

LDM

AD A 077 485

D756-1001-1

LEVEL II



DDC
RECEIVED
DEC 5 1975
REGISTRY
E

STORAGE RELIABILITY OF CHIP AND BOND WIRE ELECTRONIC DEVICES

UNCLASSIFIED
DATE 11/1/00 BY 60322 UCBAW/STP

VOLUME I - DATA ANALYSIS

DECEMBER 8, 1975

DDC FILE COPY



This document has been approved
for public release and sale; its
distribution is unlimited.

ARMY SYSTEMS DIVISION
BOEING AEROSPACE COMPANY
MUNTSVILLE OPERATIONS

79 11 -05 060

DISCLAIMER NOTICE

THIS DOCUMENT IS BEST QUALITY PRACTICABLE. THE COPY FURNISHED TO DDC CONTAINED A SIGNIFICANT NUMBER OF PAGES WHICH DO NOT REPRODUCE LEGIBLY.

14

D256-1082-1

6

STORAGE RELIABILITY OF CHIP
AND BOND WIRE ELECTRONIC DEVICES •
VOLUME I • DATA ANALYSIS •

11 8 Dec 75

15 DHHPT-75-C-0835

1396

410 935

4/3

PREFACE

This program was conducted by Boeing Aerospace Company's Army Systems Division in Huntsville, Alabama under Contract DAAH01-75-C-0835, "Storage Reliability Retest Program for Minuteman Electronic Components." The study was directed by Rex Provence, U.S. Army Missile Command (MICOM). Larry McTigue was Boeing Program Manager. Testing and failure analysis was performed by the Boeing Minuteman Reliability Engineering Organization, with Robert Frank as Principal Investigator.

This study is part of MICOM's Storage Reliability Technology program. Materiel in the Army inventory - particularly missile systems - must withstand long periods of storage and "launch ready" non-activated dormancy. Within the Department of Defense, MICOM has lead responsibility to develop the Data Bank and supporting methodology required to design, manufacture and package hardware for this non-operating environment. The results contained herein will be incorporated into the Data Bank and used to predict storage reliability characteristics for electronic parts of chip and bond wire design.

We wish to acknowledge the contributions of the MICOM Technical Manager, Rex Provence, Product Assurance Directorate, whose direction and technical comments made the results of this study a more valuable part of the overall Storage Reliability Program.

Questions on the contents of this report should be directed to Larry McTigue, Boeing Aerospace Company, P. O. Box 1470, Huntsville, Alabama 35807, phone (205) 837-5520.

Administrative stamp with handwritten notations:

Approved For	<input checked="" type="checkbox"/>
Reviewed	<input checked="" type="checkbox"/>
Checked	<input checked="" type="checkbox"/>
File	<input checked="" type="checkbox"/>
<i>File on file</i>	
<i>A 23</i>	
<i>GO</i>	

ABSTRACT

Storage reliability and parameter drift rates were measured on 10,027 Minuteman chip and bond wire Resistor-Transistor Logic (RTL) devices, which have been in storage since mid-1967 (eight years). Three parts failed as a result of the eight years of storage. Analysis of the failed parts showed all three were caused by oxide defects which allowed the deposited aluminum metalization to contact the active silicon of the die and short to ground. *The 90% confidence level values for Failure Rate and Mean Time Between Failure are 0.0095×10^{-9} failures/part-hr and 0.05×10^6 part-hrs/failure, respectively.*

After eight years of storage, none of the parts experienced a single bond wire failure, no external leads were corroded or broken and there were no package problems. This is evidence of the high storage reliability that can be achieved with proper design, manufacturing and test procedures.

Parameter drift measurements showed the resistor elements virtually unchanged after 8 years of storage. *However, the transistor elements showed a significant degradation in gain characteristics.* The gain changes are attributed to migration of contaminants (which are always present in minute amounts), and/or to changes in the gold doping process used in the manufacture of the parts. The average rate of drift ranged from 1-2% per year, depending on the logic function circuit involved. Substantially higher rates of drift - up to 7% per year - occurred in parts whose 1967 measured performance fell more than one standard deviation (-1σ) below the mean. About 2% of the parts measured had drifted close enough to specification limits to be classed as "incipient failures" (Parts that are likely to drift out of specified performance levels in 10 years of storage or less). With one exception, all of these "incipient failures" were -1σ parts or worse when tested in 1967. *The strong correlation between original measured performance and drift rate suggests that storage life can be enhanced significantly by rejecting parts that fall below the -1σ level during acceptance testing.* Rejecting the 16% of the parts that fall outside the -1σ value would reduce the number of parameter drift failures that could be expected during 10 years of storage from 2% of the population to less than 0.1%.

Study results are presented in two volumes. Volume I, Data Analysis (this volume) presents the findings, backed by summary plots and tables of reduced test data. Volume II, Test Results, tabulates all parameter measurements made on each part tested.

STORAGE RELIABILITY OF CHIP
AND BOND WIRE ELECTRONIC DEVICES

VOLUME I, DATA ANALYSIS

	PREFACE	i
	ABSTRACT	ii
	CONTENTS	iii
	FIGURES	iv
	TABLES	vii
1.0	INTRODUCTION AND SUMMARY	1-1
2.0	FAILURE RATE ANALYSIS	2-1
3.0	PARAMETER DRIFT ANALYSIS	3-1
4.0	PRODUCT IMPROVEMENT GUIDELINES	4-1

VOLUME II, TEST RESULTS

	ABSTRACT	i
	CONTENTS	ii
	FIGURES	iii
	TABLES	iv
5.0	INTRODUCTION	5-1
5.1	TWIN BUFFER TEST RESULTS	5-2
5.2	ADDER TEST RESULTS	5-19
5.3	DOUBLE GATE TEST RESULTS	5-31
5.4	4-INPUT GATE TEST RESULTS	5-63
5.5	HALF ADDER TEST RESULTS	5-78
5.6	REGISTER TEST RESULTS	5-90
5.7	EXPANDER TEST RESULTS	5-118
	APPENDIX: TEST CONDITION DEFINITION	A-1

FIGURES

-VOLUME I-

<u>FIGURE</u>		<u>PAGE</u>
1-1	PROGRAM OVERVIEW	1-1
1-2	HISTOGRAM COMPARISON OF $I_{OUT}(7)$ -DOUBLE GATE	1-4
1-3	HISTOGRAM COMPARISON OF $V_{OUT}(7-1)$ -DOUBLE GATE	1-5
1-4	LINEAR PARAMETER DRIFT MODEL FOR EXPANDER DEVICES	1-7
2-1	CIRCUIT SCHEMATICS FOR FAILED PARTS	2-1
3-1	LINEAR PARAMETER DRIFT MODEL FOR DOUBLE GATE PLUS REGISTER	3-10
3-2	V_{OUT} PARAMETER VS TRANSISTOR GAIN FOR DOUBLE GATE DEVICES	3-11
3-3	HISTOGRAM COMPARISON OF $I_{IN}(3)$ - TWIN BUFFER	3-16
3-4	HISTOGRAM COMPARISON OF $I_{OUT}(7)$ - TWIN BUFFER	3-17
3-5	HISTOGRAM COMPARISON OF $V_{OUT}(7-1)$ - TWIN BUFFER	3-18
3-6	HISTOGRAM COMPARISON OF $V_{OL}(7-1)$ - TWIN BUFFER	3-19
3-7	HISTOGRAM COMPARISON OF $I_{RT}(1-2)$ - TWIN BUFFER	3-20
3-8	HISTOGRAM COMPARISON OF $I_{RT}(3-5)$ - TWIN BUFFER	3-21
3-9	HISTOGRAM COMPARISON OF $I_L(8)$ - TWIN BUFFER	3-22
3-10	HISTOGRAM COMPARISON OF $I_{IN}(1)$ - ADDER	3-24
3-11	HISTOGRAM COMPARISON OF $I_{OUT}(6)$ - ADDER	3-25
3-11a	HISTOGRAM COMPARISON OF $I_{OUT}(7-1)$ - ADDER	3-26
3-12	HISTOGRAM COMPARISON OF $V_{OL}(7-1)$ - ADDER	3-27
3-13	HISTOGRAM COMPARISON OF $I_{RT}(1-2,3-5)$ - ADDER	3-28
3-14	HISTOGRAM COMPARISON OF $I_L(8)$ - ADDER	3-29
3-15	HISTOGRAM COMPARISON OF $I_{IN}(1)$ - DOUBLE GATE	3-31
3-16	HISTOGRAM COMPARISON OF $I_{OUT}(7)$ - DOUBLE GATE	3-32
3-17	HISTOGRAM COMPARISON OF $V_{OUT}(6-1)$ - DOUBLE GATE	3-33
3-18	HISTOGRAM COMPARISON OF $V_{OUT}(6-1)$ - DOUBLE GATE	3-34

FIGURES (Continued)

<u>FIGURE</u>		<u>PAGE</u>
3-19	HISTOGRAM COMPARISON OF VOL(7-1) - DOUBLE GATE	3-35
3-20	HISTOGRAM COMPARISON OF IRT - DOUBLE GATE	3-36
3-21	HISTOGRAM COMPARISON OF IL(8) - DOUBLE GATE	3-37
3-22	HISTOGRAM COMPARISON OF IIN(1) - 4-INPUT GATE	3-39
3-23	HISTOGRAM COMPARISON OF IOUT(7) - 4-INPUT GATE	3-40
3-24	HISTOGRAM COMPARISON OF VOUT(6-1) - 4-INPUT GATE	3-41
3-25	HISTOGRAM COMPARISON OF VOL(6-1) - 4-INPUT GATE	3-42
3-26	HISTOGRAM COMPARISON OF IRT - 4-INPUT GATE	3-43
3-27	HISTOGRAM COMPARISON OF IL(8) - 4-INPUT GATE	3-44
3-28	HISTOGRAM COMPARISON OF IIN(1) - HALF ADDER	3-46
3-29	HISTOGRAM COMPARISON OF IIN(3) - HALF ADDER	3-47
3-30	HISTOGRAM COMPARISON OF IOUT(7-1) - HALF ADDER	3-48
3-31	HISTOGRAM COMPARISON OF VOL(6) - HALF ADDER	3-49
3-32	HISTOGRAM COMPARISON OF IRT - HALF ADDER	3-50
3-33	HISTOGRAM COMPARISON OF IL(8) - HALF ADDER	3-51
3-34	HISTOGRAM COMPARISON OF IIN(2) - REGISTER	3-53
3-35	HISTOGRAM COMPARISON OF IOUT(6-1) - REGISTER	3-54
3-36	HISTOGRAM COMPARISON OF VOUT(5-1) - REGISTER	3-55
3-37	HISTOGRAM COMPARISON OF VOL(6-1) - REGISTER	3-56
3-38	HISTOGRAM COMPARISON OF IRT - REGISTER	3-57
3-39	HISTOGRAM COMPARISON OF IL(8) - REGISTER	3-58
3-40	HISTOGRAM COMPARISON OF IIN(1) - EXPANDER	3-60
3-41	HISTOGRAM COMPARISON OF VOUT(6-1) - EXPANDER	3-61
3-42	HISTOGRAM COMPARISON OF VOL(6-1) - EXPANDER	3-62
3-43	HISTOGRAM COMPARISON OF VOL(7-1) - EXPANDER	3-63

FIGURES (Continued)

<u>FIGURE</u>		<u>PAGE</u>
3-44	HISTOGRAM COMPARISON OF I_{RT} - EXPANDER	3-64
3-45	HISTOGRAM COMPARISON OF $I_L(8)$ - EXPANDER	3-65
3-46	HISTOGRAM COMPARISON OF I_{CEX} - EXPANDER	3-66
4-1	TYPICAL OUTPUT PARAMETER VS TRANSISTOR GAIN	4-2
-VOLUME II-		
5-0	MATRIX OF TEST CONDITIONS	5-1
5-1	WIRING AND LOGIC DIAGRAMS FOR TWIN BUFFER	5-3
5-2	WIRING AND LOGIC DIAGRAMS FOR ADDER	5-20
5-3	WIRING AND LOGIC DIAGRAMS FOR DOUBLE GATE	5-32
5-4	WIRING AND LOGIC DIAGRAMS FOR 4-INPUT GATE	5-64
5-5	WIRING AND LOGIC DIAGRAMS FOR HALF ADDER	5-79
5-6	WIRING AND LOGIC DIAGRAMS FOR REGISTER	5-91
5-7	WIRING AND LOGIC DIAGRAMS FOR EXPANDER	5-119
A-1	TEST CONDITIONS FOR TWIN BUFFER	A-2 thru A-8
A-2	TEST CONDITIONS FOR ADDER	A-9 thru A-13
A-3	TEST CONDITIONS FOR DOUBLE GATE	A-14 thru A-20
A-4	TEST CONDITIONS FOR 4-INPUT GATE	A-21 thru A-26
A-5	TEST CONDITIONS FOR HALF ADDER	A-27 thru A-32
A-6	TEST CONDITIONS FOR REGISTER	A-33 thru A-38
A-7	TEST CONDITIONS FOR EXPANDER	A-39 thru A-45

0256-10002-1

TABLES

-VOLUME I-

<u>TABLE</u>		<u>PAGE</u>
1-I	INVENTORY OF PARTS BY LOGIC FUNCTION	1-2
1-II	FAILURE ANALYSIS SUMMARY	1-3
2-I	LEAK TEST RESULTS	2-2
2-II	FAILURE ANALYSIS REPORT FOR DOUBLE GATE PART NO. 1493	2-3
2-III	FAILURE ANALYSIS REPORT FOR EXPANDER PART NO. 228	2-5
2-IV	FAILURE ANALYSIS REPORT FOR EXPANDER PART NO. 561	2-4
3-I	PARAMETER DRIFT TEST MATRIX	3-1
3-II	SUMMARY OF I_{IN} PARAMETER DRIFT	3-3
3-III	SUMMARY OF I_{OUT} (RESISTOR PERFORMANCE) PARAMETER DRIFT	3-4
3-IV	SUMMARY OF V_{OUT} (TRANSISTOR PERFORMANCE) PARAMETER DRIFT	3-5
3-V	SUMMARY OF V_{OL} PARAMETER DRIFT	3-6
3-VI	SUMMARY OF I_{RT} PARAMETER DRIFT	3-7
3-VII	SUMMARY OF I_L PARAMETER DRIFT	3-8
3-VIII	SUMMARY OF I_{CEX} PARAMETER DRIFT	3-9
3-IX	INCIPIENT FAILURES	3-12
3-X	EVALUATION OF HISTOGRAM COMPARISONS FOR THE TWIN BUFFER	3-15
3-XI	EVALUATION OF HISTOGRAM COMPARISONS FOR THE ADDER	3-23
3-XII	EVALUATION OF HISTOGRAM COMPARISONS FOR THE DOUBLE GATE	3-30

TABLES (Continued)

<u>TABLE</u>		<u>PAGE</u>
3-XIII	EVALUATION OF HISTOGRAM COMPARISONS FOR THE 4-INPUT GATE	3-38
3-XIV	EVALUATION OF HISTOGRAM COMPARISONS FOR THE HALF ADDER	3-45
3-XV	EVALUATION OF HISTOGRAM COMPARISONS FOR THE REGISTER	3-52
3-XVI	EVALUATION OF HISTOGRAM COMPARISONS FOR THE EXPANDER	3-59
4-I	PRODUCT IMPROVEMENT RECOMMENDATIONS	4-1

-VOLUME II-

5-I	TEST RESULTS FOR TWIN BUFFER	5-4
5-II	TEST RESULTS FOR ADDER	5-21
5-III	TEST RESULTS FOR DOUBLE GATE	5-33
5-IV	TEST RESULTS FOR 4-INPUT GATE	5-65
5-V	TEST RESULTS FOR HALF ADDER	5-80
5-VI	TEST RESULTS FOR REGISTER	5-92
5-VII	TEST RESULTS FOR EXPANDER	5-120

INTRODUCTION AND SUMMARY

1.0 INTRODUCTION

In July 1967, over eight years ago, 10,027 Motorola RTL electronic parts of chip and bond wire design were placed in room temperature storage. Prior to storage, each part was burned in (168 hours @ 125°C), then tested to record the performance of each parameter. Starting in July of 1975, the parts were removed from storage and the original test program repeated to obtain Storage Reliability data for chip and bond wire devices. As shown in Figure 1-1, the retest program consisted of the following two elements:

- 1) Measurement of storage failure rates, followed by analysis of the failures to identify failure modes and mechanisms and to establish product improvement guidelines.
- 2) Measurement of parameter drift characteristics and analysis of results to establish incipient failures, drift rates, and projected shelf life.

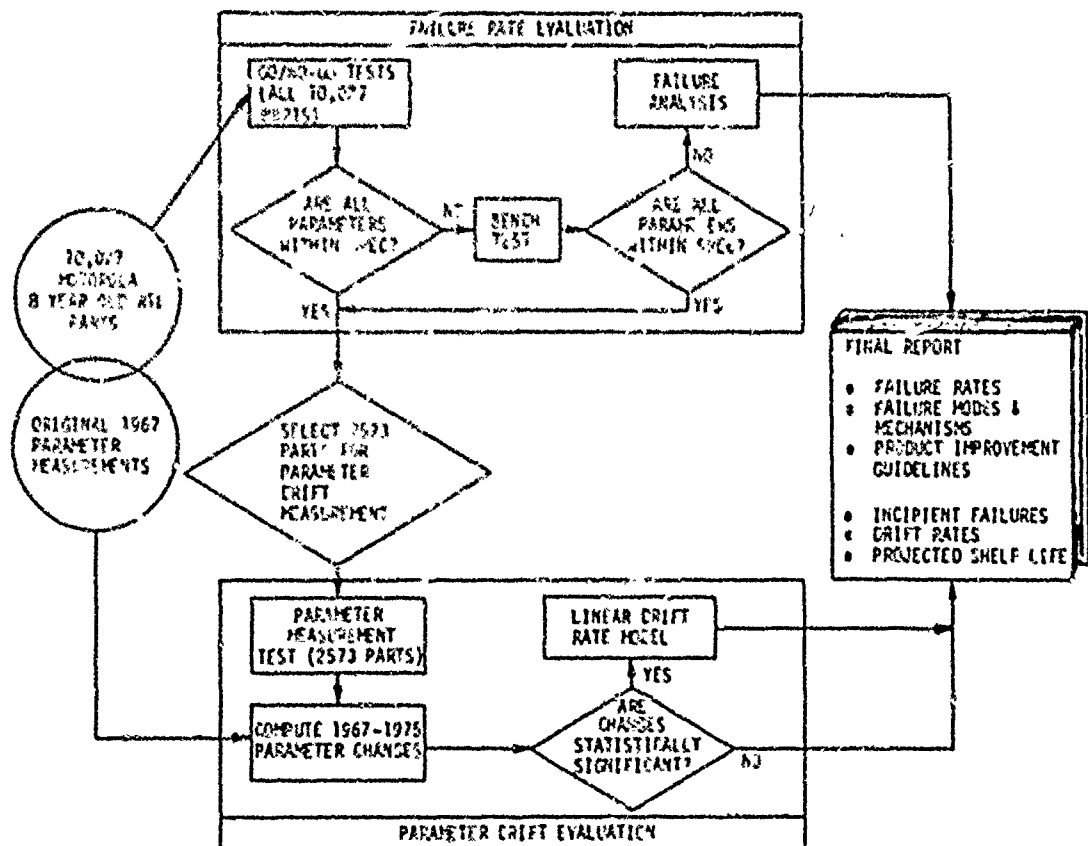


FIGURE 1-1. PROGRAM OVERVIEW

1.0 INTRODUCTION (CONTINUED)

All 10,027 parts were subjected to Go/No-Go testing to detect failed parts (parts showing one or more parameters outside of specification limits). These parts were then individually bench tested. Confirmed failed parts were analyzed to establish the failure modes and mechanisms.

A randomly selected sample of 2573 parts passing Go/No-Go testing were run through the Parameter Drift test program. Selected currents and voltages representing resistor characteristics, transistor gains and leakage rates were measured and recorded. Computer analysis was performed to compare the 1975 test values with those measured in 1967. For those parameters showing statistically significant performance changes, a linear drift rate model was fit to the test data and used to predict remaining storage life.

1.1 SUMMARY

While all parts were of similar chip and bond wire design, devices having seven different logic functions were included in the inventory of parts tested (Table 1-1).

TABLE 1-1. INVENTORY OF PARTS BY LOGIC FUNCTION

<u>LOGIC FUNCTION</u>	<u>MOTOROLA PART NO.</u>	<u>NO. OF PARTS FOR FAILURE RATE EVALUATION</u>	<u>NO. OF PARTS FOR PARAMETER DRIFT EVALUATION</u>
Twin Buffer	SC 2207	1002	250
Adder	SC 2208	1002	250
Double Gate	SC 2210	2382	500
4-Input Gate	SC 2211	1250	348
Half-Adder	SC 2212	450	250
Register	SC 2213	2992	625
Expander	SC 2221	949	350
		<u>10027</u>	<u>2573</u>

A total of three parts failed as a result of the eight years of storage. Analysis of the failed parts showed all three were due to oxide defects which allowed the deposited aluminum metalization to contact the active silicon of the die and short to ground. Table 1-11 summarizes the failures and the resulting failure rate statistics.

1.1 SUMMARY (Continued)

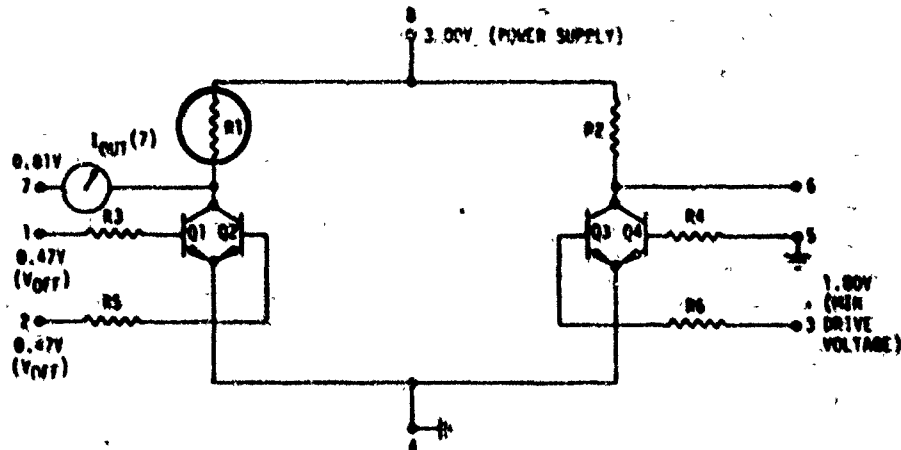
TABLE 1-II. FAILURE ANALYSIS SUMMARY

<u>PART LOGIC FUNCTION</u>	<u>PART SERIAL NUMBER</u>	<u>FAILURE MODE/MECHANISM</u>
DOUBLE GATE	1493	SHORT CAUSED BY OXIDE DEFECT UNDER AL STRIPE ON DIE CONNECTING TO PIN 1
EXPANDER	228	SHORT CAUSED BY OXIDE DEFECT UNDER BOND PAD 3
	561	SHORT CAUSED BY OXIDE DEFECT UNDER BOND PAD 6
TOTAL FAILURES = 3		
TOTAL PART-HOURS OF STORAGE = 703×10^6		
FAILURE RATE (FAILURES/PART-HR)	=	$\left\{ \begin{array}{l} 0.0089 \times 10^{-6} \text{ (60\% CONFIDENCE LEVEL)} \\ 0.0095 \times 10^{-6} \text{ (90\% CONFIDENCE LEVEL)} \end{array} \right.$
MEAN TIME BETWEEN FAILURES (MTBF) (PART-HR/FAILURE)	=	$\left\{ \begin{array}{l} 169 \times 10^6 \text{ (60\% CONFIDENCE LEVEL)} \\ 105 \times 10^6 \text{ (90\% CONFIDENCE LEVEL)} \end{array} \right.$

Results from the Parameter Drift Evaluation are typified by Figures 1-2 and 1-3 which compare 1967 and 1975 test results for parameters representing resistor and transistor performance, respectively. The 1975 measurements taken on the resistor elements are virtually unchanged from the 1967 values. Note that the 1967 and 1975 histograms (Figure 1-2b) are almost identical in shape and only differ by a 4 microamp bias. This bias is attributed to a slight difference in test set-up and is not an indication of parameter drift. This conclusion is confirmed by Figure 1-2c, which shows the 1967-1975 change in the I_{off} parameter. The near-normal distribution of this change is typical of scatter due to normal measurement error. It shows none of the skewness exhibited by true parameter drift.

The transistor elements did show a measurable loss of performance during the eight years of storage. Figure 1-3 is a typical comparison of changes in transistor gain. While the change in mean value is small (6 mv), the pronounced skewness of Figure 1-3c shows the changes are due to parameter drift rather than measurement error. There is significant performance loss in parts in the right hand tail of the distribution (parts whose original performance was more than one standard deviation below the 1967 mean). Degradation in the parts having the greatest rate of drift (parts occupying the shaded -2σ tail in Figure 1-3d) is shown by the heavy arrows in Figure 1-3d. Note that all these parts were below average performers in 1967.

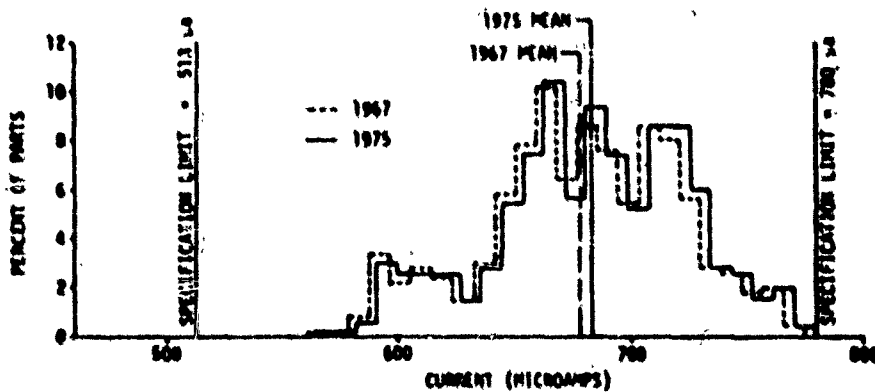
1.1 SUMMARY (Continued)



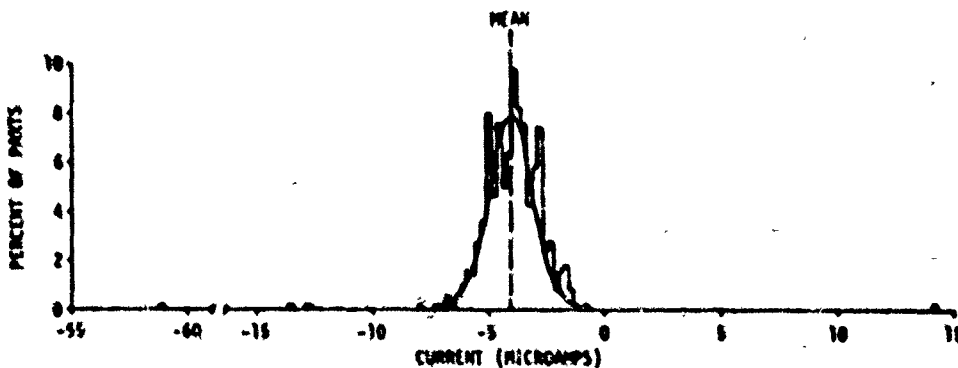
a. SCHEMATIC FOR IOUT (7) TEST (R1 RESISTANCE CHECK)

NO. OF PARTS REPRESENTED BY HISTOGRAM 800

TEST	MEAN	STD DEV.
1967	679 μ A	42.5 μ A
1975	683 μ A	42.5 μ A
1967-1975 DELTA	-4 μ A	3.0 μ A



b. DISTRIBUTION OF PARTS; 1975 VS 1967 TEST

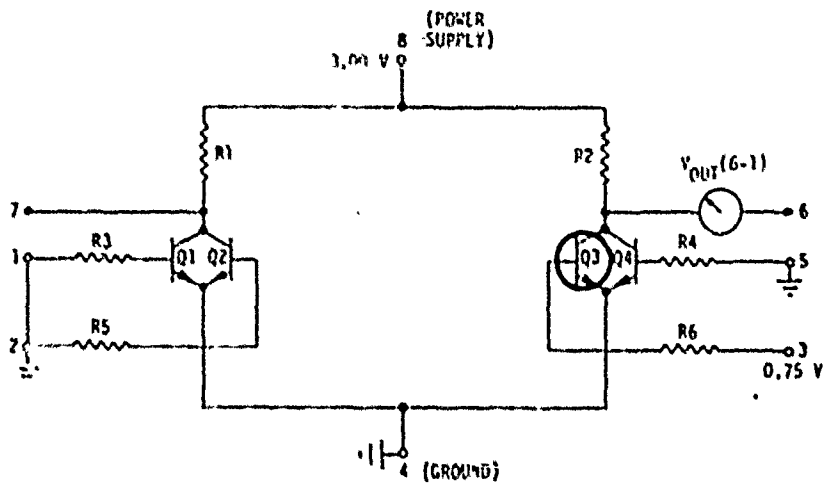


c. 1967-1975 CHANGE IN IOUT (7)

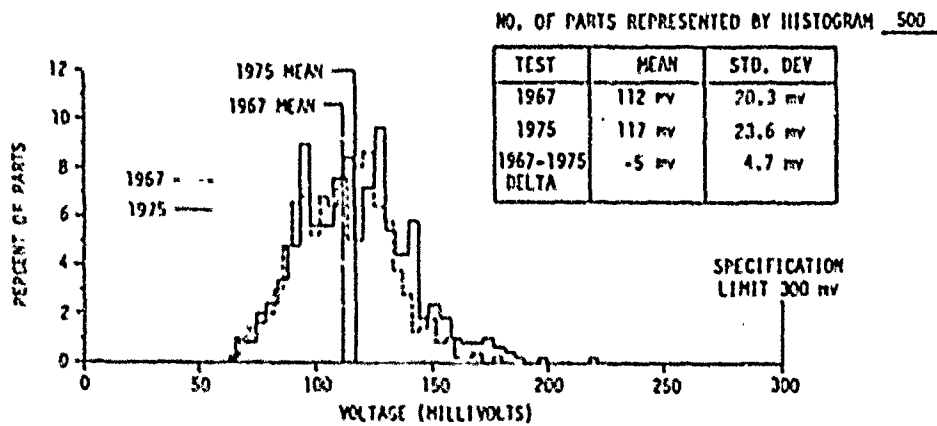
FIGURE 1-2. HISTOGRAM COMPARISON OF IOUT (7)

- DOUBLE GATE -

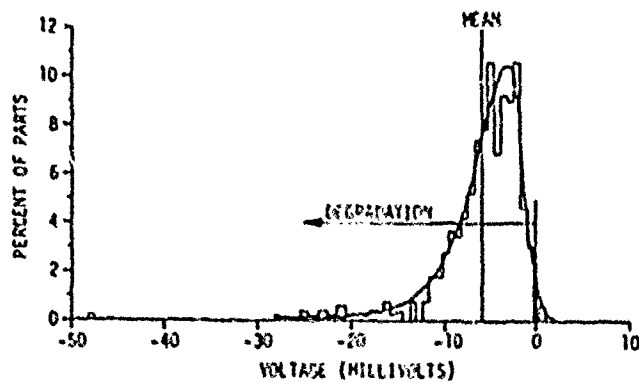
1.1 SUMMARY (Continued)



a. SCHEMATIC FOR $V_{OUT(6-1)}$ TEST (Q3 VOLTAGE DROP AT MINIMUM "ON" CONDITION)



b. DISTRIBUTION OF PARTS: 1975 VS 1967 TEST

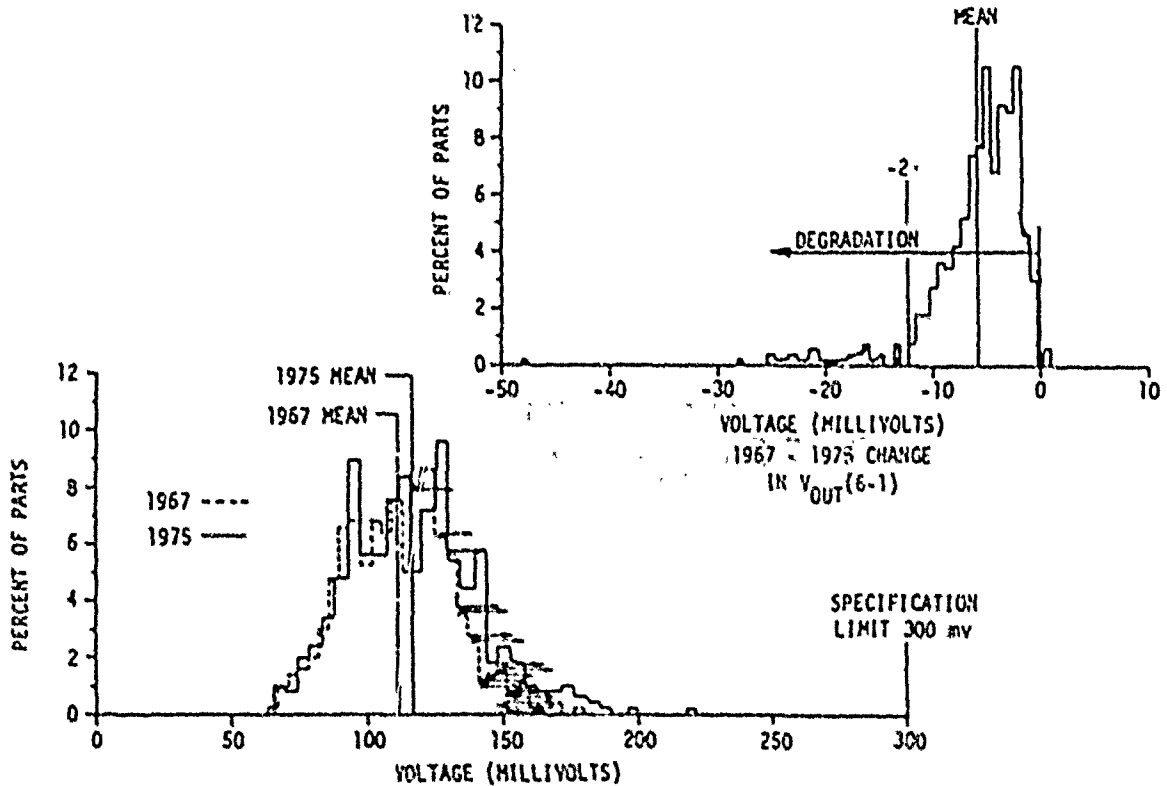


c. 1967 - 1975 CHANGE IN $V_{OUT(6-1)}$

FIGURE 1-3. HISTOGRAM COMPARISON OF $V_{OUT(6-1)}$

- DOUBLE GATE -

1.1 SUMMARY (Continued)



d. DISTRIBUTION OF PARTS SHOWING GREATEST DEGRADATION

FIGURE 1-3. (CONTINUED)

The loss of performance in the transistor elements was significant enough to class 24 parts as incipient failures. These are parts whose performance has degraded near specification limits and could fall out of spec within the next few years of storage. Since the Parameter Drift study measured only one of the two output terminals on each part, and only 2573 of the 10,027 parts ($1/2 \times 2573/10027 \approx 1/8$ sample), it can be reasonably expected that $8 \times 24 = 200$ of the 10,027 parts (approximately 2%) are likely incipient failures.

1.1 SUMMARY (CONTINUED)

The degradation in transistor performance as demonstrated by an increase in both mean and standard deviation, was statistically significant at the 99% confidence level for the Double Gate, Register and Expander devices. These devices showed drift rates of 0.5-1% per year in mean value and 2-4% per year in standard deviation. The lower figures apply to the Double Gate and Register, while the higher figures apply to the Expander. A linear model (constant rate of drift) was fit to the mean and standard deviation measured on these devices. Figure 1-4 below shows this model for the Expander. This linear model predicts that a part whose 1967 performance was more than 3 standard deviations below the mean would drift out of specification limits after 17 years of storage (by 1984).

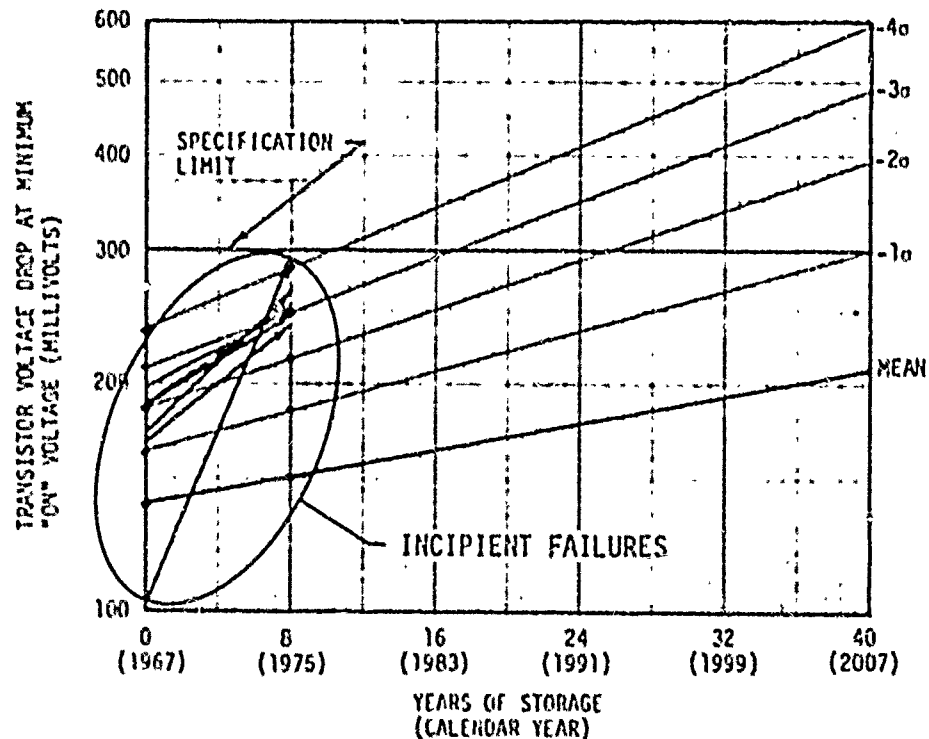


FIGURE 1-4. LINEAR PARAMETER DRIFT MODEL FOR EXPANDER DEVICES

There were 14 incipient failures detected in the 350 Expander devices tested (4%). The drift in the six worst devices is shown by the heavy arrows in the figure. The drift rate in these occasional "bad actors" is obviously much faster than the linear model predicts.

1.1 (Continued)

Whether a linear model provides a useful projection of parameter drift characteristics can only be determined by future testing of the same parts. However, the general trend of increasing rate of drift for the higher negative σ parts (poorer performer) is clearly established by the data from the 1975 test. This trend leads to the conclusion that storage reliability of these chip and bond wire devices can be increased by simply rejecting the more marginal performers during initial acceptance testing. In the case of the Expander parts, all but one of the 14 incipient failures would have been eliminated by rejecting the 16% of the parts that fell more than one standard deviation ($-\sigma$) below the mean following the 1967 acceptance testing. Eight of the 14 would have been eliminated by a -2σ criterion, which would have required rejecting only 2.3% of the parts.

SECTION 2
FAILURE RATE ANALYSIS

2.0 INTRODUCTION

To determine the shelf-life failure rate of bond wire RTL Integrated Circuits (IC's), 10,027 such devices, stored for eight years, were retested to the 25°C parametric limits of the Boeing specifications. The parts were tested to these specifications by the supplier (Motorola) eight years ago. Retesting was done on a model J283C Teradyne Test Set, programmed, calibrated and maintained by the Boeing Advanced Electronic Design Group. Each of the 10,027 IC's was tested on a GO NO-GO basis to determine if one or more of its parameters had drifted outside specification limits. Those parts which failed the GO NO-GO testing on the Teradyne were carefully rechecked on the bench to verify their condition. Out of the more than 10,000 parts tested, only three defectives were found. The three were catastrophic failures with several parameters more than two orders of magnitude outside specification limits. The failures occurred in the Double Gate and Expander devices, whose circuit schematics are shown below.

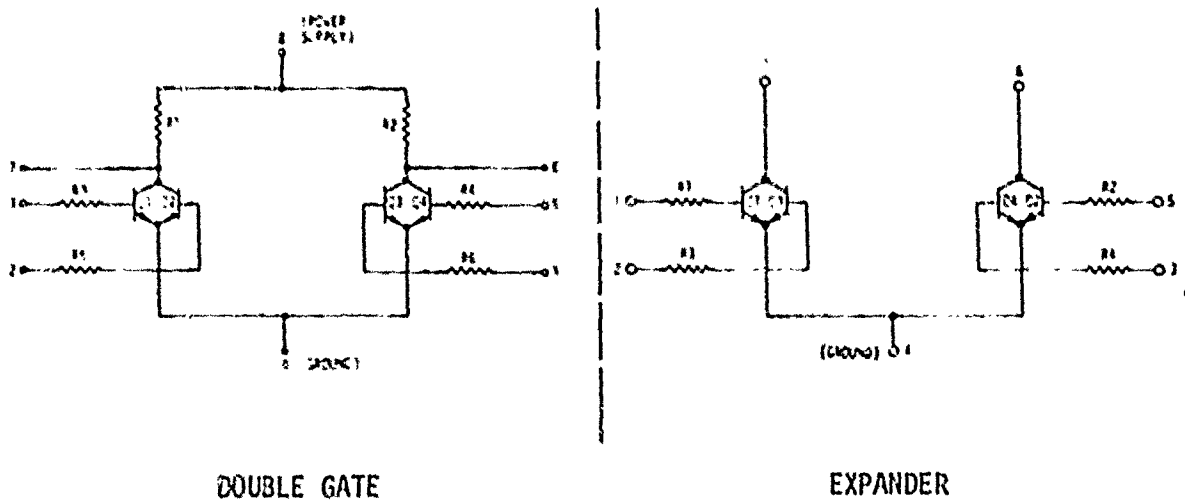


FIGURE 2-1. CIRCUIT SCHEMATICS FOR FAILED PARTS

2.1 FAILURE ANALYSIS

The three catastrophic failures were subjected to analysis to determine the cause of failure. They were first given a hermetic seal test with the following results:

TABLE 2-I. LEAK TEST RESULTS

<u>LOGIC FUNCTION</u>	<u>PART NO</u>	<u>GROSS LEAK</u>	<u>*FINE LEAK RATE</u>	<u>*SPECIFICATION VALUE</u>
Double Gate	1493	No	3.6×10^{-8} cc/sec	$<1 \times 10^{-8}$ cc/sec
Expander	228	No	9.81×10^{-8} cc/sec	"
Expander	561	No	2.19×10^{-8} cc/sec	"

*@25°C and one standard atmosphere

While the measured fine leak rates exceeded specification, they were still small enough to conclude that no significant breakdown had occurred in the hermetic seals. The defects identified by subsequent failure analyses were in no way aggravated by leakage.

Curve tracer testing of the three parts [checking from each lead to the ground (GND) lead and to the power supply lead with a Tektronix 577 Curve Tracer Oscilloscope] found a low resistance path from pin 1 (input) to pin 4 (GND) on Part No. 1493, a 100 ohm "short" from pin 3 (input) to pin 4 on Part No. 228, and a 600 ohm path from pin 6 (output) to pin 4 (GND) on Part No. 561. Experience with transistor-transistor logic devices has shown that such low resistance paths to GND (substrate of the die) occur because of oxide defects or because the part has been subjected to electrical overstress. To determine if the failures were due to oxide effects or electrical overstress, the three IC's were delidded and microscopically examined. No gross defects were observed such as might be caused by electrical overstress so the glassivation was removed from each die using buffered hydrofluoric acid. Next the aluminum metallization was removed with dilute sodium hydroxide. It was then easy to see that the failures were due to defects in the oxide which had allowed the metallization to short through to the active silicon of the die. There was an oxide defect/pinhole under an aluminization stripe connected to the No. 1 bond pad on Part No. 1493, under the No. 3 bond pad on Part No. 228, and under the No. 6 bond pad on Part No. 561. Based on the above analyses, it was concluded that the three failures were the result of deficiencies within the parts and were not caused by externally applied overstress and therefore that the three failures had to be considered shelf-life failures. The failure analysis reports are shown in Tables 2-II through 2-IV.

TABLE 2-II. FAILURE ANALYSIS REPORT FOR DOUBLE GATE PART NO. 1493

RTL FAILURE ANALYSIS REPORT NO. 1000	
TEST CASE NO. 1000	DATE CASE 10-1-52
TEST FAILED	
PARAMETERS FAILED	
BRANCH TEST RESULTS GOOD TEST <input type="checkbox"/> <input checked="" type="checkbox"/> <input type="checkbox"/> CATASTROPHIC FAILURE <input type="checkbox"/> <input checked="" type="checkbox"/> <input type="checkbox"/> DIRT FAILURE <input type="checkbox"/> <input checked="" type="checkbox"/> <input type="checkbox"/>	
SEAL TEST RESULTS FINE LEAK FAILURE YES <input type="checkbox"/> NO <input checked="" type="checkbox"/> GROSS LEAK FAILURE YES <input type="checkbox"/> NO <input checked="" type="checkbox"/>	
RESULTS OF FAILURE ANALYSIS: THE SEAL WAS FOUND TO BE THE CAUSE OF FAILURE. THE SEAL WAS FOUND TO BE THE CAUSE OF FAILURE. THE SEAL WAS FOUND TO BE THE CAUSE OF FAILURE. CONCLUSION AS TO CAUSE OF FAILURE: THE SEAL WAS FOUND TO BE THE CAUSE OF FAILURE.	
IS THIS A SHELF-LIFE FAILURE? YES <input checked="" type="checkbox"/> NO <input type="checkbox"/>	
ANALYST'S SIGNATURE APPROVED DATE 10-1-52	

TABLE 2-III. FAILURE ANALYSIS REPORT FOR EXPANDER PART NO. 228

RTL FAILURE ANALYSIS REPORT NO. 1000	
TEST CASE NO. 1000	DATE CASE 10-1-52
TEST FAILED	
PARAMETERS FAILED	
BRANCH TEST RESULTS GOOD TEST <input type="checkbox"/> <input checked="" type="checkbox"/> <input type="checkbox"/> CATASTROPHIC FAILURE <input type="checkbox"/> <input checked="" type="checkbox"/> <input type="checkbox"/> DIRT FAILURE <input type="checkbox"/> <input checked="" type="checkbox"/> <input type="checkbox"/>	
SEAL TEST RESULTS FINE LEAK FAILURE YES <input type="checkbox"/> NO <input checked="" type="checkbox"/> GROSS LEAK FAILURE YES <input type="checkbox"/> NO <input checked="" type="checkbox"/>	
RESULTS OF FAILURE ANALYSIS: THE SEAL WAS FOUND TO BE THE CAUSE OF FAILURE. THE SEAL WAS FOUND TO BE THE CAUSE OF FAILURE. THE SEAL WAS FOUND TO BE THE CAUSE OF FAILURE. CONCLUSION AS TO CAUSE OF FAILURE: THE SEAL WAS FOUND TO BE THE CAUSE OF FAILURE.	
IS THIS A SHELF-LIFE FAILURE? YES <input checked="" type="checkbox"/> NO <input type="checkbox"/>	
ANALYST'S SIGNATURE APPROVED DATE 10-1-52	

TABLE 2-IV. FAILURE ANALYSIS REPORT FOR EXPANDER PART NO. 561

RTL FAILURE ANALYSIS REPORT NO. <u>21-002</u>	
WAFER NUMBER <u>111111</u>	SERIAL NUMBER <u>2-121</u> DATE CODE <u>57A</u>
TEST FAILED <u>111111</u>	
PARAMETERS FAILED <u>111111</u>	
NEMO TEST RESULTS GOOD PART <input type="checkbox"/> <input checked="" type="checkbox"/> <input type="checkbox"/> CATASTROPHIC FAILURE <input type="checkbox"/> <input checked="" type="checkbox"/> <input type="checkbox"/> DRIFT FAILURE <input type="checkbox"/> <input checked="" type="checkbox"/> <input type="checkbox"/>	
SEAL TEST RESULTS YES <input type="checkbox"/> <input checked="" type="checkbox"/> <input type="checkbox"/> NO <input checked="" type="checkbox"/> <input type="checkbox"/> <input type="checkbox"/> FINE LEAK FAILURE <input type="checkbox"/> <input checked="" type="checkbox"/> <input type="checkbox"/> <input type="checkbox"/> <input type="checkbox"/> <input type="checkbox"/> GROSS LEAK FAILURE <input type="checkbox"/> <input checked="" type="checkbox"/> <input type="checkbox"/> <input type="checkbox"/> <input type="checkbox"/> <input type="checkbox"/>	
RESULTS OF FAILURE ANALYSIS: 1. 7.5 millamps (should be 0.10 m amp) 2. 4 millamps (should be 0.10 m amp) 3. Same trace was found a 600 ohm resistor from pin 6 to pin 4 (ground) pin 6 to pin 5 and pin 3 broke over at 7.5V. This should have been over 20 V. The aluminum metallization was stripped from the die pin holes were found in the oxide under bond pad 6. The transistor connected to pin 6 (Q2) chipping open. CONCLUSION AS TO CAUSE OF FAILURE: Failure was due to an oxide defect under bond pad 6.	
IS THIS A SHELF-LIVE FAILURE? YES <input checked="" type="checkbox"/> NO <input type="checkbox"/>	
ANALYST <u>J. J. J. J.</u> APPROVED <u>J. J. J. J.</u> DATE <u>11-21-57</u>	

Oxide defects in general result from manufacturing deficiencies during wafer fabrication and in some instances during die probe or during wire bonding. Such things as holes and/or tears in the masks used for exposing the photoresist or foreign particles on the wafer during oxide growth can cause defects in the oxide. These defects are harmful only when they occur under the metallization pattern and only if they allow the metal to short through the oxide to the active silicon beneath. Improvements in manufacturing techniques are possible which can reduce the number of oxide defects and therefore the number of failures. Very careful cleaning procedures before growing the oxides and a double mask set used during the exposure of the photoresist prior to etching the oxides will produce parts with fewer defects. Many manufacturers, though, are reluctant to change historic and generally accepted manufacturing techniques to attempt to produce defect-free parts. In most programs, the cost of such parts is prohibitive so there is little incentive to improve an already acceptable failure rate.

It is not possible to tell at what point in time the oxide defect failures occurred. Since the defects (holes) found in the oxide were relatively large, it is difficult to explain why the deposited aluminumization did not make intimate contact with the substrate silicon when the wafer was metallized during manufacture. If a very thin layer of oxide existed to insulate the aluminum from the silicon substrate, what eventually occurred to cause the short? It is possible that a very thin layer of oxide could

2.1 (Continued)

sustain the burn-in and test voltage stresses at Motorola and then chemically change with age to become a low resistance path to substrate silicon. In any event, experience in Minuteman has shown that most oxide defect failures occur either in receiving inspection testing or in equipment test after the IC's are installed on circuit cards. Though oxide defects are the most prevalent cause of failure in the low power transistor-transistor logic (TTL) devices used in Minuteman, the failures occur and are eliminated during receiving testing or during functional test at the circuit card level rather than during field operation of the equipment. Nearly 0.04% of the TTL devices obtained from four different suppliers fail due to oxide defects prior to field installation of the equipment, but with more than 200,000 TTL devices fielded, some for more than two years, the number of failures due to oxide defects is at least an order of magnitude less than during receiving/functional test. This means that in actual hardware applications, most oxide defect parts would be detected and eliminated prior to storage by assuring that adequate functional tests are carried out at the circuit card or subsystem level.

2.2 FAILURE RATE AND MTBF

Since there were no parameter drift failures in the 10,027 parts after eight years of storage, the three catastrophic failures were used to compute the failure rate statistics. The Chi Square (χ^2) distribution was used to determine the 60% and 90% confidence level for failure rate and MTBF. Use of the χ^2 distribution to establish confidence limits is treated in any standard text on statistics. The computations are presented in Equations 2-1 and 2-2.

FAILURE RATE

60% Confidence:

$$FR_{60\%} = \frac{\chi^2_{60\%} \times 3 \text{ failures}}{10,027 \text{ parts} \times 8 \text{ yrs/part} \times 8760 \text{ hr/yr}}$$

$$= \frac{4.175 \text{ failures}}{703 \times 10^6 \text{ hrs}} = 0.0059 \times 10^{-6} \text{ failures/hr} \quad (2-1a)$$

$$FR_{90\%} = \frac{\chi^2_{90\%} \times 3 \text{ failures}}{703 \times 10^6 \text{ hrs}} = \frac{6.70 \text{ failures}}{703 \times 10^6 \text{ hrs}} = 0.0095 \times 10^{-6} \text{ failures/hr} \quad (2-1b)$$

2.2 (Continued)

MEAN TIME BETWEEN FAILURES

$$MTBF_{60\%} = \frac{1}{FR_{60\%}} = \frac{1}{0.0059 \times 10^{-6}} = 169 \times 10^6 \text{ hrs} \quad (2-2a)$$

$$MTBF_{90\%} = \frac{1}{FR_{90\%}} = \frac{1}{0.0095 \times 10^{-6}} = 105 \times 10^6 \text{ hrs} \quad (2-2b)$$

The design, manufacture, and test procedures used to develop these parts has obviously produced IC's of very high storage reliability. After eight years of storage, there were no parameter drift failures, no bond wire failures, no external leads corroded or broken, and no package problems. As already discussed, in an actual hardware application the three oxide defects that did occur would likely have been eliminated by assuring that normal functional tests were conducted following installation of the IC's on circuit cards.

SECTION 3

PARAMETER DRIFT ANALYSIS

3.0 INTRODUCTION

The Parameter Drift Test Program measured up to seven different parameters on each of the seven types of logic function devices. Table 3-I shows the 45 individual parameter tests that were performed on a total of 2573 parts. The physical characteristics associated with each parameter measurement (resistance, transistor voltage drop, leakage current) are defined in the right hand column of the table. The 2573 parts tested were selected at random in blocks of 20 or less from the total 10027 part inventory.

TABLE 3-I. PARAMETER DRIFT TEST MATRIX

PARAMETER	LOGIC FUNCTION AND NO. OF PARTS TESTED (2573 PARTS TOTAL)							CHARACTERISTICS MEASURED
	INVERTER (230 PARTS)	ANDER (250 PARTS)	DOUBLE DATE (300 PARTS)	4-INPUT DATE (340 PARTS)	HALF ADDER (250 PARTS)	REGISTER (625 PARTS)	EXPANDER (350 PARTS)	
INPUT CURRENT I_{IN}	$I_{IN}(3)$	$I_{IN}(1)$	$I_{IN}(3)$	$I_{IN}(1)$	$I_{IN}(3)$ $I_{IN}(2)$	$I_{IN}(7)$	$I_{IN}(1)$	RESISTANCE PLUS BASE EMITTER PERFORMANCE AT SATURATION VOLTAGE
OUTPUT CURRENT I_{OUT}	$I_{OUT}(7)$	$I_{OUT}(6)$ $I_{OUT}(2,3)$	$I_{OUT}(7)$	$I_{OUT}(7)$	$I_{OUT}(2,3)$	$I_{OUT}(6-1)$	NO TEST	RESISTANCE
OUTPUT VOLTAGE V_{OUT}	$V_{OUT}(7-3)$	NO TEST	$V_{OUT}(6-1)$	$V_{OUT}(6-1)$	NO TEST	$V_{OUT}(5-1)$	$V_{OUT}(6-1)$	TRANSISTOR VOLTAGE DROP AT MINIMUM "ON" BASE EMITTER VOLTAGE
OUTPUT VOLTAGE V_{OL}	$V_{OL}(7-3)$	$V_{OL}(2-1)$	$V_{OL}(6-1)$ $V_{OL}(7-1)$	$V_{OL}(6-1)$	$V_{OL}(6)$	$V_{OL}(6-2)$	$V_{OL}(6-1)$ $V_{OL}(7-1)$	TRANSISTOR VOLTAGE DROP AT SATURATION VOLTAGE
LEAKAGE CURRENT I_{RT}	$I_{RT}(1-2)$ $I_{RT}(2-3)$	$I_{RT}(1,2,3,5)$	I_{RT}	I_{RT}	I_{RT}	I_{RT}	$I_{RT}(1,2,3,5)$	BASE EMITTER FUNCTION LEAKAGE CHARACTERISTICS
LEAKAGE CURRENT I_L	$I_L(8)$	$I_L(8)$	$I_L(8)$	$I_L(8)$	$I_L(8)$	$I_L(8)$	$I_L(6,7,8)$	TRANSISTOR LEAKAGE CHARACTERISTICS AT ZERO BASE EMITTER VOLTAGE
LEAKAGE CURRENT I_{CEX}	NO TEST	NO TEST	NO TEST	NO TEST	NO TEST	NO TEST	$I_{CEX}(7)$	TRANSISTOR LEAKAGE CHARACTERISTICS AT MAXIMUM "OFF" BASE EMITTER VOLTAGE

NOTE NO. IN PARENTHESES INDICATES PIN BEING TESTED, AND TEST CONDITIONS ARE INDICATED. THESE CONDITIONS ARE DEFINED IN SECTION 3.2

Section 3.1 summarizes Parameter Drift results with emphasis on pinpointing the physical elements within each device most susceptible to aging. Section 3.2 provides a histogram comparison of the 1967 and 1975 test results for each of the 45 parameter tests defined above.

3.1 PARAMETER DRIFT SUMMARY

Tables 3-II through 3-VIII summarize the Test Results for the seven parameters that were measured to evaluate drift. Each table compares the 1967 and 1975 mean values and standard deviations for a single parameter, starting with I_{IN} (Table 3-II). The 1967-1975 changes in the mean value and standard deviation were tested for statistical significance via the Student t and F-Distribution tests, respectively. These two tests are covered in all standard texts on Statistics. Tests of significance determine the likelihood that the observed changes are due to random sampling differences (in this case, measurement errors) rather than to true drift. The conservative criterion of 99% confidence was adopted for these tests. This means that there is less than a one percent chance that the 1967-1975 change in any parameter that fails this criterion could be explained by measurement errors alone (or conversely, there is 99% confidence that parameter drift has occurred). The "Analysis of Change" columns at the right of each table show the results of these statistical tests of significance.

The two most useful parameters proved to be I_{OUT} (Table 3-III) and V_{OUT} (Table 3-IV), which directly measure changes in resistor and transistor characteristics, respectively. The V_{OUT} measurement is the most sensitive of the transistor measurements, since it determines voltage drop across the transistor under conditions of minimum "on" base emitter voltage. This "knee-of-the-curve" operational condition provided the clearest picture of storage-induced changes in the transistor elements. The I_{IN} and V_{OL} measurements (Tables 3-II and 3-V), while not as sensitive as the V_{OUT} measurements, also provided supportive data on transistor drift. Little quantitative information was obtained from the leakage current measurements, I_{RT} , I_L , and I_{CEX} (Tables 3-VI thru 3-VIII), since the 1967 tests were not carried out to the nanoamp precision needed to define changes in these parameters. However, the 1975 measurements showed that leakage rates were insignificant compared with specification values and that drift in these parameters was negligible.

As discussed in Section 1, there was no measurable degradation in the resistor elements after eight years of storage. However, the degradation in transistor performance was significant at the 95% confidence level for all six logic function devices on which V_{OUT} measurements were taken. In three of these families, the Double Gate, the Register, and the Expander, changes were significant at the 99% confidence level, as indicated by the boxed-in values in Table 2-IV. The statistics for the Double Gate and Register were similar enough to combine these two families, which gives the bottom row in Table 3-III.

TABLE 3-11 SUMMARY OF I_{IN} PARAMETER DRIFT

LOGIC FUNCTION	PARAMETER *(REF)	SAMPLE SIZE N	MEASURED PERFORMANCE (μa)		1967 - 1975 CHANGE (μa)		SPECIFICATION LIMIT (μa)	ANALYSIS OF CHANGE	
			1967 TEST X	1975 TEST σ	ΔX	Δσ		t _X	F _σ
TWIN BUFFER	I _{IN} (3) (Fig. 3-3)	250	185	10.0	181	9.5	<250	**	**
ADDER	I _{IN} (1) (Fig. 3-10)	250	88.0	6.4	86.4	6.3	<125		
DOUBLE GATE	I _{IN} (1) (Fig. 3-15)	500	98.2	4.9	95.2	5.4			
4-INPUT GATE	I _{IN} (1) (Fig. 3-22)	348	83.5	3.8	82.5	3.8			
HALF ADDER	I _{IN} (1) (Fig. 3-28)	250	90.7	4.9	89.0	4.7			
	I _{IN} (3) (Fig. 3-29)	250	89.7	4.6	88.6	4.4			
REGISTER	I _{IN} (2) (Fig. 3-34)	625	76.4	6.3	91.3	5.2			
EXPANDER	I _{IN} (1) (Fig. 3-40)	350	114.8	6.3	122.9	6.5	<166		

* FIGURE NO. OF PLOTTED RESULTS

\bar{x} = MEAN

σ = STANDARD DEVIATION

$\Delta\bar{x}$ = 1967-1975 CHANGE IN MEAN

$\Delta\sigma$ = 1967-1975 CHANGE IN STANDARD DEVIATION

☐ CHANGE SIGNIFICANT AT 99% CONFIDENCE LEVEL

$$t_{\bar{x}} = \frac{\Delta\bar{x}}{\sigma_{\bar{x}}} = \frac{\Delta\bar{x}}{\frac{\sigma}{\sqrt{N}}}$$

t_{99} = 99% PROBABILITY LEVEL FROM STUDENT t DISTRIBUTION

F_{99} = 99% PROBABILITY LEVEL FROM F-DISTRIBUTION

** = NO STATISTICALLY SIGNIFICANT CHANGE - DIFFERENCES ATTRIBUTED TO NORMAL OBSERVATION ERROR

TABLE 3-III SUMMARY OF I_{OUT} PARAMETER DRIFT
(RESISTOR PERFORMANCE)

LOGIC FUNCTION	PARAMETER *(REF)	SAMPLE SIZE n	MEASURED PERFORMANCE (μa)		1967 - 1975 CHANGE (μa)	SPECIFICATION LIMIT(S) (μa)	ANALYSIS OF CHANGE		
			\bar{x}	σ			\bar{x}	t_{99}	F_{99}
TWIN BUFFER	I _{OUT} (7) (Fig. 3-4)	250	18900	700	19000	700	**	**	**
ADDER	I _{OUT} (6) (Fig. 3-11)	250	556	59	561	59			
DOUBLE GATE	I _{OUT} (7) (Fig. 3-16)	500	679	43	683	43			
4-INPUT GATE	I _{OUT} (7) (Fig. 3-23)	348	574	34	577	34			
HALF ADDER	I _{OUT} (7-1) (Fig. 3-30)	250	598	36	601	38			
REGISTER	I _{OUT} (6-1) (Fig. 3-35)	625	521	41	533	38			

* FIGURE NO. OF PLOTTED RESULTS

\bar{x} = MEAN

σ = STANDARD DEVIATION

$\Delta\bar{x}$ = 1967-1975 CHANGE IN MEAN

$\Delta\sigma$ = 1967-1975 CHANGE IN STANDARD DEVIATION

☐ CHANGE SIGNIFICANT AT 99% CONFIDENCE LEVEL

$$t_{\bar{x}} = \frac{\Delta\bar{x}}{\sigma_{\bar{x}}} = \frac{\Delta\bar{x}}{\frac{\sigma}{\sqrt{n}}}$$

$$F_{\sigma} = \frac{\sigma_{1975}^2}{\sigma_{1967}^2}$$

t_{99} = 99% PROBABILITY LEVEL FROM
STUDENT t DISTRIBUTION

F_{99} = 99% PROBABILITY LEVEL FROM
F-DISTRIBUTION

** = NO STATISTICALLY SIGNIFICANT CHANGE -
DIFFERENCES ATTRIBUTED TO NORMAL
OBSERVATION ERROR

TABLE 3-IV SUMMARY OF V_{OUT} PARAMETER DRIFT
(TRANSISTOR PERFORMANCE)

LOGIC FUNCTION	PARAMETER *(REF)	SAMPLE SIZE N	MEASURED PERFORMANCE (mv)		1967 - 1975 CHANGE (mv)		SPECIFICATION LIMIT (mv)	ANALYSIS OF CHANGE					
			1967 TEST X	σ	1975 TEST X	σ		ΔX	Δσ	t	t ₉₉	F	F ₉₉
TWIN BUFFER	V _{OUT} (7-1) (Fig. 3-5)	250	103	17.7	107	20.7	+ 4	+ 2.4	< 300	2.4	2.3	1.3	1.4
DOUBLE GATE	V _{OUT} (6-1) (Fig. 3-17)	500	112	20.3	117	23.6	+ 5	+ 3.3	↑	3.6	2.3	1.4	1.2
4-INPUT GATE	V _{OUT} (6-1) (Fig. 3-24)	348	94	18.0	97	19.6	+ 3	+ 1.6	↑	2.1	2.3	1.2	1.3
REGISTER	V _{OUT} (5-1) (Fig. 3-36)	625	110	21.8	114	24.2	+ 4	+ 2.5	↑	3.1	2.3	1.2	1.2
EXPANDER	V _{OUT} (6-1) (Fig. 3-41)	350	138	23.5	150	32.4	+12	+ 8.9	↑	5.6	2.3	1.9	1.3
DOUBLE GATE + REGISTER	V _{OUT} (6-1) + V _{OUT} (5-1)	1125	111	21.1	116	24.0	+ 5	+ 2.9	↑	5.2	2.3	1.3	1.2

* FIGURE NO. OF PLOTTED RESULTS

\bar{X} = MEAN

σ = STANDARD DEVIATION

Δ \bar{X} = 1967-1975 CHANGE IN MEAN

Δσ = 1967-1975 CHANGE IN STANDARD DEVIATION

☐ STATISTICALLY SIGNIFICANT CHANGE AT 99% CONFIDENCE LEVEL

$$t_{\bar{X}} = \frac{\Delta \bar{X}}{\sqrt{\frac{R}{n} \left(\frac{\sigma_{67}^2}{n} + \frac{\sigma_{75}^2}{n} \right)}}$$

t₉₉ = 99% PROBABILITY LEVEL FROM STUDENT t DISTRIBUTION

$$F_{\sigma} = \frac{\sigma_{75}^2}{\sigma_{67}^2}$$

F₉₉ = 99% PROBABILITY LEVEL FROM F-DISTRIBUTION

TABLE 3-V SUMMARY OF V_{OL} PARAMETER DRIFT

LOGIC FUNCTION	PARAMETER *(REF)	SAMPLE SIZE N	MEASURED PERFORMANCE (mv)		1967 - 1975 CHANGE (mv)	SPECIFICATION LIMIT (mv)	ANALYSIS OF CHANGE	
			1967 TEST	1975 TEST			\bar{x}	σ
TWIN BUFFER	V_{OL} (7-1) Fig. 3-6	250	77.7	10.8	75.7	11.1	**	**
ADDER	V_{OL} (7-1) Fig. 3-12	250	54.3	7.1	57.4	6.1	**	**
DOUBLE GATE	V_{OL} (6-1) Fig. 3-18	500	88.8	14.0	89.5	14.7	**	**
4-INPUT GATE	V_{OL} (7-1) Fig. 3-19	500	89.5	14.1	90.7	15.0	**	**
HALF ADDER	V_{OL} (6-1) Fig. 3-25	348	73.9	11.1	74.1	11.4	**	**
REGISTER	V_{OL} (6) Fig. 3-31	250	93.5	13.8	91.9	13.9	**	**
EXPANDER	V_{OL} (6-1) Fig. 3-37	625	89.2	14.8	90.5	15.7	**	**
	V_{OL} (6-1) Fig. 3-42	350	111.8	15.0	113.8	16.0	**	**
	V_{OL} (7-1) Fig. 3-43	350	112.7	14.8	115.3	16.0	**	**

* FIGURE NO. OF PLOTTED RESULTS

\bar{x} = MEAN

σ = STANDARD DEVIATION

$\Delta\bar{x}$ = 1967-1975 CHANGE IN MEAN

$\Delta\sigma$ = 1967-1975 CHANGE IN STANDARD DEVIATION

CHANGE SIGNIFICANT AT 99% CONFIDENCE LEVEL

$$t_{\bar{x}} = \frac{\Delta\bar{x}}{\sigma_{67}} \sqrt{\frac{N}{2 + \sigma_{75}^2}}$$

t_{99} = 99% PROBABILITY LEVEL FROM STUDENT t DISTRIBUTION

$$F_{\sigma} = \frac{\sigma_{75}^2}{\sigma_{67}^2}$$

F_{99} = 99% PROBABILITY LEVEL FROM F-DISTRIBUTION

** = NO STATISTICALLY SIGNIFICANT CHANGE - DIFFERENCES ATTRIBUTED TO NORMAL OBSERVATION ERROR

TABLE 3-VI SUMMARY OF I_{RT} PARAMETER DRIFT

LOGIC FUNCTION	PARAMETER *(REF)	SAMPLE SIZE N	MEASURED PERFORMANCE (µa)		1967 - 1975 CHANGE (µa)		SPECIFICATION LIMIT (µa)	ANALYSIS OF CHANGE			
			1967 TEST X	1975 TEST σ	ΔX	Δσ		t \bar{x}	X	t ₉₉	F _σ
TWIN BUFFER	I _{RT} (1-2) (Fig. 3-7)	250	0.013	0.017	0.026	0.035	<1	**	**	**	**
			0.012	0.016	0.010	0.015					
ADDER	I _{RT} (3-5) (Fig. 3-8)	250	0.012	0.017	0.022	0.022					
			0.012	0.017	0.022	0.022					
DOUBLE GATE	I _{RT} (1,2,3,5) (Fig. 3-13)	500	0.019	0.019	0.014	0.017					
			0.019	0.019	0.014	0.017					
4-INPUT GATE	I _{RT} (Fig. 3-20)	348	0.005	0.005	0.008	0.004					
			0.005	0.005	0.008	0.004					
HALF ADDER	I _{RT} (Fig. 3-26)	250	0.018	0.021	0.019	0.024					
			0.018	0.021	0.019	0.024					
REGISTER	I _{RT} (Fig. 3-38)	625	0.053	0.032	0.017	0.021					
			0.053	0.032	0.017	0.021					
EXPANDER	I _{RT} (Fig. 3-44)	350	0.006	0.002	0.001	0.001					
			0.006	0.002	0.001	0.001					

* FIGURE NO. OF PLOTTED RESULTS

\bar{X} = MEAN

σ = STANDARD DEVIATION

$\Delta\bar{X}$ = 1967-1975 CHANGE IN MEAN

$\Delta\sigma$ = 1967-1975 CHANGE IN STANDARD DEVIATION

$$t_{\bar{x}} = \frac{\Delta\bar{X}}{\sigma_{\bar{x}}} = \frac{\Delta\bar{X}}{\sqrt{\frac{\sigma_{67}^2}{N} + \sigma_{75}^2}}$$

$$F_{\sigma} = \frac{\sigma_{75}^2}{\sigma_{67}^2}$$

t₉₉ = 99% PROBABILITY LEVEL FROM STUDENT t DISTRIBUTION

F₉₉ = 99% PROBABILITY LEVEL FROM F-DISTRIBUTION

** = NO MEANINGFUL CHANGE - MEASURED CHANGES ATTRIBUTED TO DIFFERENCES IN TEST

TABLE 3-VII SUMMARY OF I_L PARAMETER DRIFT

LOGIC FUNCTION	PARAMETER *(REF)	SAMPLE SIZE N	MEASURED PERFORMANCE (μa)				1967 - 1975 CHANGE (μa)		SPECIFICATION LIMIT (μa)	ANALYSIS OF CHANGE			
			1967 TEST		1975 TEST		ΔX	$\Delta \sigma$		\bar{x}	t_{99}	F_{99}	σ
			\bar{x}	σ	\bar{x}	σ							
TWIN BUFFER	I_L (8) (Fig. 3-9)	250	0.4	0.4	2.3	1.3	**	**	<200	**	**	**	**
ADDER	I_L (8) (Fig. 3-14)	250	0.60	1.2	1.92	1.2			<100				
COUBLE GATE	I_L (8) (Fig. 3-21)	500	6.30	0.13	1.52	0.11			<100				
4-INPUT GATE	I_L (8) (Fig. 3-27)	348	0.41	1.11	1.61	1.06			<100				
HALF ADDER	I_L (8) (Fig. 3-33)	250	0.7	2.2	0.2	0.2			<100				
REGISTER	I_L (8) (Fig. 3-39)	625	1.4	2.1	0.2	0.2			<100				
EXPANDER	I_L (8) (Fig. 3-45)	350	0.30	0.002	0.13	0.06			<100				

* FIGURE NO. OF PLOTTED RESULTS

\bar{x} = MEAN

σ = STANDARD DEVIATION

$\Delta \bar{x}$ = 1967-1975 CHANGE IN MEAN

$\Delta \sigma$ = 1967-1975 CHANGE IN STANDARD DEVIATION

$$t_{\bar{x}} = \frac{\Delta \bar{x}}{\sigma_{\bar{x}}} = \frac{\Delta \bar{x}}{\sqrt{\frac{\sigma_{67}^2}{N} + \sigma_{75}^2}}$$

$$F_{\sigma} = \frac{\sigma_{75}^2}{\sigma_{67}^2}$$

** = NO MEANINGFUL CHANGE - MEASURED CHANGES ATTRIBUTED TO DIFFERENCES IN TEST PROCEDURES

t_{99} = 99% PROBABILITY LEVEL FROM STUDENT t DISTRIBUTION

F_{99} = 99% PROBABILITY LEVEL FROM F-DISTRIBUTION

TABLE 3-VIII SUMMARY OF I_{CEX} PARAMETER DRIFT

LOGIC FUNCTION	PARAMETER *(REF)	SAMPLE SIZE N	MEASURED PERFORMANCE (µa)		1967 - 1975 CHANGE (µa)		SPECIFICATION LIMIT (µa)	ANALYSIS OF CHANGE					
			1967 TEST X	σ	1975 TEST X	σ		ΔX	Δσ	t ₉₉	F _σ	F ₉₉	
EXPANDER	I _{CEX} (7) (Fig. 3-46)	350	0.68	0.43	0.58	0.37	**	**	**	**	**	**	**

* FIGURE NO. OF PLOTTED RESULTS

\bar{X} = MEAN

σ = STANDARD DEVIATION

Δ \bar{X} = 1967-1975 CHANGE IN MEAN

Δσ = 1967-1975 CHANGE IN STANDARD DEVIATION

$$t_{\bar{X}} = \frac{\Delta \bar{X} \sqrt{N}}{\sqrt{\sigma_{67}^2 + \sigma_{75}^2}}$$

$$F_{\sigma} = \frac{\sigma_{75}^2}{\sigma_{67}^2}$$

t₉₉ = 99% PROBABILITY LEVEL FROM STUDENT t DISTRIBUTION

F₉₉ = 99% PROBABILITY LEVEL FROM F-DISTRIBUTION

** = NO MEANINGFUL CHANGE - MEASURED CHANGES ATTRIBUTED TO DIFFERENCES IN TEST

3.1 (Continued)

Linear parameter drift rate models were developed for the Double Gate plus Register combined and the Expander. The Expander model has already been discussed in Section 1.1, Figure 1-4. The Double Gate/Register Model is plotted in Figure 3-1. The linear drift rate predicted for an average part is 1/2% per year, and for a -3σ part is 1% per year. These rates are about half those predicted for the Expander.

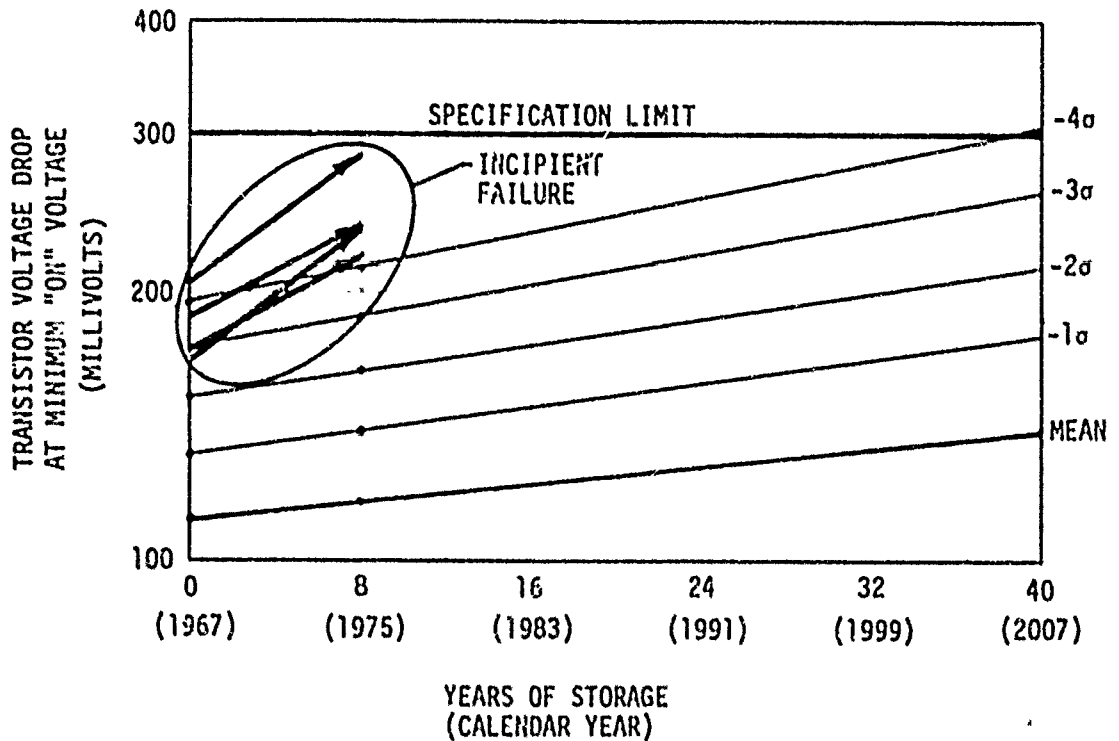


Figure 3-1. LINEAR PARAMETER DRIFT MODEL FOR DOUBLE GATE PLUS REGISTER

The four incipient failures from the Double Gate family are shown by the arrows in the figure. As was the case with the Expander, these incipient failures show a more rapid rate of drift than the linear model predicts for even a -4σ part. Extrapolating the linear model suggests that a -4σ part would not reach the 300mV specification limit until the turn of the century. The one -4σ incipient failure (uppermost arrow in the figure) has almost reached this limit after only eight years of storage.

3.1 (Continued)

A reason why parts with high V_{OUT} measurements should show the highest rates of drift can be deduced from Figure 3-2, which is a plot of V_{OUT} vs transistor gain. For above average (high gain, low V_{OUT}) parts, V_{OUT} is relatively insensitive to changes in transistor gain. A $+2\sigma$ part ($V_{OUT} < 71$ MV) shows only a 4 MV (5%) change in V_{OUT} for a 10% change in gain. For below average parts, however, V_{OUT} becomes increasingly sensitive to changes in gain. A -4σ part ($V_{OUT} > 193$ MV) shows a 36 MV (20%) change in V_{OUT} for a 10% change in gain. Transistor gain changes can occur because of growth of a "parasitic transistor" condition due to surface contamination, or to migration of the gold within the silicon lattice. Gold doping was used in these parts to suppress the parasitic transistor condition as well as to increase part reaction speed. These gain change mechanisms are discussed further in Section 4.

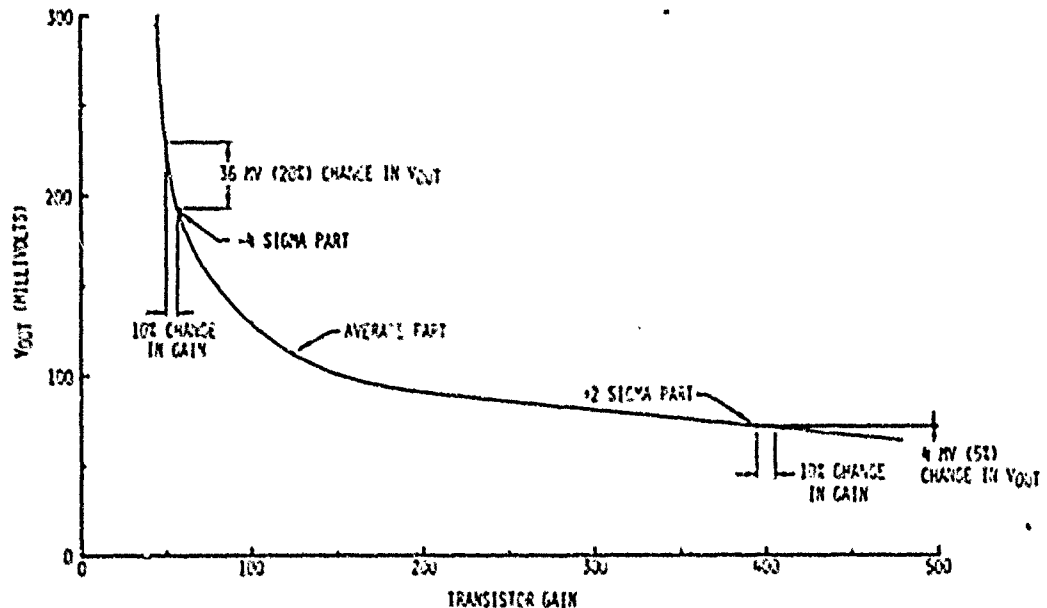


FIGURE 3-2. V_{OUT} PARAMETER VS. TRANSISTOR GAIN FOR DOUBLE GATE DEVICES

There were 24 parts out of the 2573 parts tested that showed large enough increases in V_{OUT} to class them as incipient failures. These parts are identified in Table 3-IX. As noted in Section 1.1, the V_{OUT} tests were performed on a 1/8 sample of the total part - output terminal population. Consequently, it is likely that approximately 200 incipient failures exist in the total of 10,027 parts.

The criteria for identifying a part as an "incipient failure" are: (1) the 1975 V_{OUT} value must exceed 220mv, and (2) the 1967-1975 increase in V_{OUT} must exceed 25mv. Of these 24 parts, all but one fell outside the -1σ limit during the 1967 tests. The lone exception is Part No. 1172 of the Expander family. Furthermore, all but 7 of the parts came from beyond the -2σ limit. These seven exceptions are also from the Expander Family (Part Nos. 1027, 1055, 1129, 1147, 1155, 1172, and 1201). *These statistics show that the shelf life of these parts could be significantly enhanced by rejecting parts whose performance falls more than one standard deviation below the mean. This would mean rejecting about 16% of the parts.*

3.1 (Continued)

TABLE 3-IX. INCIPIENT FAILURES

LOGIC FUNCTION	PART NO.	PARAMETER	TEST VALUE (mv)		PERCENT CHANGE	SPECIFICATION LIMIT (mv)
			1967	1975		
TWIN BUFFER	349	$V_{out}(7-1)$	161	229	42	200
	815	"	155	251	62	
	825	"	149	235	58	
	*945	"	172	295	70	
	*1229	"	165	231	40	
ALFIER DOUBLE GATE	N656					
	597	$V_{out}(6-1)$	169	238	40	
	*831	$V_{out}(7-1)$	184	238	28	
	1968	$V_{out}(6-1)$	172	250	28	
	*2452	$V_{out}(6-2)$	204	282	38	
4 INPUT GATE	*153	$V_{out}(6-4)$	178	227	56	
	N657					
HALF ADDER REGISTER	N658					
	N659					
EXPANDER	1027	$V_{out}(6-1)$	172	238	38	
	1055	$V_{out}(6-1)$	174	264	52	
	*1057	$V_{out}(6-2)$	192	226	14	
	1093	$V_{out}(6-1)$	196	225	15	
	1123	"	189	247	31	
	1129	"	180	237	32	
	1147	"	178	224	26	
	1155	"	179	244	42	
	1160	"	169	228	20	
	1172	"	164	256	185	
	1201	"	183	229	25	
	1220	"	175	232	18	
	1232	"	186	252	35	
	1267	"	192	249	28	

* PARTS REJECTED AS "OUT OF SPEC" DURING GO/NO-GO TEST, BUT FOUND TO BE WITHIN SPEC DURING LABORATORY CONTROLLED BENCH TEST. THESE MARGINAL PARTS WERE FOUND TO BE HIGHLY SENSITIVE TO TEMPERATURE. WARMING BY FINGERS (SUCH AS COULD OCCUR DURING INSERTION INTO TEST FIXTURE) COULD CAUSE PART TO FAIL DURING ROOM TEMPERATURE SPEC.

3.2 HISTOGRAM COMPARISONS

The results of the 1967 and 1975 Parameter Drift measurements have been plotted on common scales in Figures 3-3 through 3-16 for visual evaluation of storage induced changes. Each plot presents results from a single parameter test on a single Logic Function family of parts. For example, Figure 3-3 shows the $I_{IN}(3)$ measurements for the Twin Buffer devices. The remaining plots follow in the order defined in Table 3-1. Each figure contains the following information:

- a) a schematic showing the test conditions used to measure the parameter. The physical elements (specific resistors and transistors) being measured have been circled on the schematic.
- b) the 1967 measured performance distribution or histogram (dashed line) plotted on top of the histogram of 1975 test results (solid line). Appearing above this figure is a table of mean values and standard deviations associated with the 1967 and 1975 test results. The Delta values apply to item (c) described below.
- c) a histogram of the 1967-1975 changes in individual part performance. Parts that have drifted closer to specification limits (degraded) appear along the negative axis.

Each histogram comparison has been technically evaluated to determine whether the 1967-1975 changes can be attributed to normal measurement differences or whether parameter drift has actually occurred. Each of these leaves its own signature in the histograms. Measurement differences include: (1) a bias, or shift in mean value, due to a small difference in the test set up, and (2) random sampling errors due to the limited precision to which each parameter is measured. The latter will tend to have a normal, or bell-shaped distribution.

When measurement differences are present, the 1975 histogram will have a shape very similar to the 1967 histogram, but may be shifted to the right or left. The 1967-1975 change histogram will show a near-normal distribution about a mean value equal to the bias between the two test measurements.

Where significant parameter drift has occurred, the 1975 histogram will tend to be skewed, or stretched closer to the specification limit than the 1967 histogram. The mean value also may have shifted toward the spec limit although there may be little change in the above average parts. Since the below average parts tend to drift more rapidly than the better performers, the 1967-1975 change histogram will not be bell-shaped, but will show a pronounced skewness in the negative (degraded performance) direction.

The criteria discussed above have been used to evaluate the histogram comparisons. These evaluations appear in Tables 3-X through 3-XVI. These seven tables cover the seven families of logic function devices, starting with the Twin Buffer, Table 3-X. The remaining six tables immediately precede the histogram plots for the other six logic function devices.

The histogram plots confirm the assessments already made from the Summary Tables (Tables 3-II through 3-VIII). In fact, evaluation

3.2 HISTOGRAM COMPARISONS (Continued)

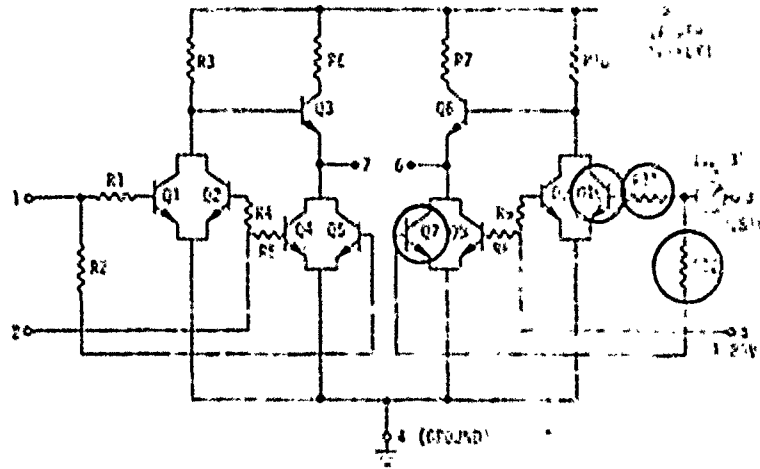
of the histograms sometimes shows that drift has occurred in parameters that did not exceed the conservative 99% confidence criterion used in the statistical tests. The I_{QH} (Resistance) measurements still show no clear evidence of drift. The most sensitive transistor parameter, V_{OUT} , shows drift on each logic function device, with significant drift occurring on the Double Gate, Register, and Expander. These are the three devices that showed drift at the 99% confidence level. In all cases, drift is most pronounced in the below-average parts. The less sensitive transistor performance parameters, I_{IN} , and V_{OL} , suggest that drift has occurred on some of the devices, but the magnitude is small and difficult to separate from the measurement differences. The best indications of drift on these parameters appears in the below average parts from the Double Gate, Register, and Expander families.

The I_L , I_{RT} , and I_{CEX} measurements made in 1967 were not carried out to the nanoamp precision required to quantitatively evaluate leakage current drift. However, they were sufficiently accurate to state with confidence that significant drift in leakage characteristics did not occur. Because of their greater precision, the 1975 tests showed the leakage rates actually to be lower in some devices than the 1967 measurements indicated.

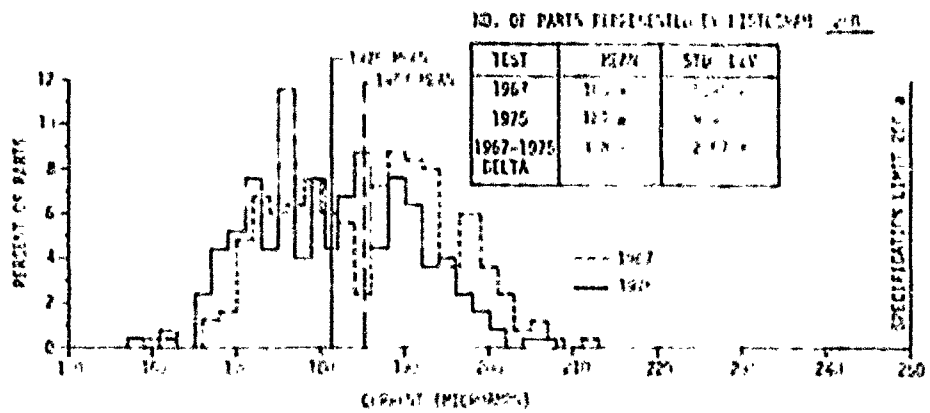
TABLE 3-X. EVALUATION OF HISTOGRAM COMPARISONS FOR THE TWIN BUFFER

PARAMETER (FIGURE NO.)	* TRENDS OBSERVED IN HISTOGRAM COMPARISONS						TECHNICAL ASSESSMENT
	1967 - 1975 HISTOGRAMS SIMILAR IN SHAPE	SMALL SHIFT IN MEAN ATTRIBUTABLE TO MEASUREMENT DIFFERENCES	NEAR NORMAL DISTRIBUTION OF 1967-1975 CHANGES	1975 HISTOGRAM SHIFTS AND SPEC LIMIT	SHIFT IN 1975 MEAN TOWARD DEGRADED PERFORMANCE	DISTRIBUTION OF 1967-1975 CHANGES SKewed TOWARD DEGRADATION	
I_{IN} (3)	✓	✓	✓				NO MEASURABLE DRIFT
I_{OUT} (3-3)	✓	✓	✓				NO MEASURABLE DRIFT
V_{OUT} (7-1)				✓	✓	✓	MODERATE DRIFT
V_{OL} (3-6)	✓	✓	✓				NO MEASURABLE DRIFT
I_{RT} (1-2)	✓	✓	✓				NO SIGNIFICANT DRIFT
I_{RT} (3-5)	✓	✓	✓				NO SIGNIFICANT DRIFT
I_L (3-8)	✓	✓	✓				NO SIGNIFICANT DRIFT
I_L (3-9)	✓	✓	✓				NO SIGNIFICANT DRIFT

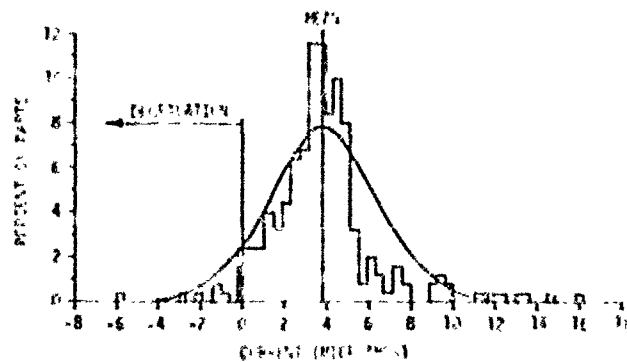
*NOTE: CHECKS APPEARING IN FIRST THREE COLUMNS SUPPORT CONCLUSION THAT DIFFERENCES ARE DUE TO NORMAL MEASUREMENT ERRORS; CHECKS IN LAST THREE COLUMNS SUPPORT CONCLUSION THAT DIFFERENCES ARE DUE TO PARAMETER DRIFT



a. SCHEMATIC FOR I_{IN} TEST (R1 + R2 RESISTANCE + Q1 + Q2 USE EXACTLY CHECK AT SATURATION VOLTAGE)



b. DISTRIBUTION OF PARTS: 1975 VS 1967 TEST

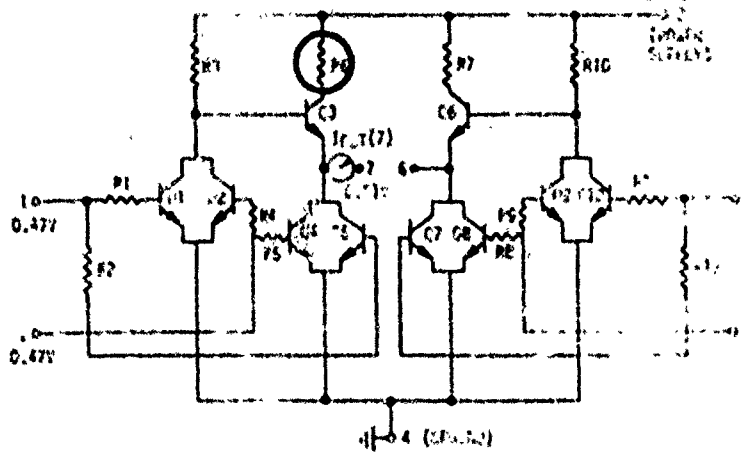


c. 1967 - 1975 CHANGE IN I_{IN}

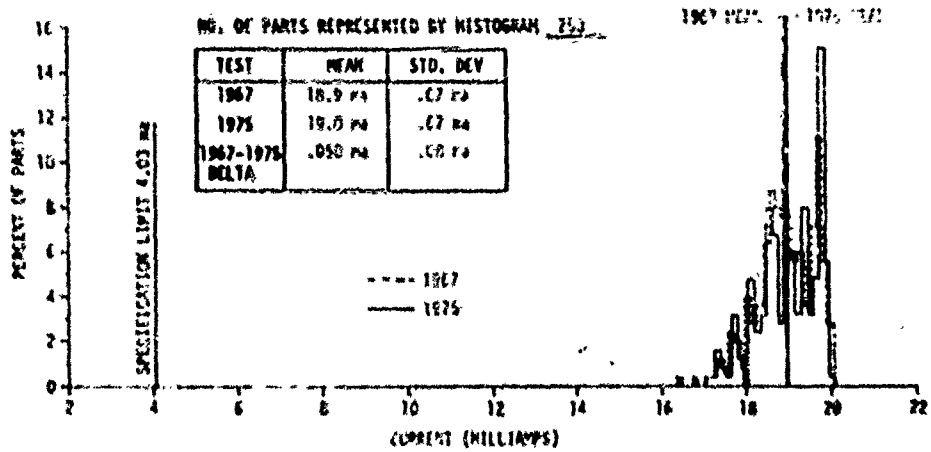
FIGURE 3-2. HISTOGRAM COMPARISON OF I_{IN}

- T. H. LOFFER -

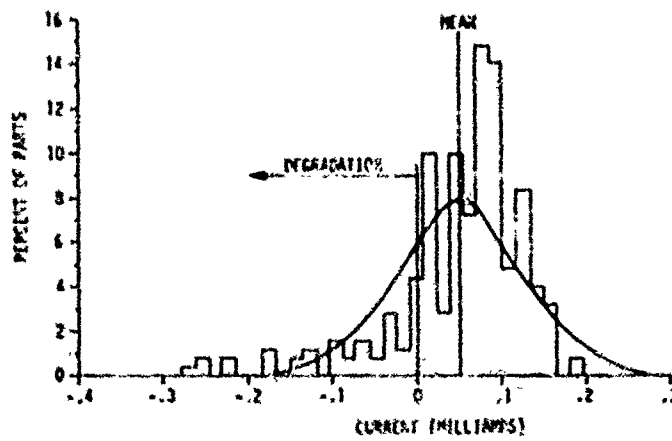
D756-10002-1



a. SCHEMATIC FOR I_{OUT}(7) TEST (R_g RESISTANCE CHECK)



b. DISTRIBUTION OF PARTS: 1975 VS 1967 TEST

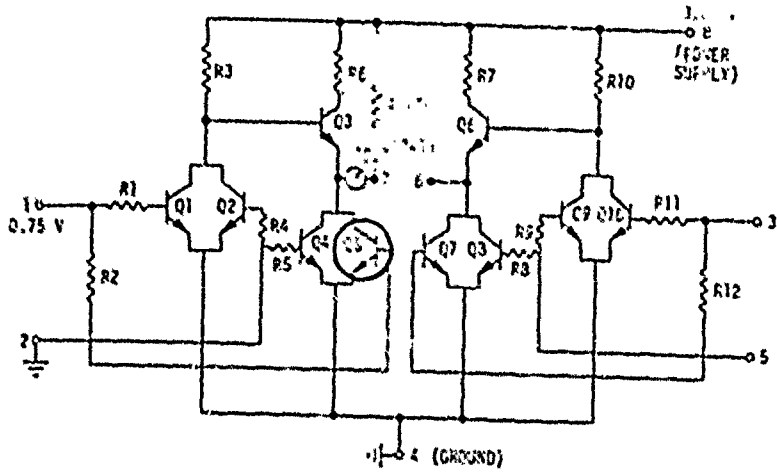


c. 1967-1975 CHANGE IN I_{OUT}(7)

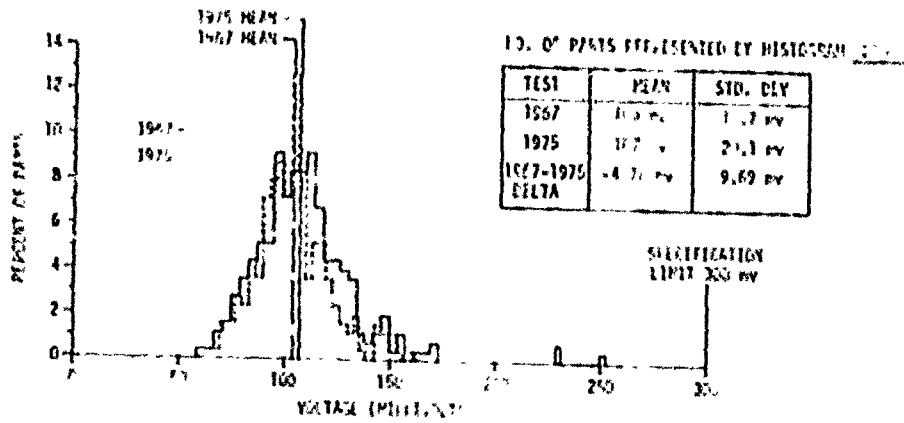
FIGURE 3-4. HISTOGRAM COMPARISON OF I_{OUT}(7)

- TWIN SUFFER -

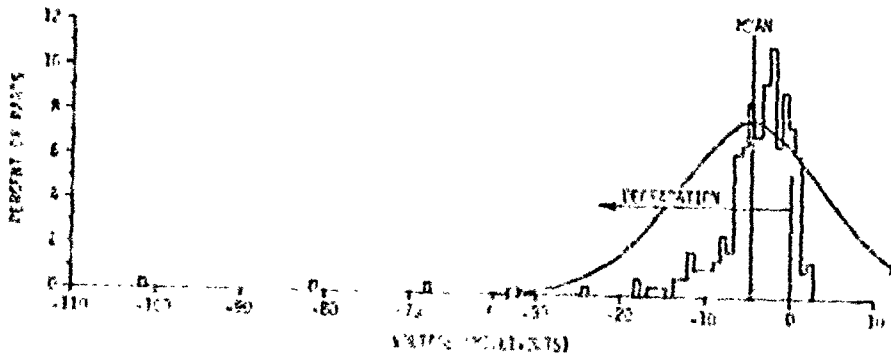
D23-16022-1



a. SCHEMATIC FOR $V_{OUT(7-11)}$ TEST (CS) (TAPE DROP AT MINIMUM "ON" CONDITION)



b. DISTRIBUTION OF PARTS: 1975 VS 1967 TEST

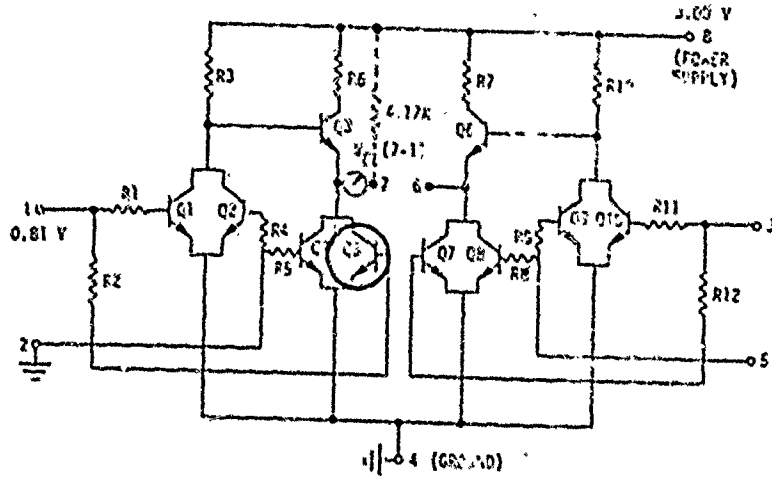


c. 1967 - 1975 CHANGE IN $V_{OUT(7-11)}$

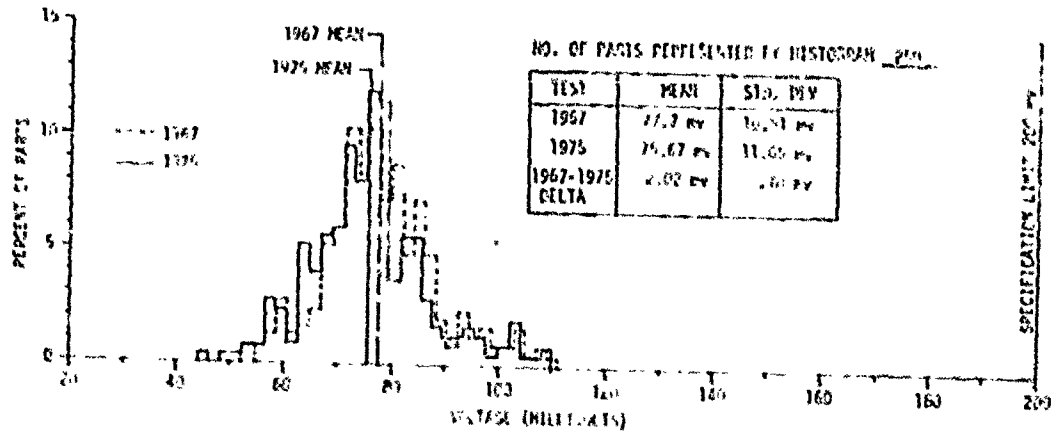
FIGURE 3-5 HISTOGRAM COMPARISON OF $V_{OUT(7-11)}$

- TWIN BUFFER -

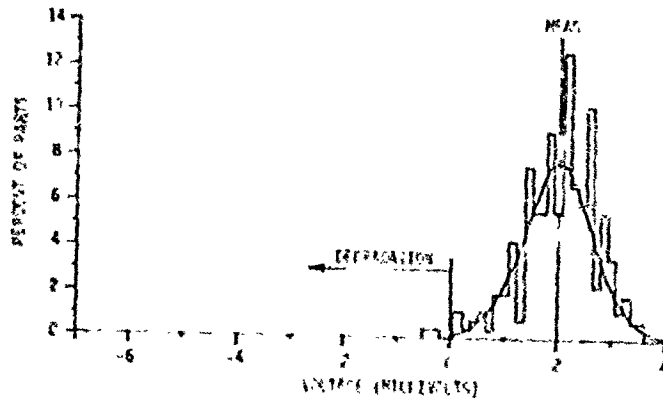
0256-10922-1



a. SCHEMATIC FOR V_{OL} (7-II) TEST (CS VOLTAGE DROP AT SATURATION)



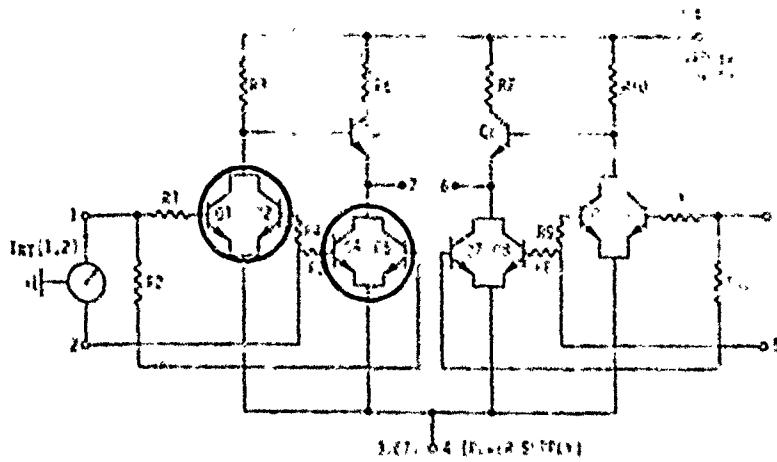
b. DISTRIBUTION OF PARTS: 1975 VS 1967 TEST



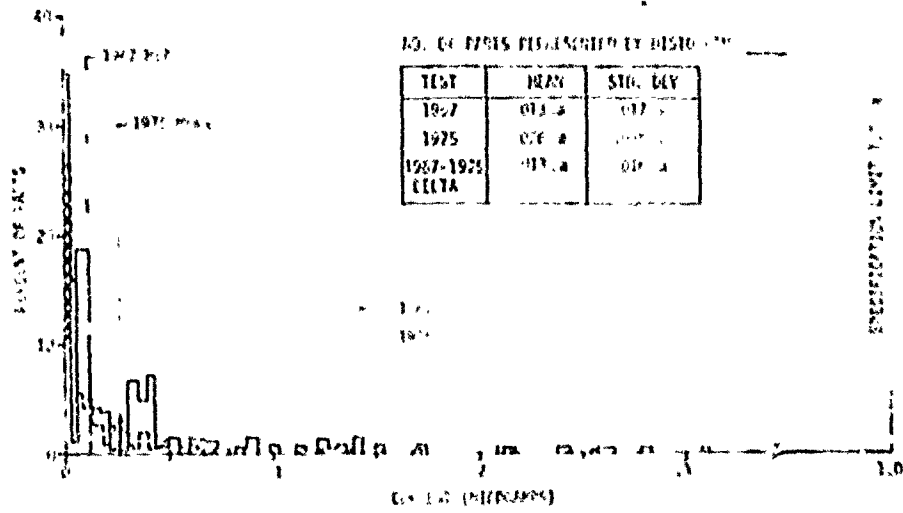
c. 1967 - 1975 CHANGE IN V_{OL} (7-II)

FIGURE 3-a HISTOGRAM COMPARISON OF V_{OL} (7-II)

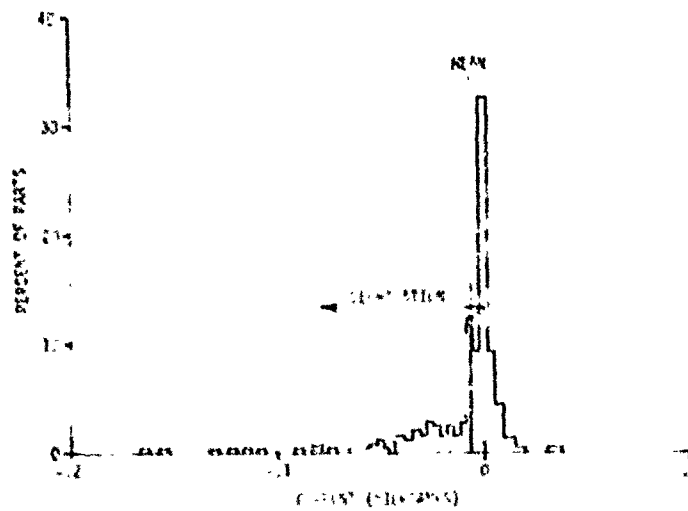
-TWIN BUFFER-



a. SCHEMATIC FOR IRT(1,2) TEST (Q1+Q2+R4+C5 BASE EMITTER JUNCTION LEAKAGE CURRENT)

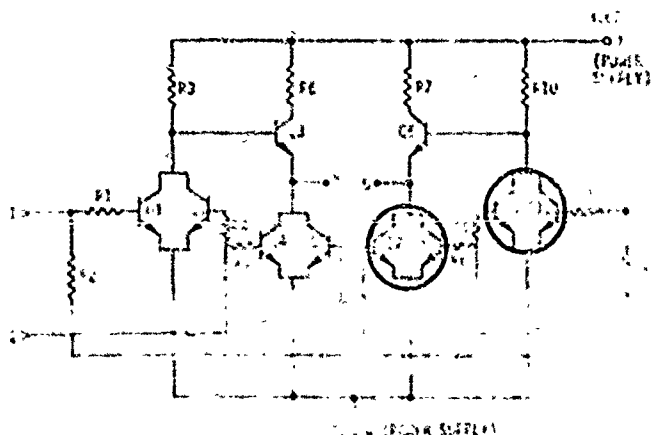


b. DISTRIBUTION OF PARTS: 1975 VS 1967 TEST

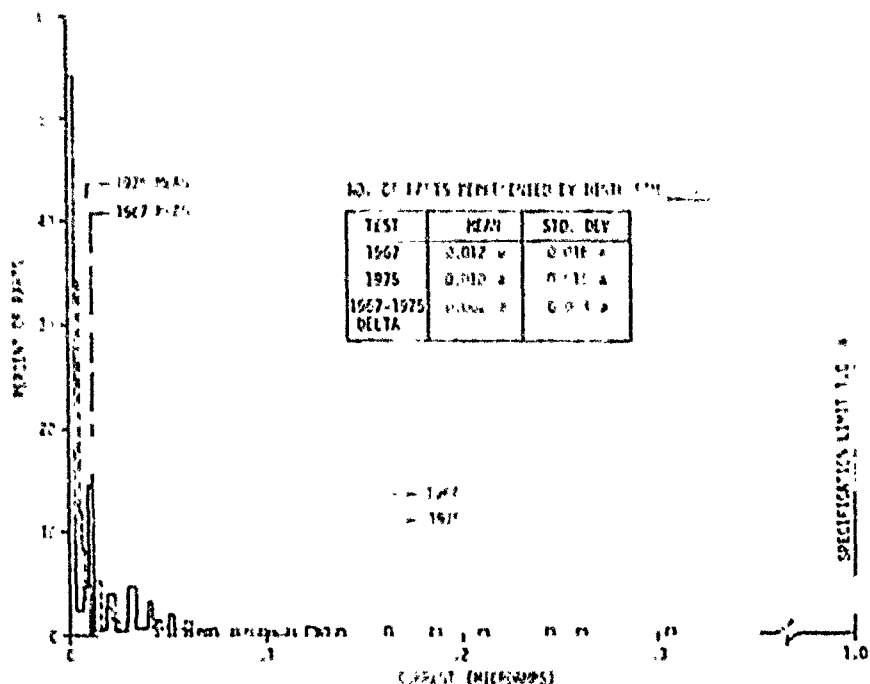


c. 1967-1975 CHANGE IN IRT(1,2)

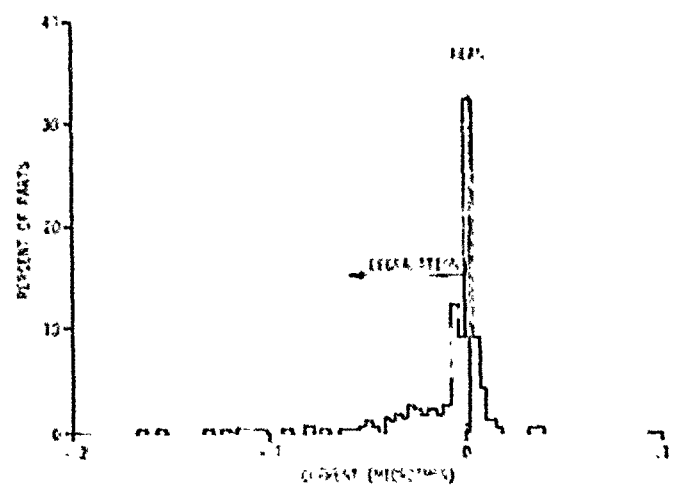
FIGURE 3-7 HISTOGRAM COMPARISON OF IRT(1,2) TWIN BUFFER 3-20



a. SCHEMATIC FOR IRT(3,5) TEST (R7-C6-C9-C10 BASE EMITTER JUNCTION LEAKAGE CURRENT)

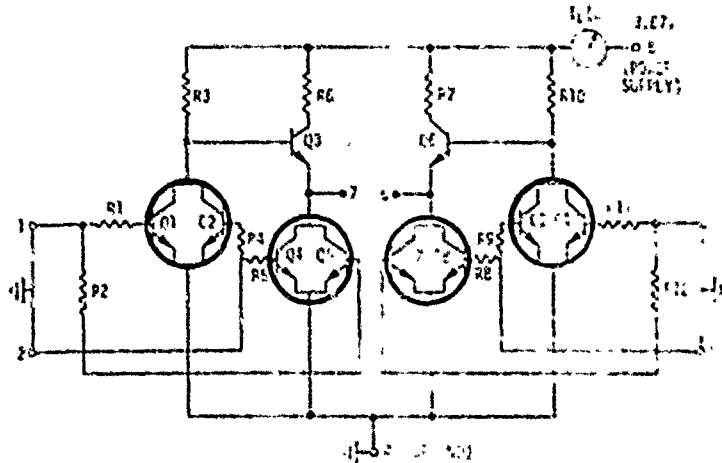


b. DISTRIBUTION OF PARTS; 1975 VS 1967 TEST

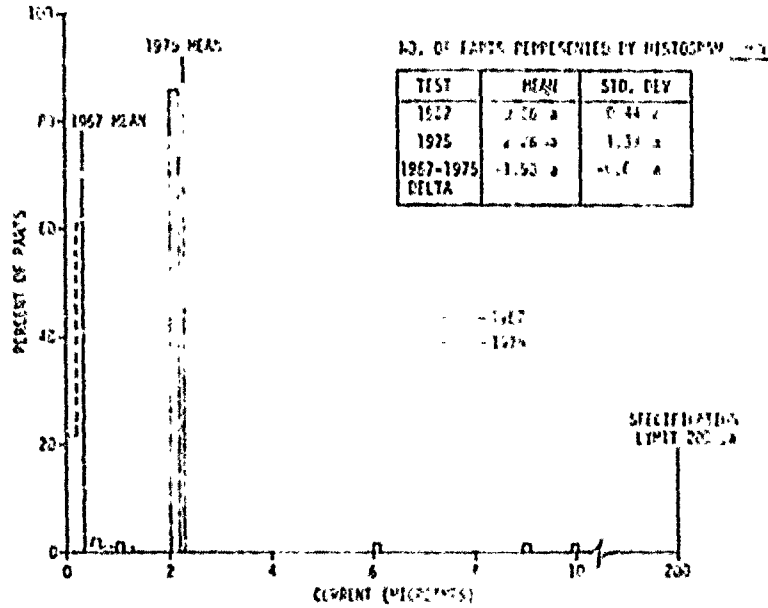


c. 1967-1975 CHANGE IN IRT(3,5)

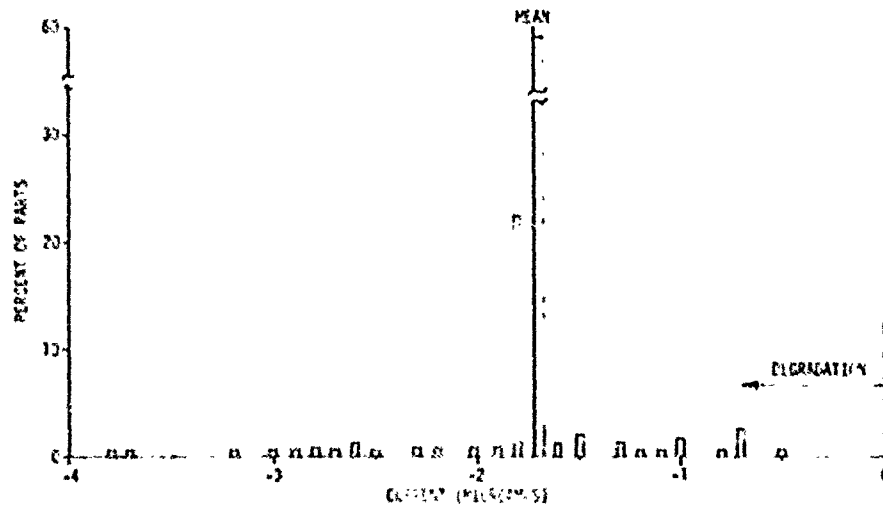
FIGURE 3-8 HISTOGRAM COMPARISON OF IRT(3,5) TWIN BUFFER



a. SCHEMATIC FOR $I_L(I)$ TEST ($I_{C1}+I_{C2}+I_{C4}+I_{Q1}+I_{Q2}+I_{Q3}+I_{Q4}+I_{C3}+I_{C10}$ LEAKAGE CURRENT)



b. DISTRIBUTION OF PARTS: 1975 VS. 1967 TEST



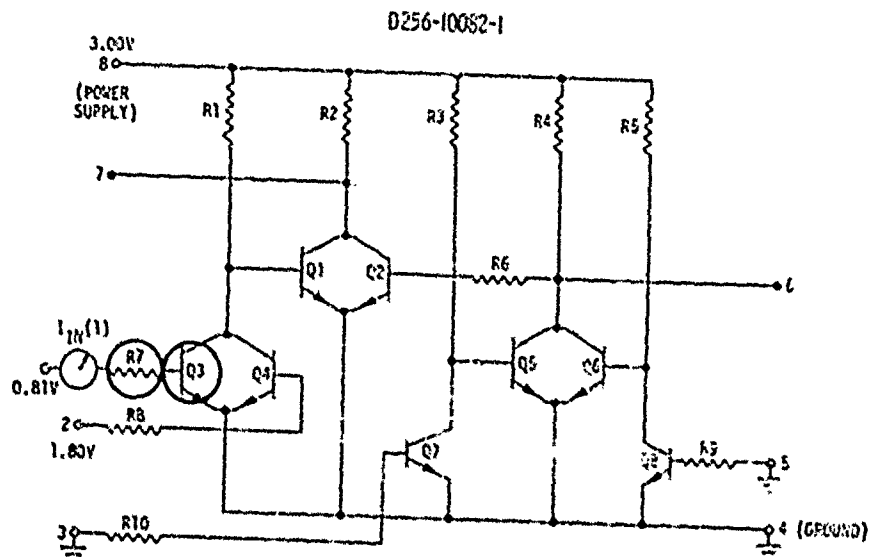
c. 1967-1975 CHANGE IN $I_L(I)$

FIGURE 3-9. HISTOGRAM COMPARISON OF $I_L(I)$ TWIN BUFFER

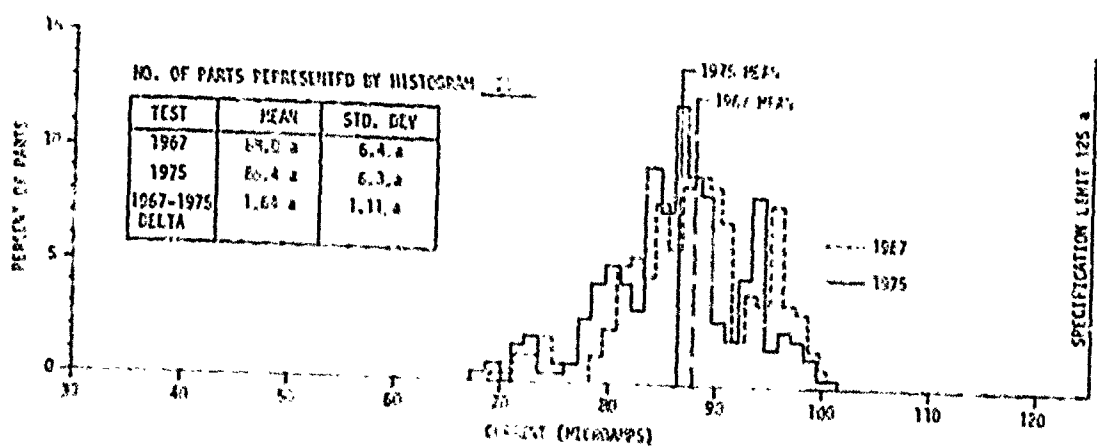
TABLE 3-XI. EVALUATION OF HISTOGRAM COMPARISONS FOR THE ADDER

PARAMETER (FIGURE NO.)	* TRENDS OBSERVED IN HISTOGRAM COMPARISONS										TECHNICAL ASSESSMENT
	TYPICAL MEASUREMENT DIFFERENCES					TYPICAL PARAMETER DRIFT					
	1967 - 1975 HISTOGRAMS SIMILAR IN SHAPE	SMALL SHIFT IN MEAN ATTRIBUTABLE TO MEASUREMENT DIFFERENCES	NEAR NORMAL DISTRIBUTION OF 1967-1975 CHANGES	1975 HISTOGRAM SKEWED AND SPEC LIMIT	SHIFT IN 1975 MEAN TOWARD PLOWBACK	DISTRIBUTION OF 1967-1975 CHANGES SKEWED TOWARD DEGRADATION					
$I_{IN}(1)$ (3-10)	///	///	///	///	///	///	///	///	///	///	NO MEASURABLE DRIFT
$I_{OUT}(6)$ (3-11)	///	///	///	///	///	///	///	///	///	///	NO MEASURABLE DRIFT
$I_{OUT}(7-1)$ (3-11a)	///	///	///	///	///	///	///	///	///	///	NO MEASURABLE DRIFT
$V_{OL}(7-1)$ (3-12)	///	///	///	///	///	///	///	///	///	///	NO MEASURABLE DRIFT
$I_{RT}(1,2,3,5)$ (3-13)	///	///	///	///	///	///	///	///	///	///	NO SIGNIFICANT DRIFT
$I_L(8)$ (3-14)	///	///	///	///	///	///	///	///	///	///	NO SIGNIFICANT DRIFT

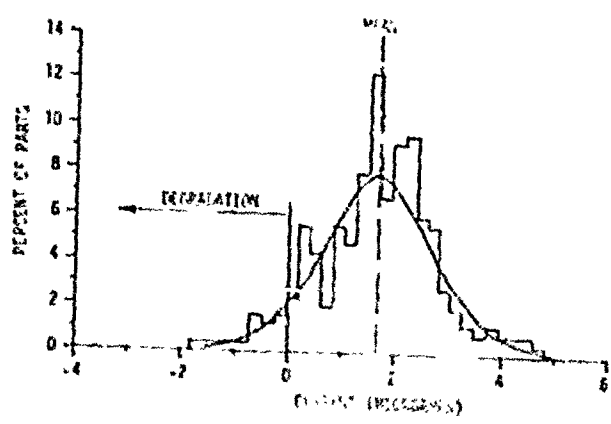
*NOTE: CHECKS APPEARING IN FIRST THREE COLUMNS SUPPORT CONCLUSION THAT DIFFERENCES ARE DUE TO NORMAL MEASUREMENT ERRORS; CHECKS IN LAST THREE COLUMNS SUPPORT CONCLUSION THAT DIFFERENCES ARE DUE TO PARAMETER DRIFT



a. SCHEMATIC FOR $I_{IN(II)}$ TEST (R7 RESISTANCE AND Q3 BASE EMITTER CHECK AT SATURATION VOLTAGE)



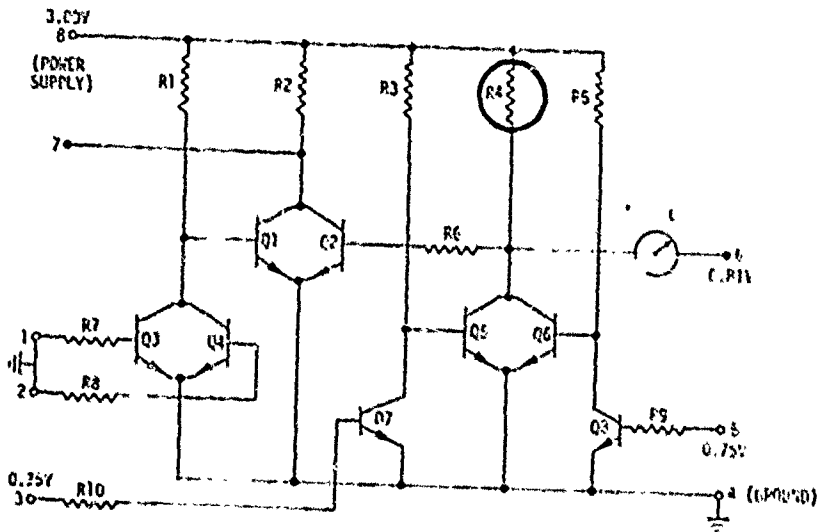
b. DISTRIBUTION OF PARTS: 1975 VS 1967 TEST



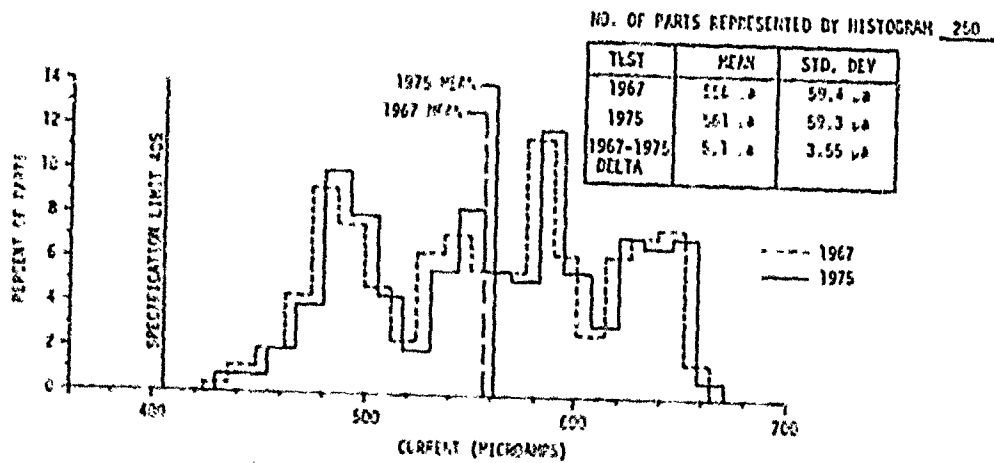
c. 1967 - 1975 CHANGE IN $I_{IN(II)}$

FIGURE 3-12. HISTOGRAM COMPARISON OF $I_{IN(II)}$

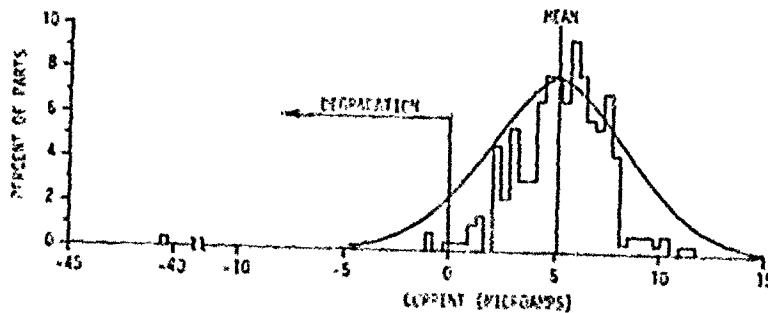
0250-10082-1



a. SCHEMATIC FOR IOUT(6) TEST (R4 RESISTANCE CHECK)



b. DISTRIBUTION OF PARTS: 1975 VS 1967 TEST

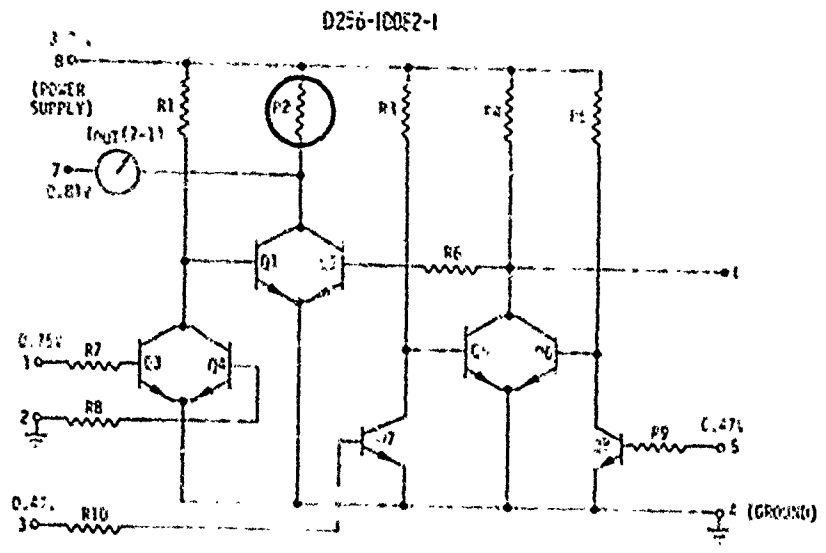


c. 1967-1975 CHANGE IN IOUT(6)

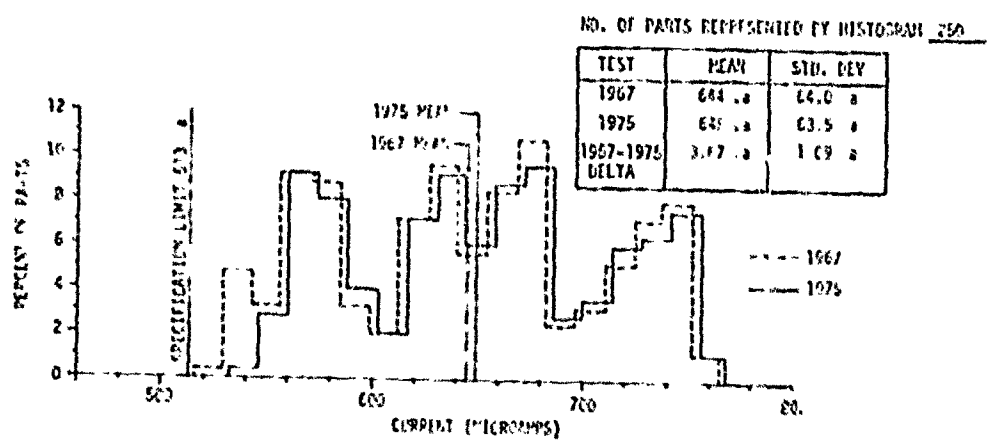
FIGURE 3-II. HISTOGRAM COMPARISON OF IOUT(6)

AUDER

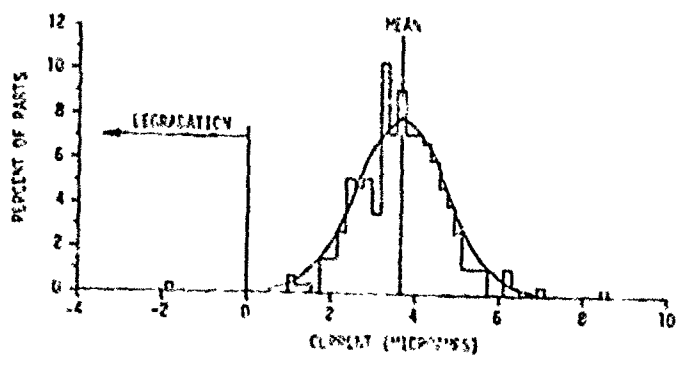
3-25



a. SCHEMATIC FOR IOUT(7-II) TEST (R₂ RESISTANCE CHECK)



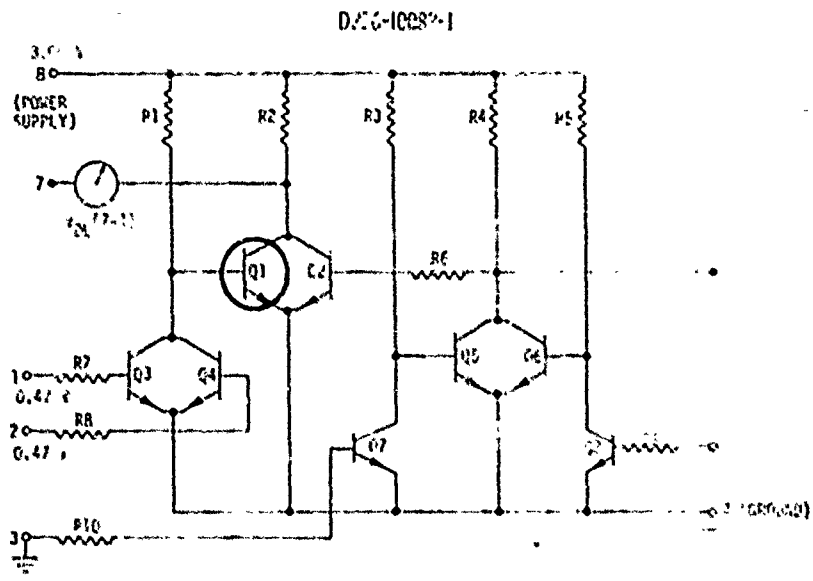
b. DISTRIBUTION OF PARTS: 1975 VS 1967 TEST



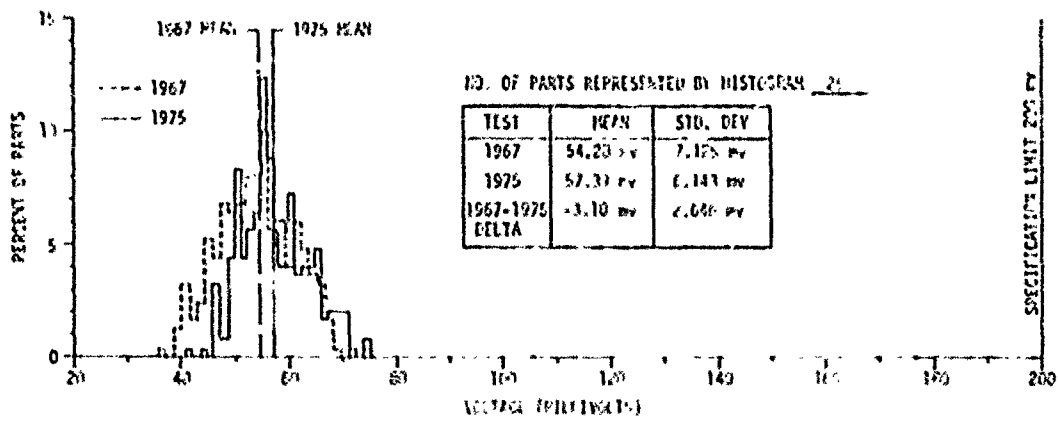
c. 1967-1975 CHANGE IN IOUT(7-II)

FIGURE 3-11 a. HISTOGRAM COMPARISON OF IOUT(7-II)

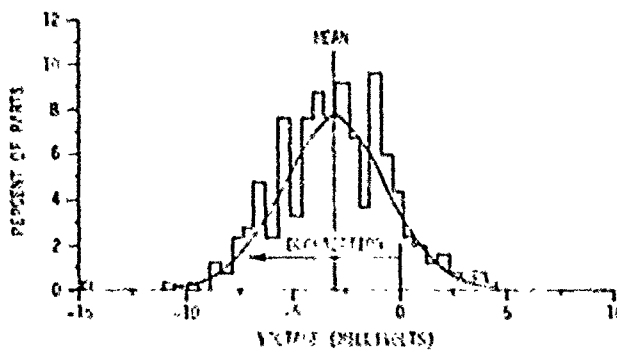
ADDFR



a. SCHEMATIC FOR V_{OL} (7-II) TEST (CI VOLTAGE DROP AT SATURATION)



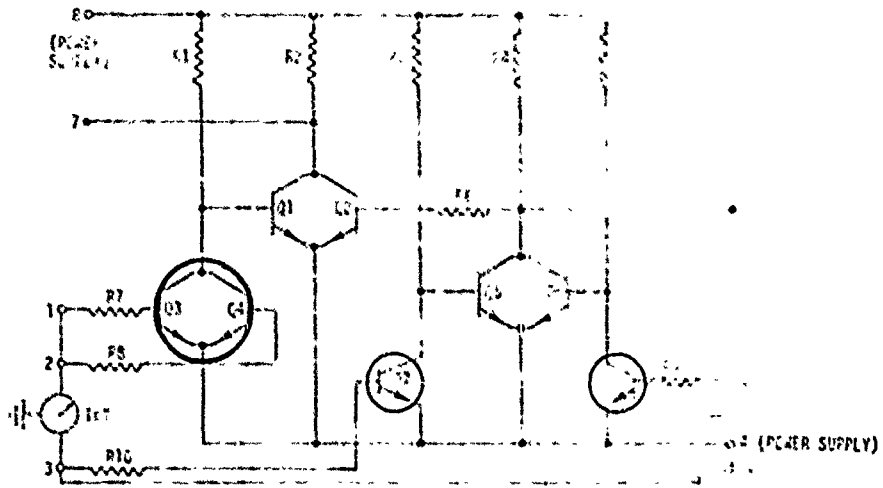
b. DISTRIBUTION OF PARTS: 1975 VS 1967 TEST



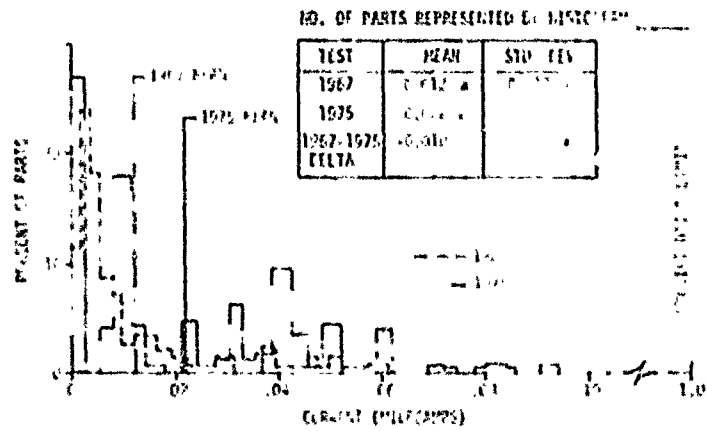
c. 1967 - 1975 CHANGE IN V_{OL} (7-II)

FIGURE 3-12. HISTOGRAM COMPARISON OF V_{OL} (7-II)

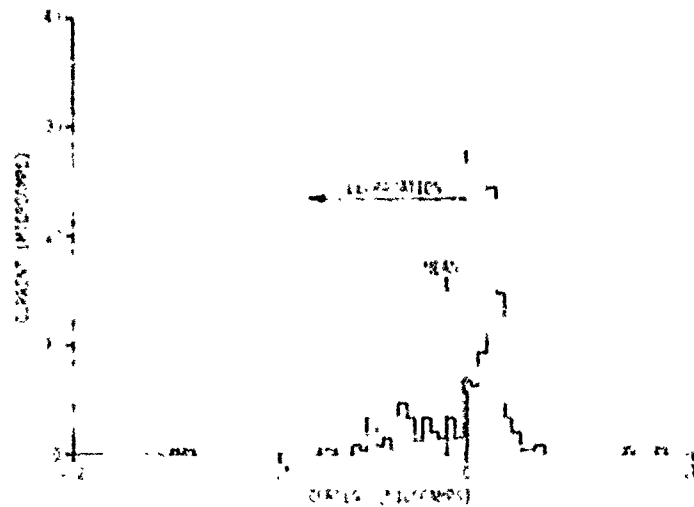
- ADDER -



a SCHEMATIC FOR IRT (I, 2, 3-5) TEST (Q3+Q4+Q7+Q8 BASE-EMITTER JUNCTION LEAKAGE CURRENT)



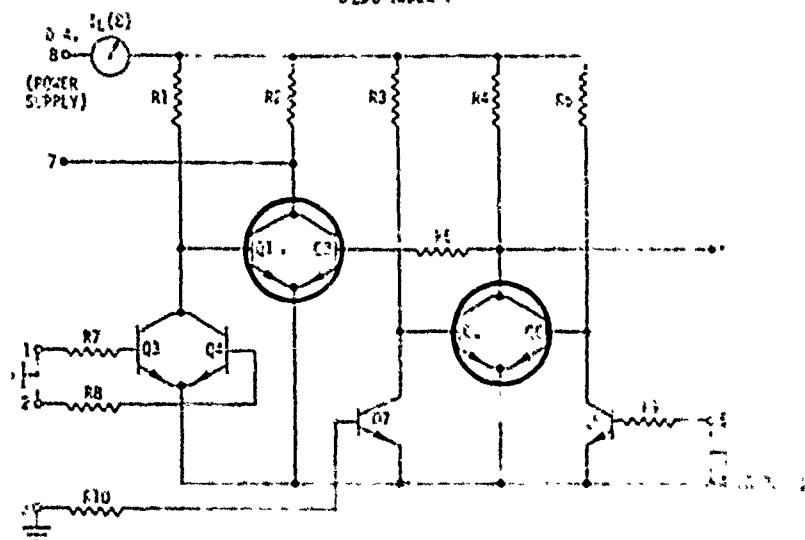
b. DISTRIBUTION OF PARTS: 1975 VS 1967 TEST



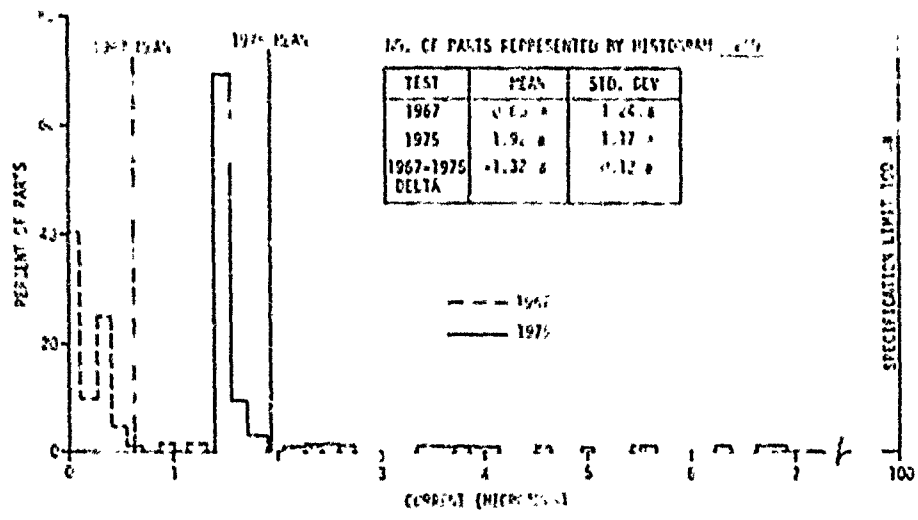
c. 1967-1975 CHANGE IN IRT (I, 2, 3-5)

FIGURE 3-13. HISTOGRAM COMPARISON OF IRT (I, 2, 3-5)

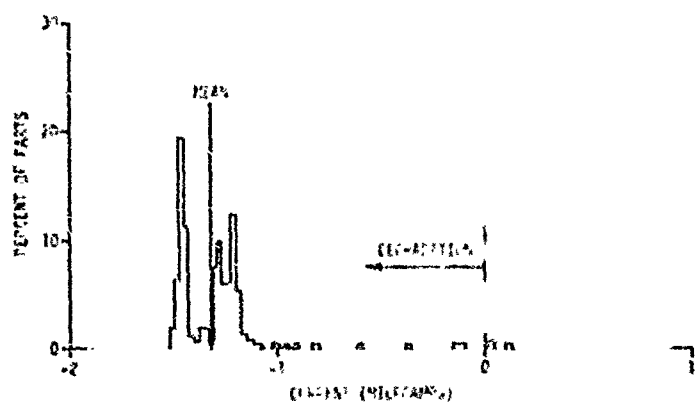
D256-10022-1



a. SCHEMATIC FOR $I_L(I8)$ TEST (Q1+Q2+Q5+Q6 LEAKAGE CURRENT JUST BELOW MAX "OFF" VOLTAGE)



b. DISTRIBUTION OF PARTS: 1975 VS. 1967 TEST



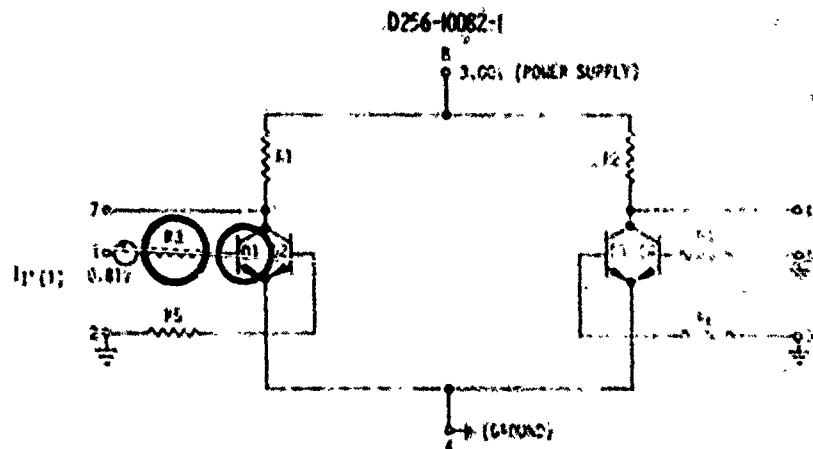
c. 1967-1975 CHANGE IN $I_L(I8)$

FIGURE 3-14, HISTOGRAM COMPARISON OF $I_L(I8)$

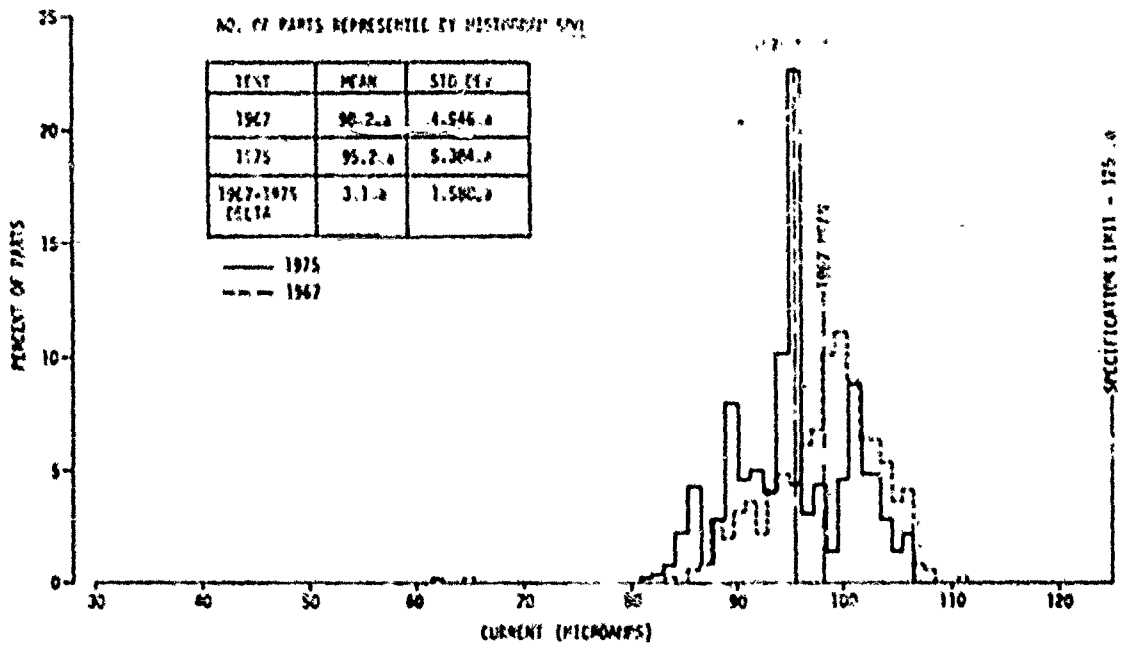
TABLE 3-XII. EVALUATION OF HISTOGRAM COMPARISONS FOR THE DOUBLE GATE

PARAMETER (FIGURE NO.)	* TRENDS OBSERVED IN HISTOGRAM COMPARISONS						TECHNICAL ASSESSMENT
	1967-1975 HISTOGRAMS SINGLE IN SWEP	SKEL SHIFT IN REM ATTRIBUTED TO MEASUREMENT DIFFERENCES	NEAR NORMAL DISTRIBUTION OF 1967-1975 GAGES	1975 HISTOGRAM SHIFTS AND SPEC LIMIT	SHIFT IN 1975 REM TOWARD PERFORMANCE	DISTRIBUTION OF 1967-1975 GAGES DEGRADATION	
$I_{IN}(1)$ (3-15)	/	/	/				NO MEASURABLE DRIFT
$I_{OUT}(7)$ (3-16)	//	/	//				NO MEASURABLE DRIFT
$V_{OUT}(6-1)$ (3-17)				//	//	//	PRONOUNCED DRIFT
$V_{OL}(6-1)$ (3-18)	//	/	/	/	/	/	NO MEASURABLE DRIFT IN + σ PARTS; SLIGHT DRIFT IN - σ PARTS
$V_{OL}(7-1)$ (3-19)	//	/	/	/	/	/	NO MEASURABLE DRIFT IN + σ PARTS; SLIGHT DRIFT IN - σ PARTS
$I_{RT}(3-20)$	/	/	/				NO SIGNIFICANT DRIFT
$I_L(8)$ (3-21)	/	/	/				NO SIGNIFICANT DRIFT

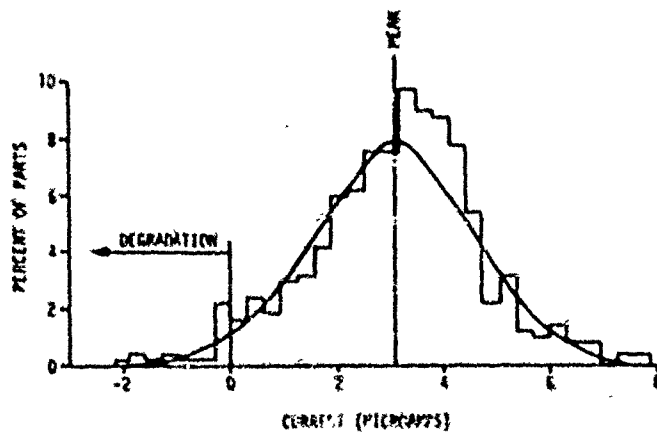
*NOTE: CHECKS APPEARING IN FIRST THREE COLUMNS SUPPORT CONCLUSION THAT DIFFERENCES ARE DUE TO NORMAL MEASUREMENT ERRORS; CHECKS IN LAST THREE COLUMNS SUPPORT CONCLUSION THAT DIFFERENCES ARE DUE TO PARAMETER DRIFT



a. SCHEMATIC FOR $I_{B(II)}$ TEST (R3 RESISTANCE + Q1 BASE EMITTER CHECK AT SATURATION VOLTAGE)



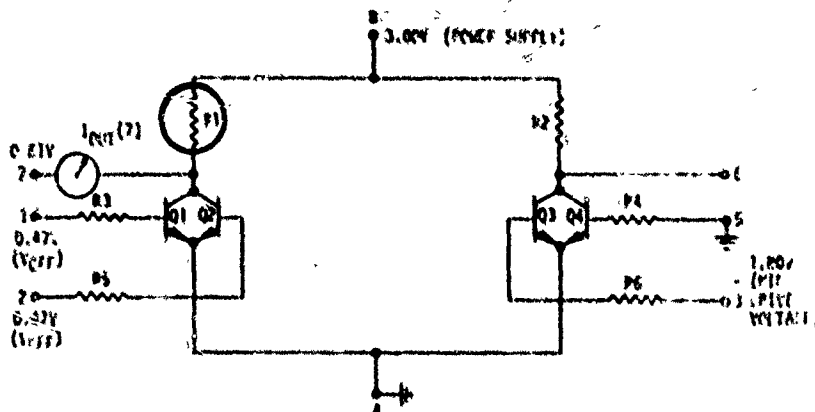
b. DISTRIBUTION OF PARTS: 1975 VS. 1967 TEST



c. 1967 - 1975 CHANGE IN $I_{B(II)}$

FIGURE 3-15. HISTOGRAM COMPARISON OF $I_{B(II)}$

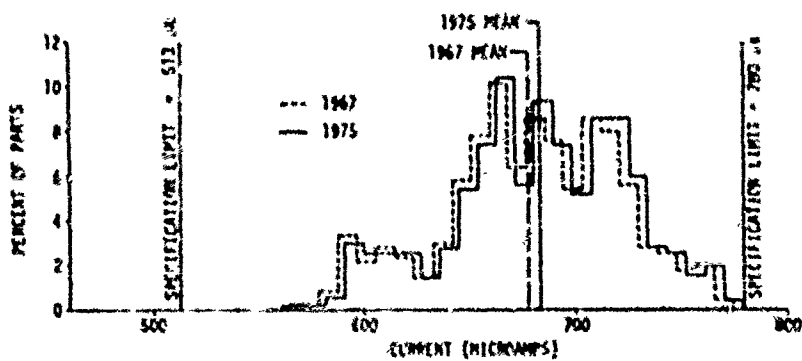
- DOUBLE GATE -



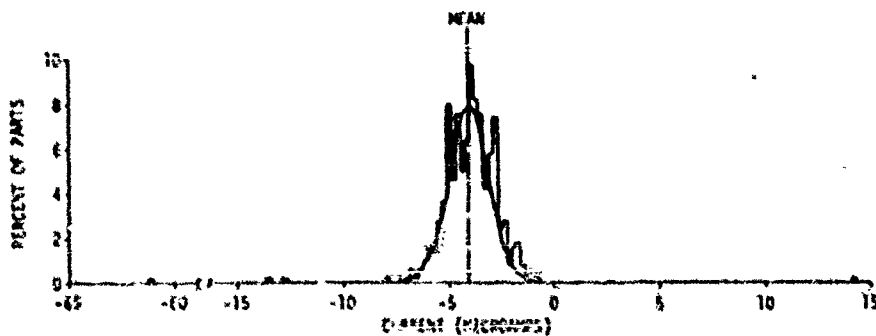
a. SCHEMATIC FOR IOUT (7) TEST (R1 RESISTANCE CHECK)

NO. OF PARTS REPRESENTED BY HISTOGRAM: 500

TEST	MEAN	STD. DEV.
1967	679 μ	42.5 μ
1975	693 μ	42.5 μ
1967-1975 MILIA	-1 μ	3.0 μ



b. DISTRIBUTION OF PARTS: 1975 VS 1967 TEST

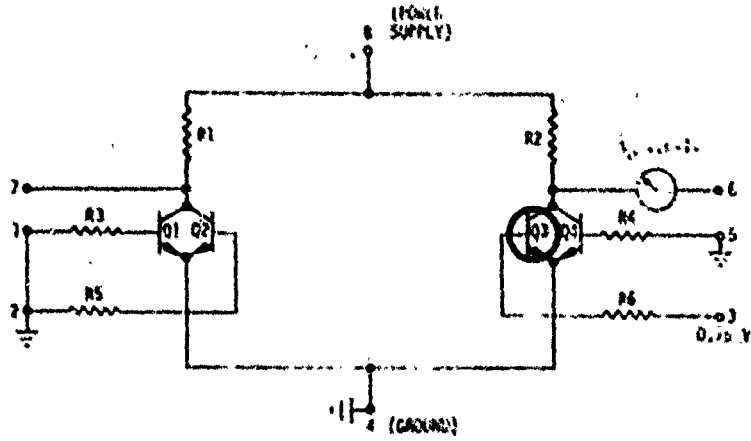


c. 1967-1975 CHANGE IN IOUT (7)

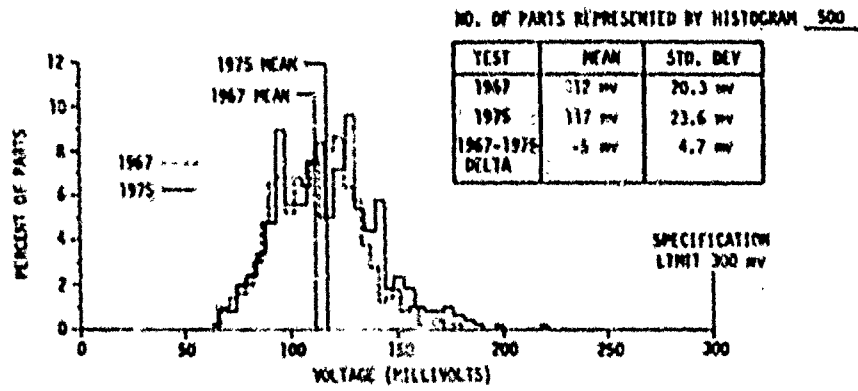
FIGURE 3-16 HISTOGRAM COMPARISON OF IOUT (7)

- DOUBLE GATE -

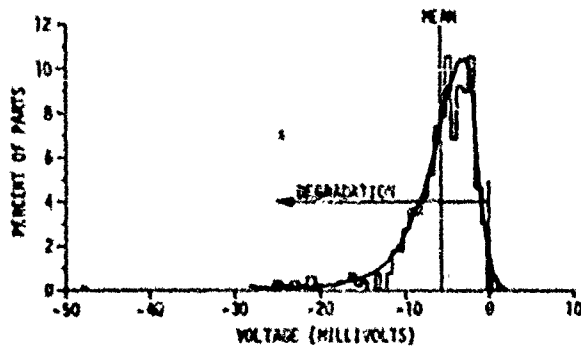
D256-10082-1



a. SCHEMATIC FOR $V_{OUT(6-1)}$ TEST (C3 VOLTAGE DROP AT MINIMUM "ON" CONDITION)



b. DISTRIBUTION OF PARTS; 1975 VS 1967 TEST

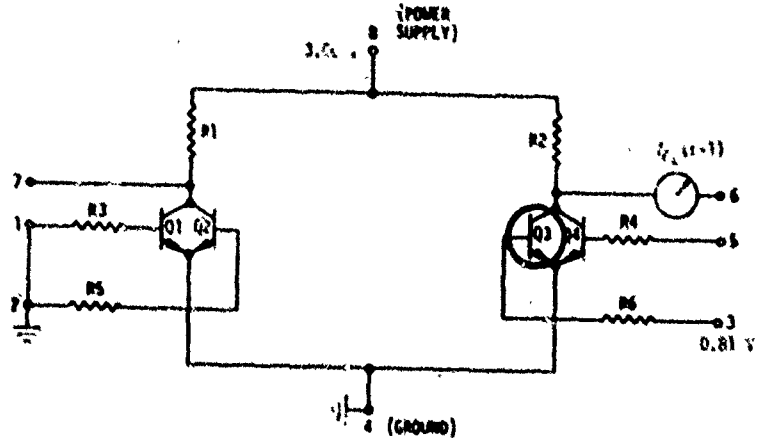


c. 1967 - 1975 CHANGE IN $V_{OUT(6-1)}$

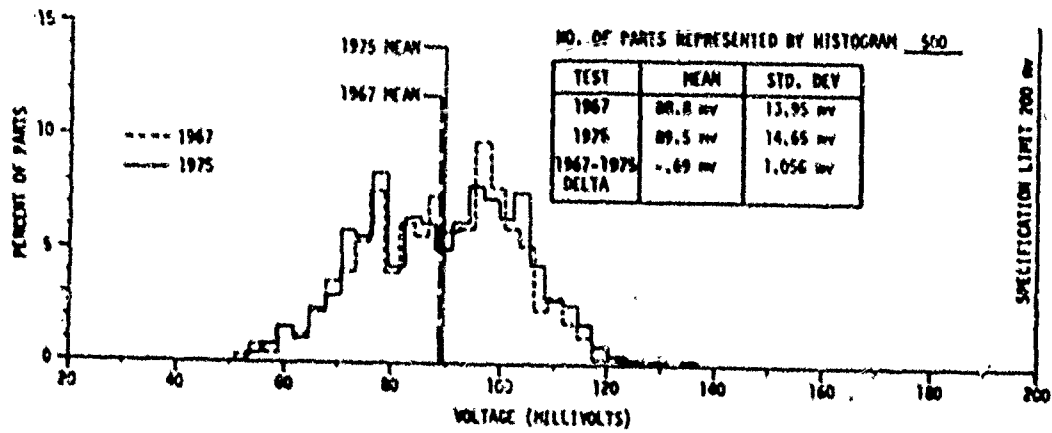
FIGURE 3-17. HISTOGRAM COMPARISON OF $V_{OUT(6-1)}$

- DOUBLE GATE -

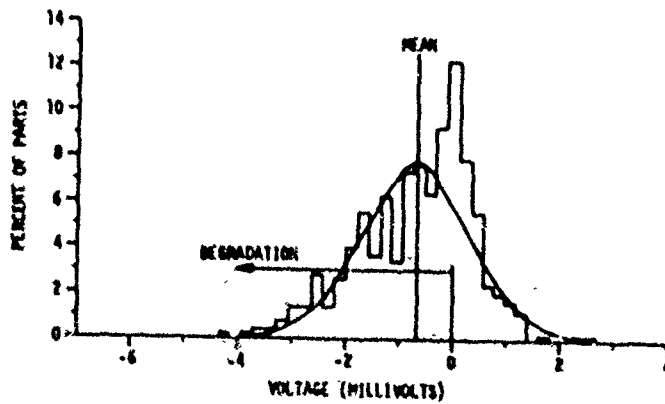
D256-10082-1



a. SCHEMATIC FOR V_{OL} (6-1) TEST (Q3 VOLTAGE DROP AT SATURATION)



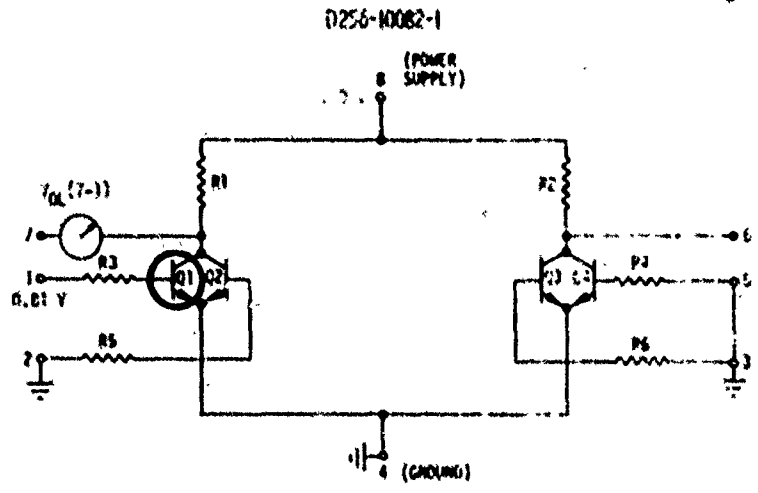
b. DISTRIBUTION OF PARTS: 1975 VS 1967 TEST



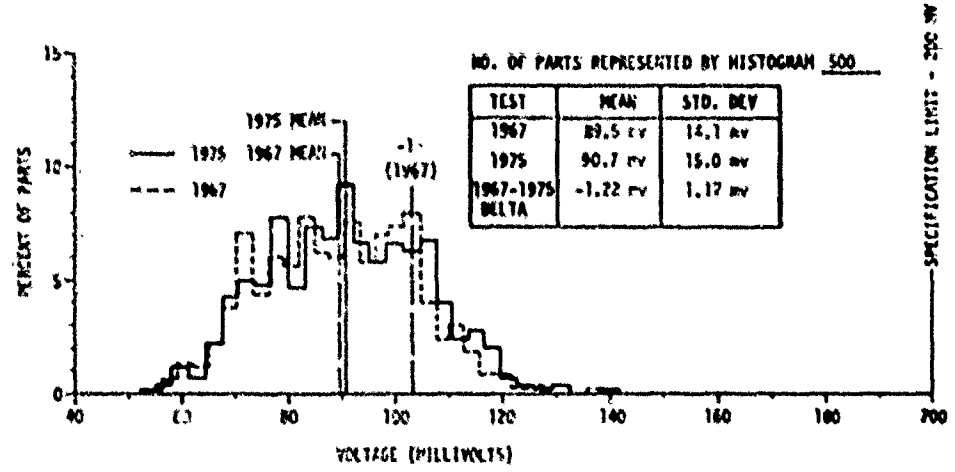
c. 1967 - 1975 CHANGE IN V_{OL} (6-1)

FIGURE 3-28 HISTOGRAM COMPARISON OF V_{OL} (6-1)

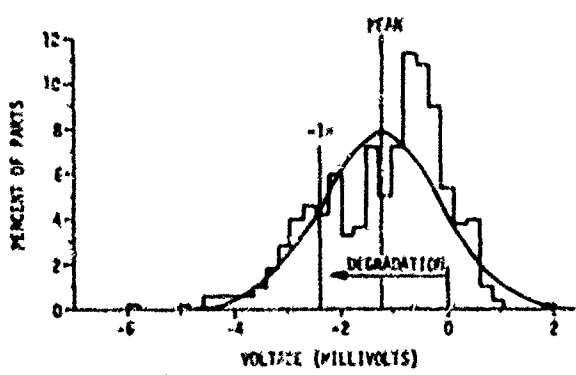
- DOUBLE GATE -



a. SCHEMATIC FOR $V_{OL}(7-1)$ TEST (CI VOLTAGE DROP AT SATURATION)

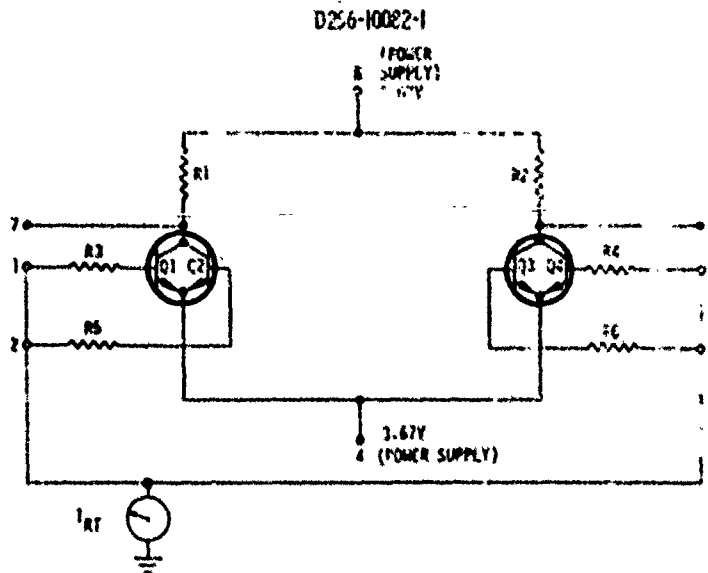


b. DISTRIBUTION OF PARTS: 1975 VS 1967 TEST

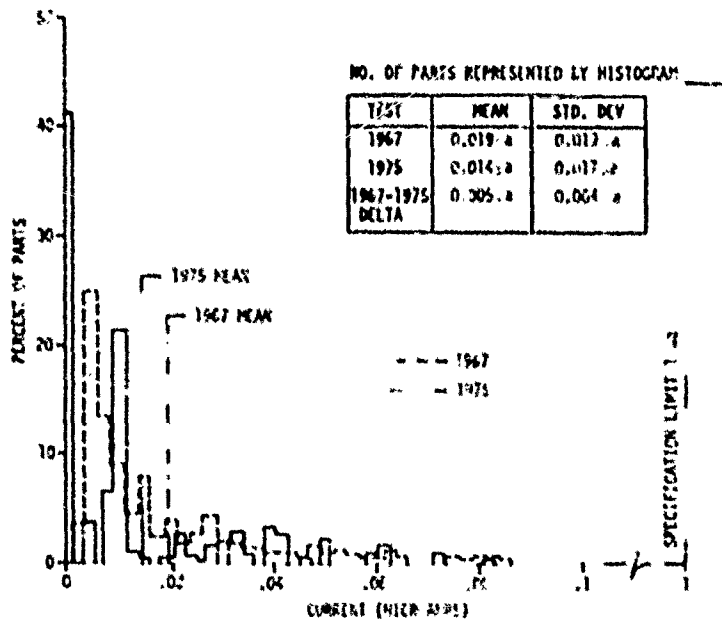


c. 1967 - 1975 CHANGE IN $V_{OL}(7-1)$

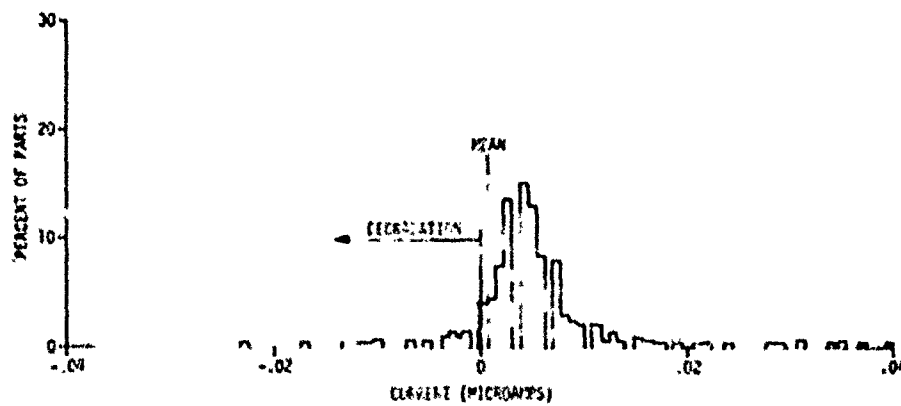
FIGURE 3-19. HISTOGRAM COMPARISON OF $V_{OL}(7-1)$



a. SCHEMATIC FOR I_{RT} TEST ($Q1+Q2+Q3+Q4$ BASE-EMITTER JUNCTION LEAKAGE CURRENT)



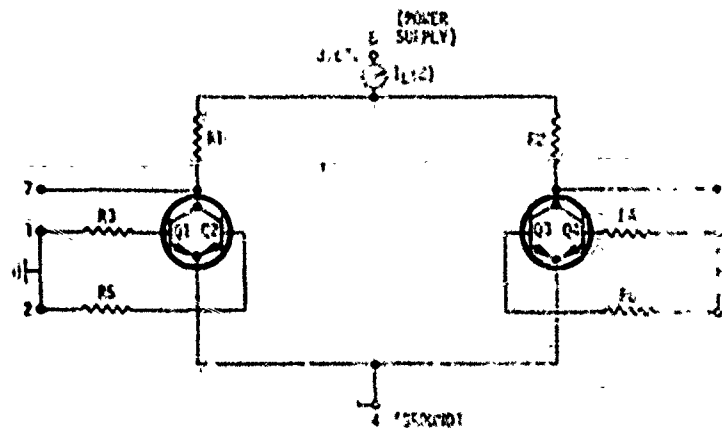
b. DISTRIBUTION OF PARTS: 1975 VS. 1967 TEST



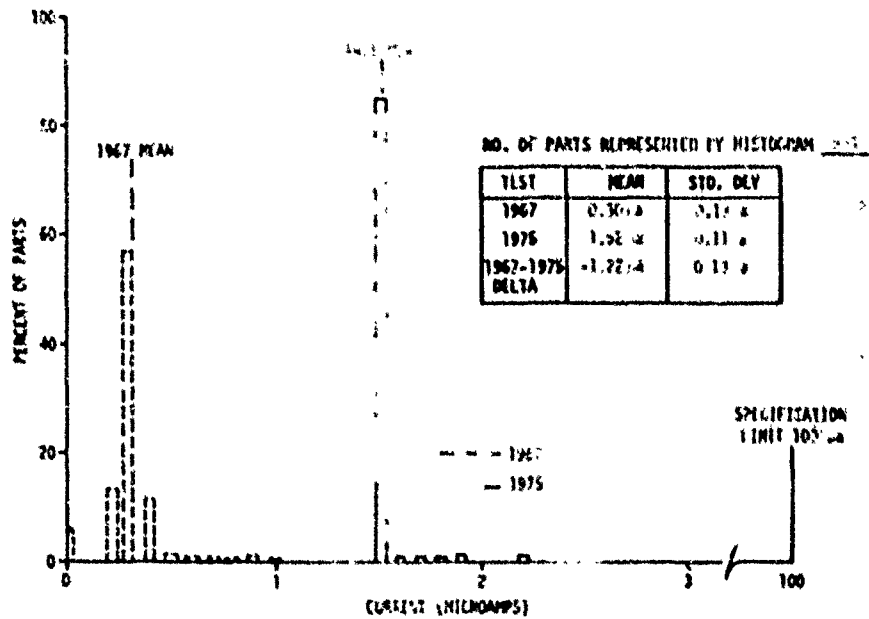
c. 1967-1975 CHANGE IN I_{RT}

FIGURE 3-20. HISTOGRAM COMPARISON OF I_{RT} DOUBLE GATE

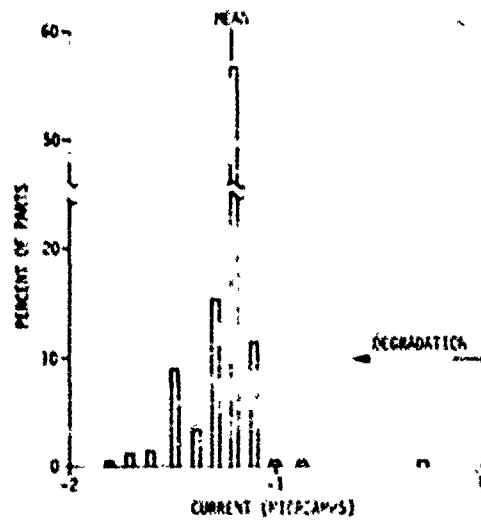
D256-10082-1



a. SCHEMATIC FOR $I_{L(I)}$ TEST (Q1+Q2+Q3+Q4 LEAKAGE CURRENT)



b. DISTRIBUTION OF PARTS, 1975 VS. 1967 TEST



c. 1967-1975 CHANGE IN $I_{L(I)}$

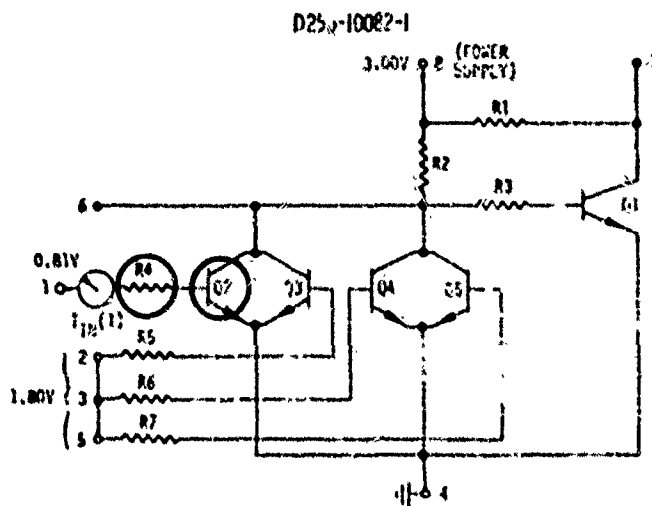
FIGURE 3-21. HISTOGRAM COMPARISON OF $I_{L(I)}$ DOUBLE GATE

TABLE 3-XIII. EVALUATION OF HISTOGRAM COMPARISONS FOR THE 4-INPUT GATE

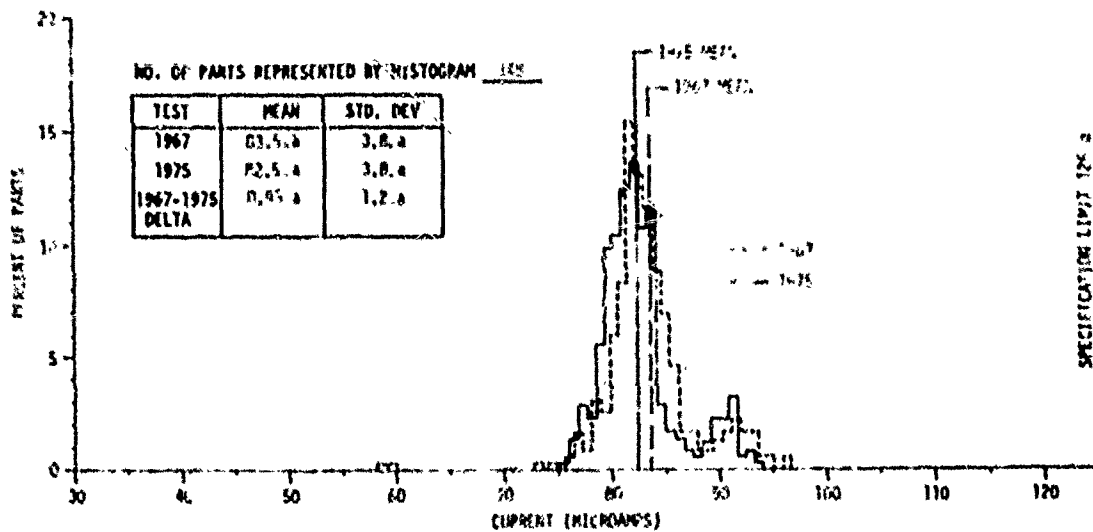
PARAMETER (FIGURE NO.)	* TRENDS OBSERVED IN HISTOGRAM COMPARISONS						TECHNICAL ASSESSMENT
	1967 - 1975 HISTOGRAMS SIMILAR IN SHAPE	SEAL SPLIT IN REAR ATTACHMENT DIFFERENCES	NEAR NORMAL DISTRIBUTION OF 1967-1975 OWNERS	1975 HISTOGRAM SPLITTED AND SPLITTED TOWARD SPEC LIMIT	SPLIT IN 1975 DECADES NEAR TOWARD PLANNING	DISTRIBUTION OF 1967-1975 OWNERS TOWARD DEGRADATION	
I _{IN} (1) (3-22)	//	//	/			/	NO MEASURABLE DRIFT
I _{OUT} (7) (3-23)	///	/	///				NO MEASURABLE DRIFT
V _{OUT} (6-1) (3-24)				//	//	//	MODERATE DRIFT
V _{OL} (6-1) (3-25)	//		//				NO MEASURABLE DRIFT
I _{RT} (3-26)	/	/	/				NO SIGNIFICANT DRIFT
I _L (8) (3-27)	/	/	/				NO SIGNIFICANT DRIFT

LEGEND
 / SLIGHT TREND
 // MODERATE TREND
 /// PRONOUNCED TREND

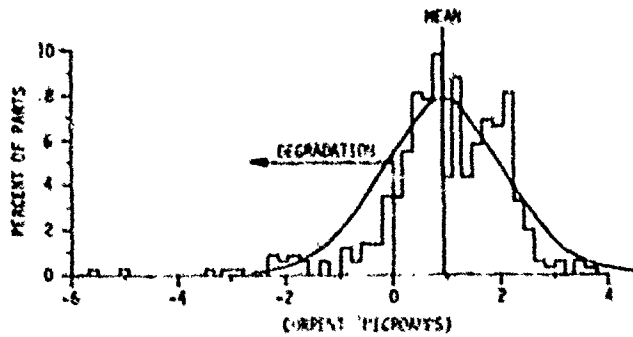
*NOTE: CHECKS APPEARING IN FIRST THREE COLUMNS SUPPORT CONCLUSION THAT DIFFERENCES ARE DUE TO NORMAL MEASUREMENT ERRORS; CHECKS IN LAST THREE COLUMNS SUPPORT CONCLUSION THAT DIFFERENCES ARE DUE TO PARAMETER DRIFT



a. SCHEMATIC FOR $I_{IN(II)}$ TEST (RA RESISTANCE VALUE BASED IN FIGURE 3-22) (SEE DRAWING 3-22)



b. DISTRIBUTION OF PARTS: 1975 VS 1967 TEST

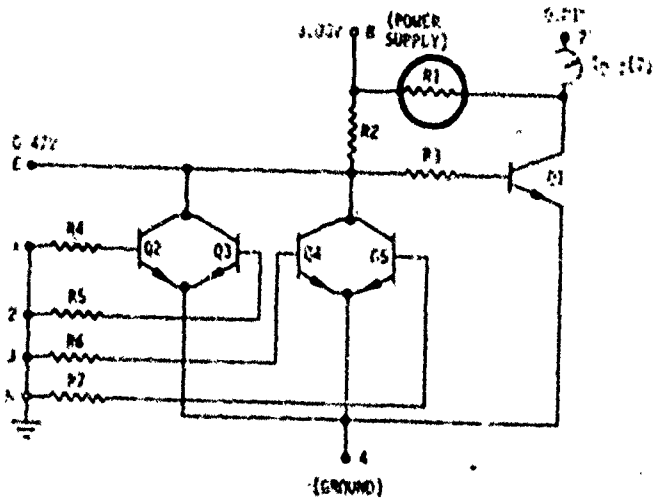


c. 1967 - 1975 CHANGE IN $I_{IN(II)}$

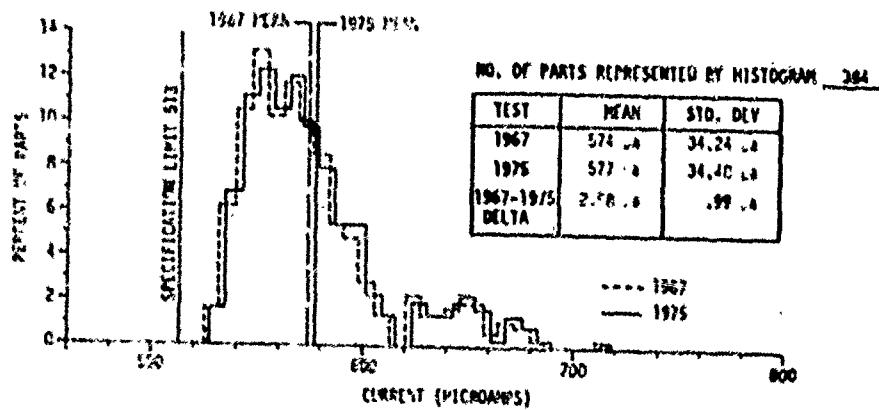
FIGURE 3-22. HISTOGRAM: COMPARISON OF $I_{IN(II)}$

- FOUR INPUT GATE -

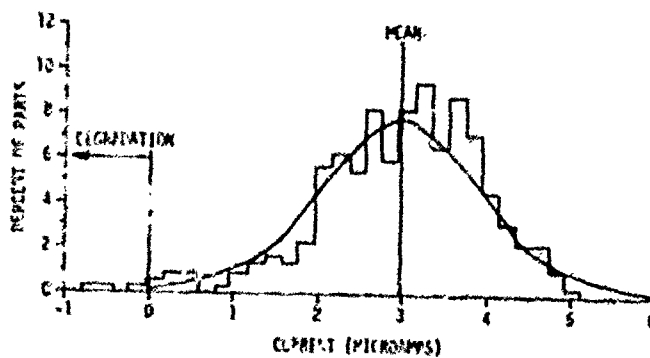
DE56-10082-1



a. SCHEMATIC FOR IOUT(7) TEST (Rj RESISTANCE CHECK)



b. DISTRIBUTION OF PARTS: 1975 VS 1967 TEST

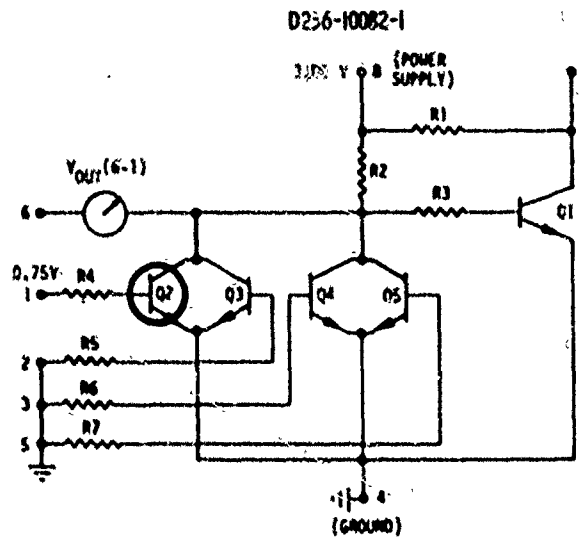


c. 1967-1975 CHANGE IN IOUT(7)

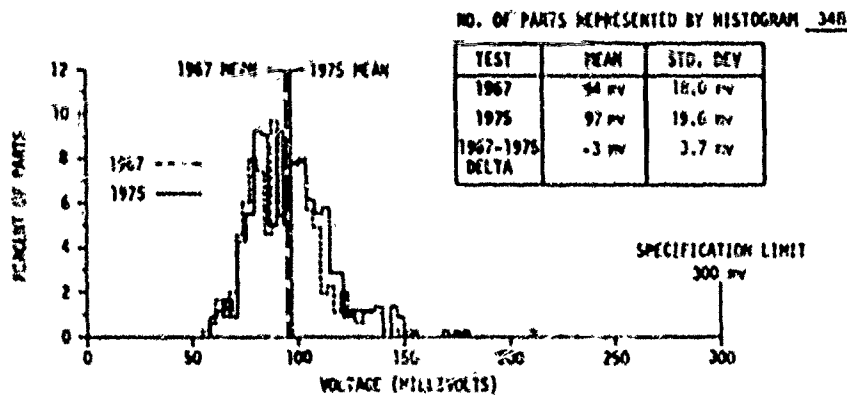
FIGURE 3-23. HISTOGRAM COMPARISON OF IOUT(7)

4 - INPUT GATE

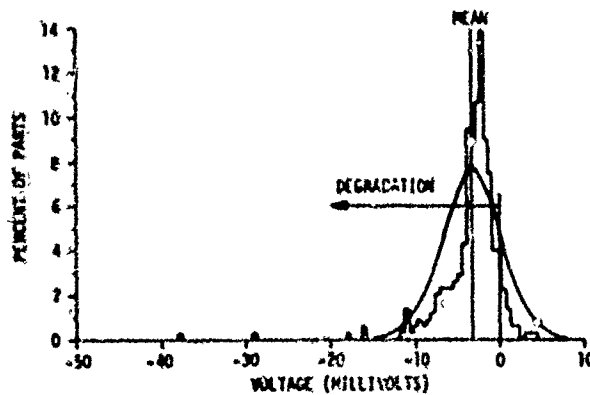
3-80



a. SCHEMATIC FOR $V_{OUT(6-1)}$ TEST (Q2 VOLTAGE DROP AT MINIMUM "ON" CONDITION)



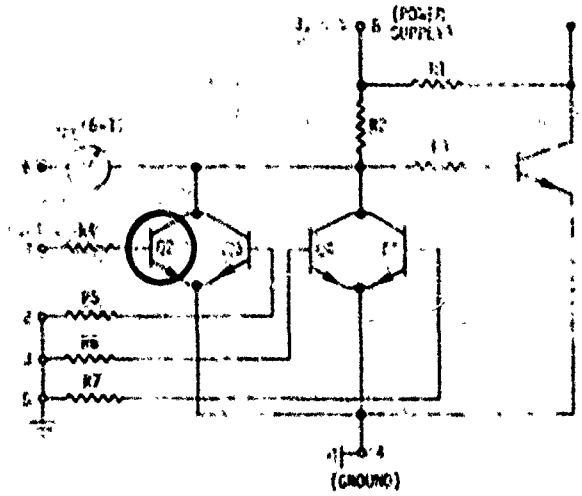
b. DISTRIBUTION OF PARTS: 1975 VS 1967 TEST



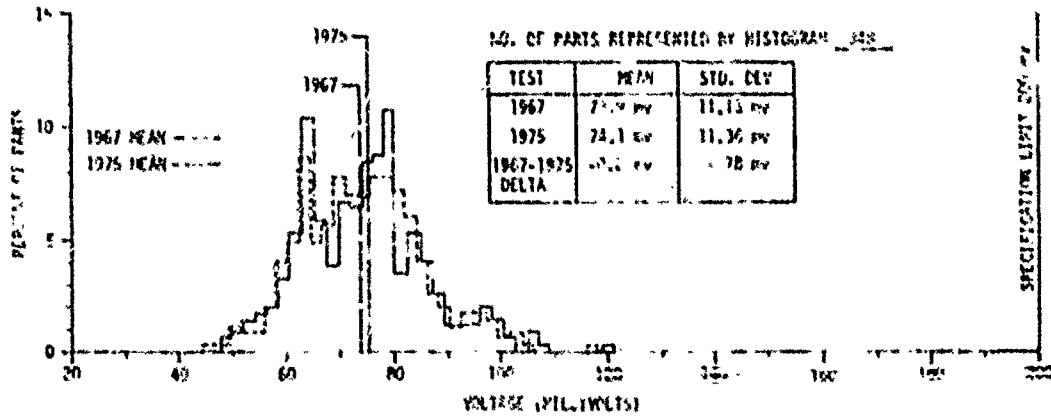
c. 1967 - 1975 CHANGE IN $V_{OUT(6-1)}$

FIGURE 3-24. HISTOGRAM: COMPARISON OF $V_{OUT(6-1)}$
- FOUR-INPUT GATE -

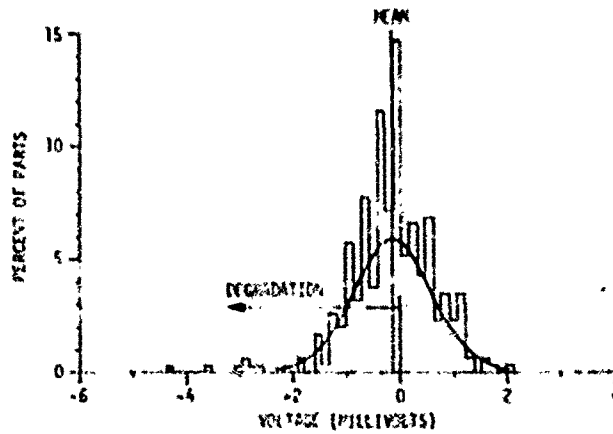
D250-1005-1



a. SCHEMATIC FOR $V_{OL}(6-1)$ TEST (C2 VOLTAGE DROP AT SATURATION)



b. DISTRIBUTION OF PARTS: 1975 VS. 1967 TEST

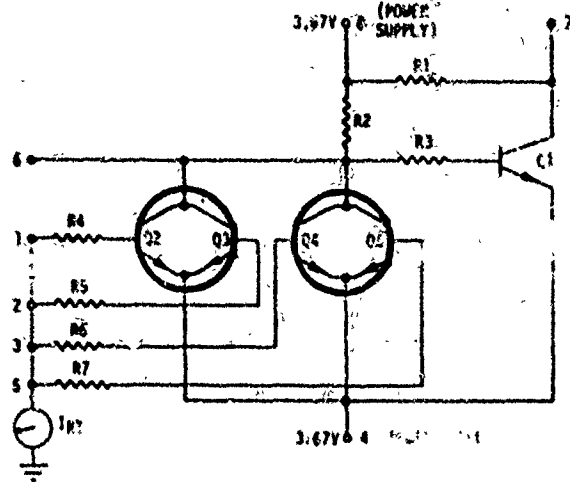


c. 1967 - 1975 CHANGE IN $V_{OL}(6-1)$

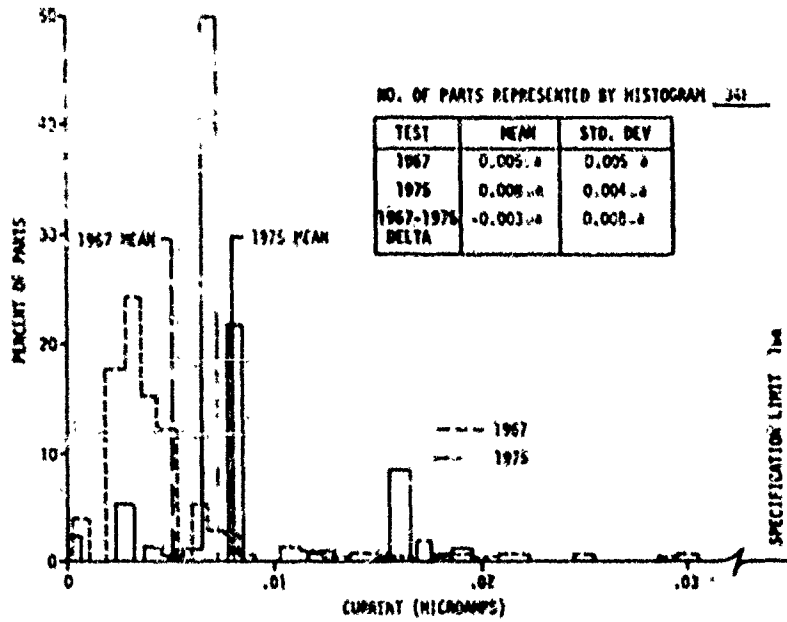
FIGURE 3-25. HISTOGRAM COMPARISON OF $V_{OL}(6-1)$

- FOUR-INPUT GATE -

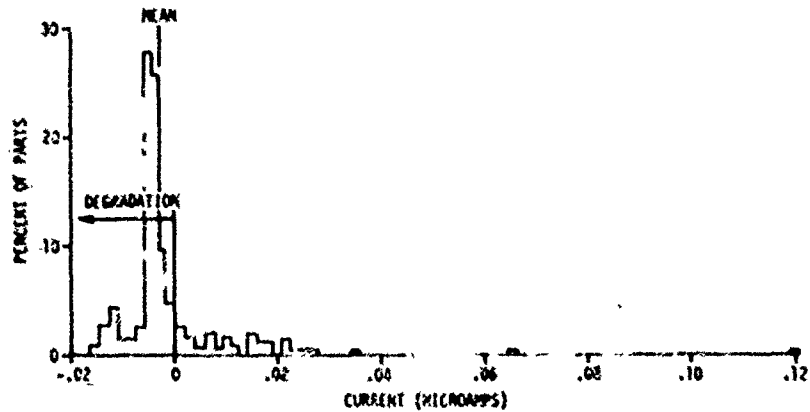
D256-10082-1



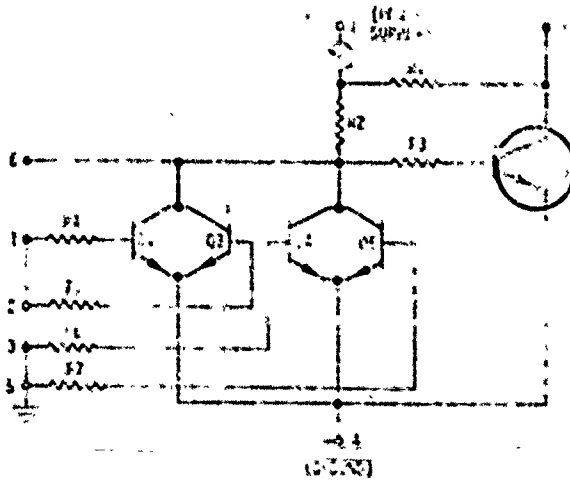
a. SCHEMATIC FOR IRT TEST (Q2+Q3+Q4+Q5 BASE-EMITTER JUNCTION LEAKAGE CURRENT)



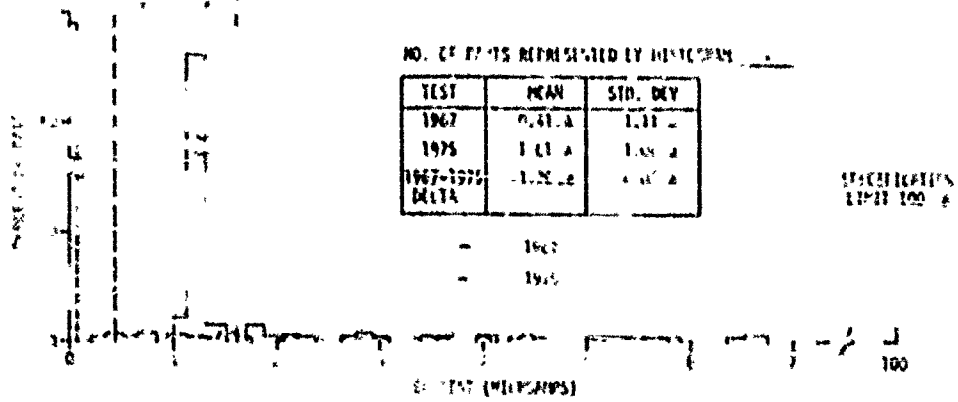
b. DISTRIBUTION OF PARTS: 1975 VS. 1967 TEST



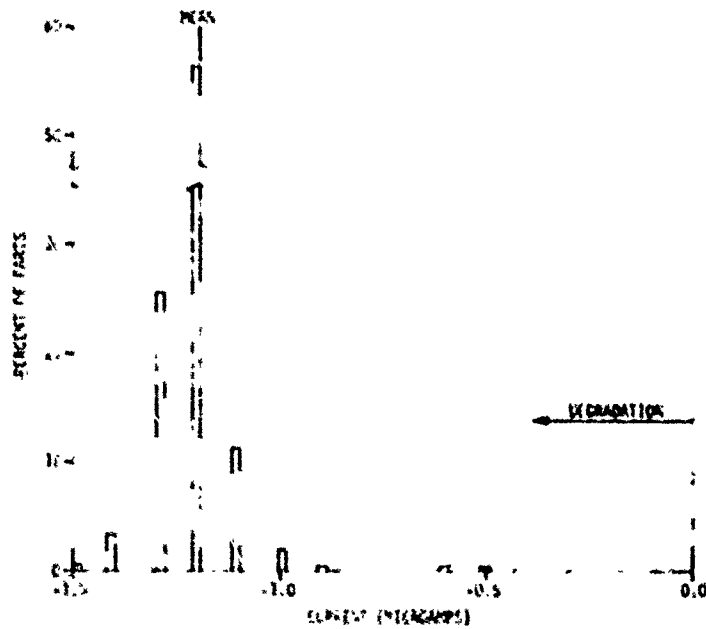
c. 1967-1975 CHANGE IN IRT
 FIGURE 3-26. HISTOGRAM COMPARISON OF IRT
 FOUR-INPUT GATE



a. SCHEMATIC FOR $I_L(0)$ TEST (0) LEAKAGE CURRENT AT JUST BELOW MAXIMUM "OFF" CONDITION



b. DISTRIBUTION OF PARTS: 1975 VS 1967 TEST



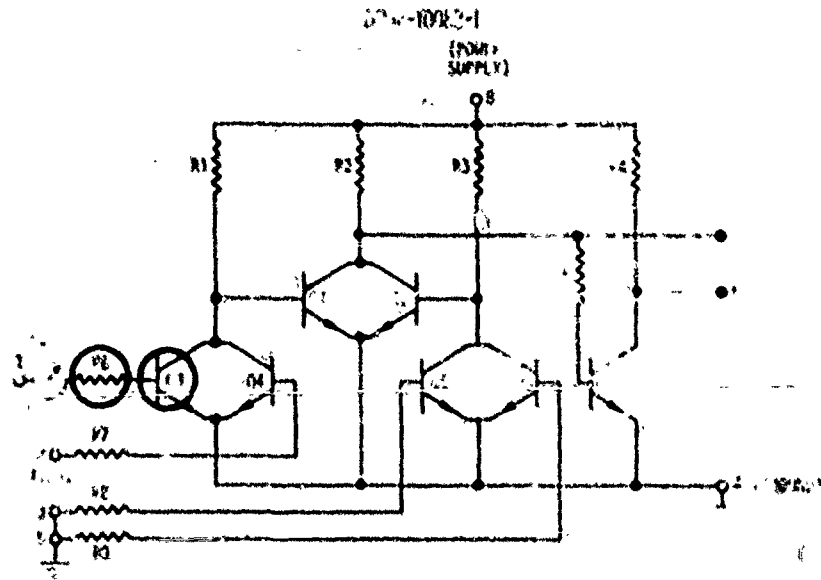
c. 1967-1975 CHANGE IN $I_L(0)$
 FIGURE 3-27. HISTOGRAM COMPARISON OF $I_L(0)$

FOUR-INPUT GATE

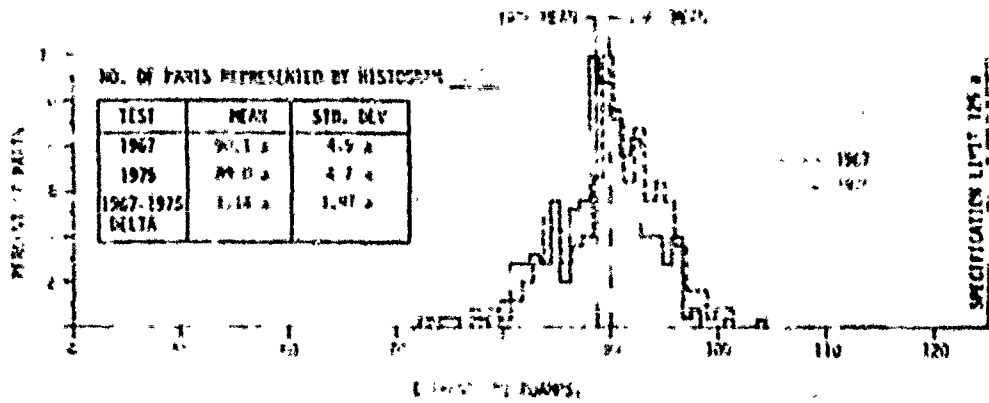
TABLE 3-XIV. EVALUATION OF HISTOGRAM COMPARISONS FOR THE HALF ADDER

PARAMETER (FIGURE NO.)	* TRENDS OBSERVED IN HISTOGRAM COMPARISONS						TECHNICAL ASSESSMENT
	TYPICAL MEASUREMENT DIFFERENCES			TYPICAL PARAMETER DRIFT			
LEGEND	1975 HISTOGRAM SIMILAR TO 1967-1975	SMALL SHIFT IN MEAN TOWARD HIGHER VALUES	SMALL SHIFT IN MEAN TOWARD LOWER VALUES	1975 HISTOGRAM SLOTTED AND SPEC LIMIT	SHIFT IN 1975 MEAN TOWARD HIGHER OR LOWER	RESTRICTION OF 1967-1975 RANGE OR DEFINITION	
✓ // ///	SLIGHT TREND MODERATE TREND PROMOUNCED TREND						
I _{IN} (1) (3-28)	//	//	✓				NO MEASURABLE DRIFT
I _{IN} (3) (3-29)	//	//	✓				NO MEASURABLE DRIFT
I _{OUT} (7-1) (3-30)	//	✓	✓				NO MEASURABLE DRIFT
V _{OL} (6) (3-31)	//	✓	//				NO MEASURABLE DRIFT
I _{PT} (3-32)	✓	✓	✓				NO SIGNIFICANT DRIFT
I _L (8) (3-33)	✓	✓	✓				NO SIGNIFICANT DRIFT

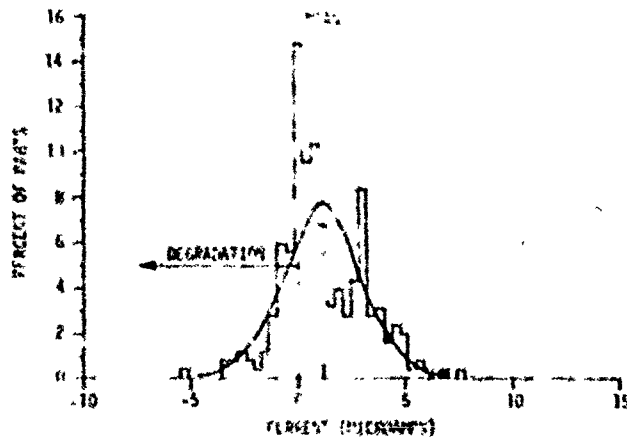
*NOTE: CHECKS APPEARING IN FIRST THREE COLUMNS SUPPORT CONCLUSION THAT DIFFERENCES ARE DUE TO NORMAL MEASUREMENT ERRORS; CHECKS IN LAST THREE COLUMNS SUPPORT CONCLUSION THAT DIFFERENCES ARE DUE TO PARAMETER DRIFT



a. SCHEMATIC FOR I_{IN} TEST (RESISTANCE OF TEST IS 100 OHMS, CURRENT IS 100 MA, TEMPERATURE IS 25°C)



b. DISTRIBUTION OF PARTS: 1975 VS 1967 TEST

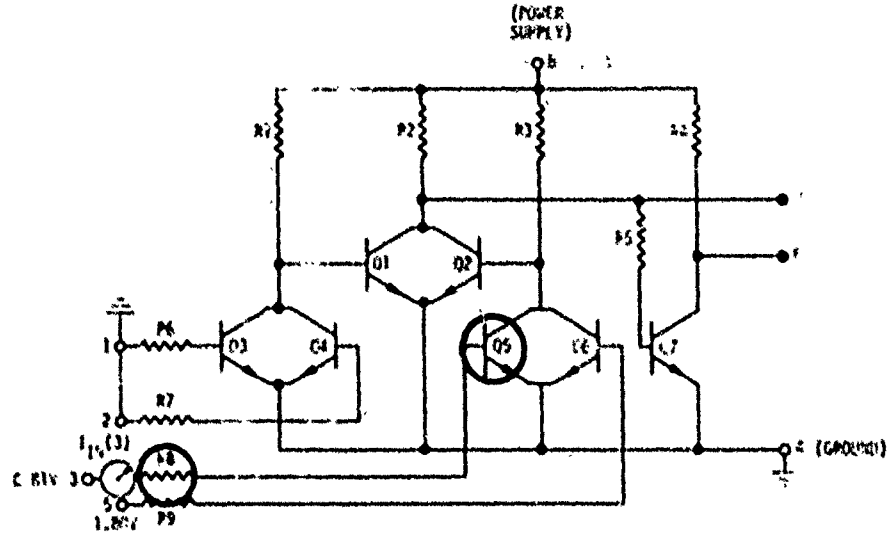


c. 1967 - 1975 CHANGE IN I_{IN} (μA)

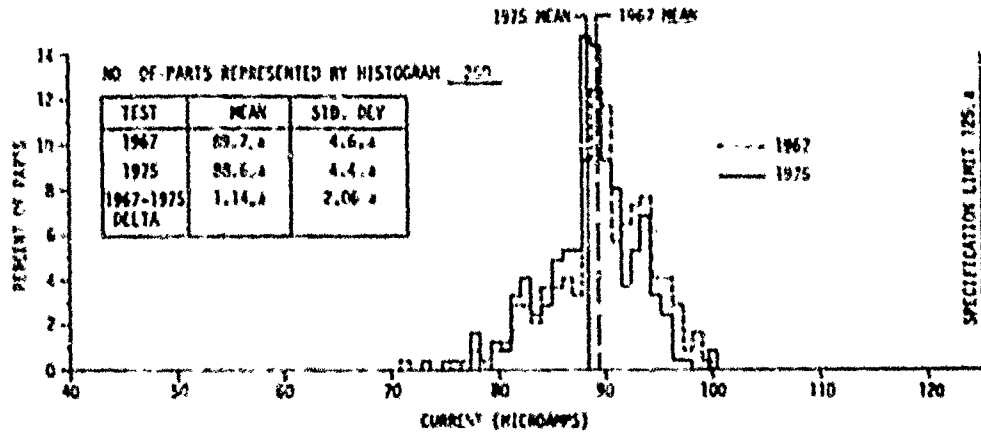
FIGURE 3-2. HISTORICAL COMPARISON OF I_{IN} (μA)

- NAME / ORDER -

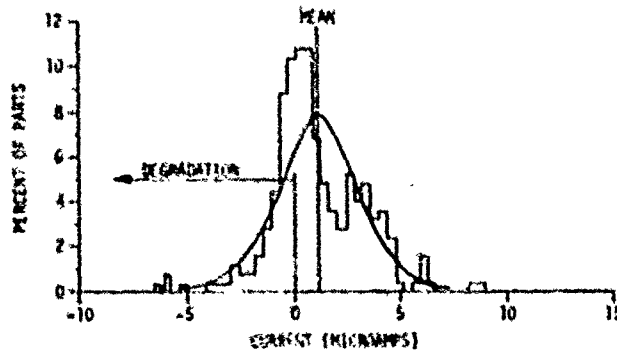
D256-10082-1



a. SCHEMATIC FOR $I_{IN(3)}$ TEST (R8 RESISTANCE + Q5 BASE EMITTER JUNCTION LEAKAGE CHECK AT SATURATION VOLTAGE)



b. DISTRIBUTION OF P/RIS: 1975 VS 1967 TEST

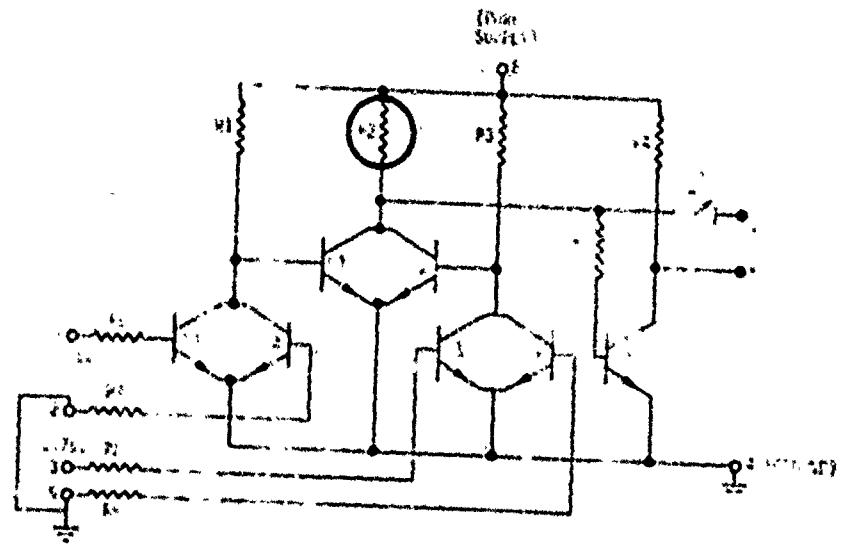


c. 1967 - 1975 CHANGE IN $I_{IN(3)}$

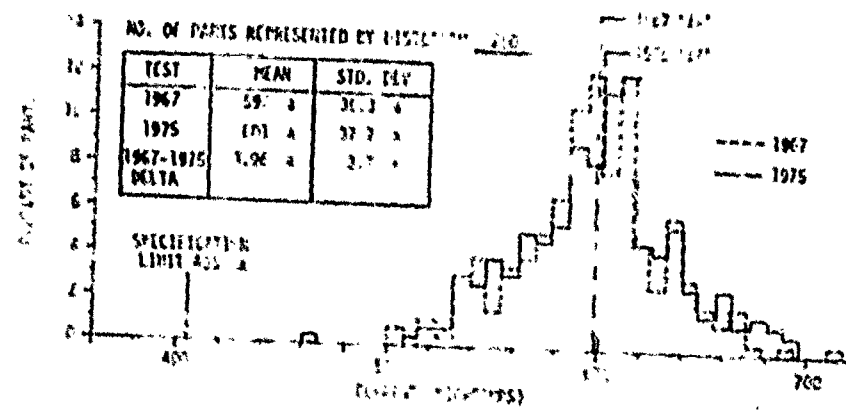
FIGURE 3-2: HISTOGRAM COMPARISON OF $I_{IN(3)}$

- HALF ADDER -

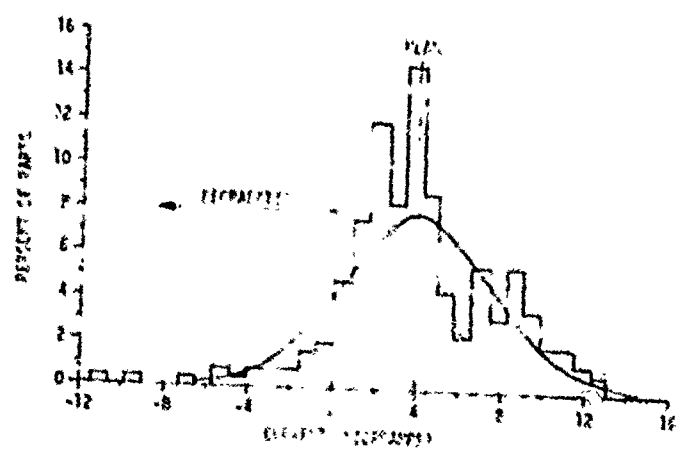
D25-10282-1



a. SCHEMATIC FOR IOUT(7-II) TEST (1/2 RESISTANCE CHECK)



b. DISTRIBUTION OF PARTS: 1975 VS 1967 TEST

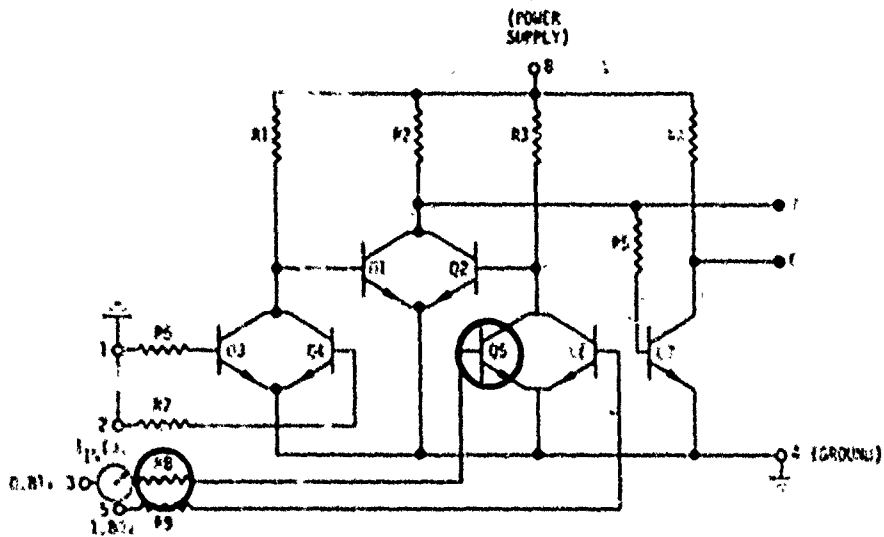


c. 1967-1975 CHANGE IN IOUT(7-II)

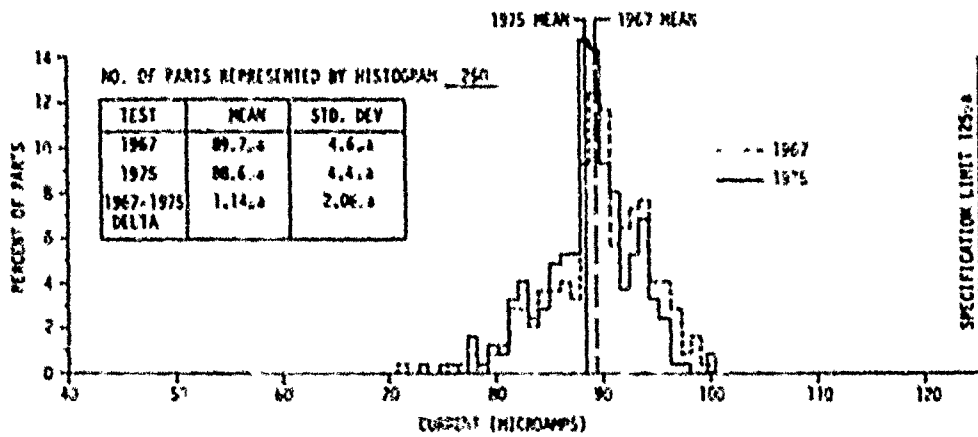
FIGURE 2-20. HISTORICAL COMPARISON OF IOUT(7-II)

HALF ADDER

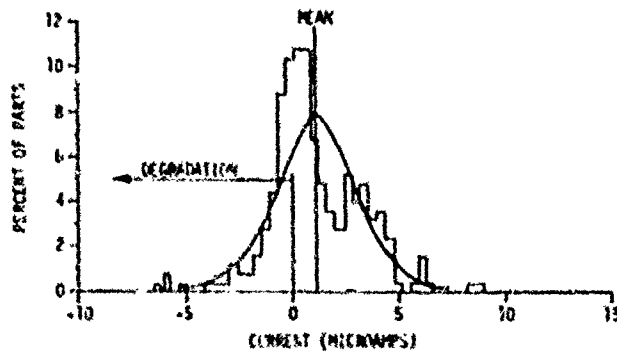
D256-10082-1



a. SCHEMATIC FOR $I_{IN(3)}$ TEST (R8 RESISTANCE + Q5 BASE EMITTER JUNCTION LEAKAGE CHECK AT SATURATION VOLTAGE)



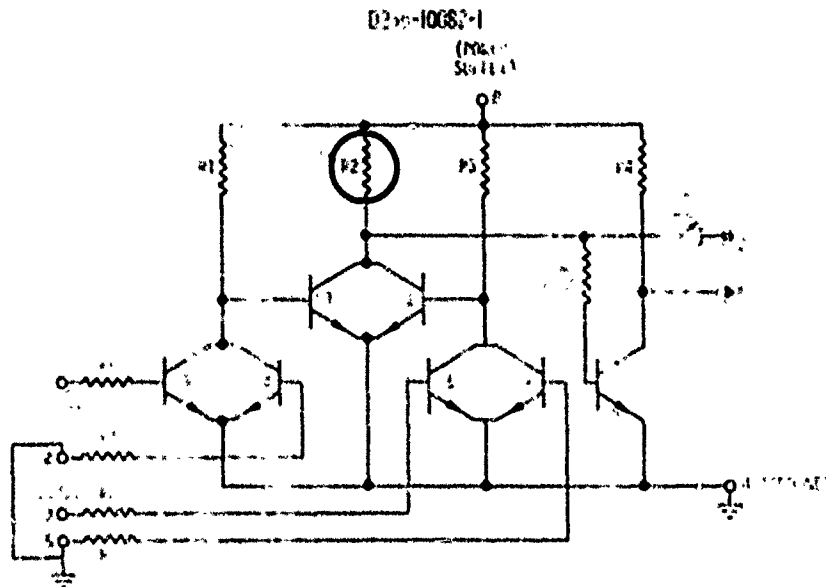
b. DISTRIBUTION OF PARTS: 1975 VS 1967 TEST



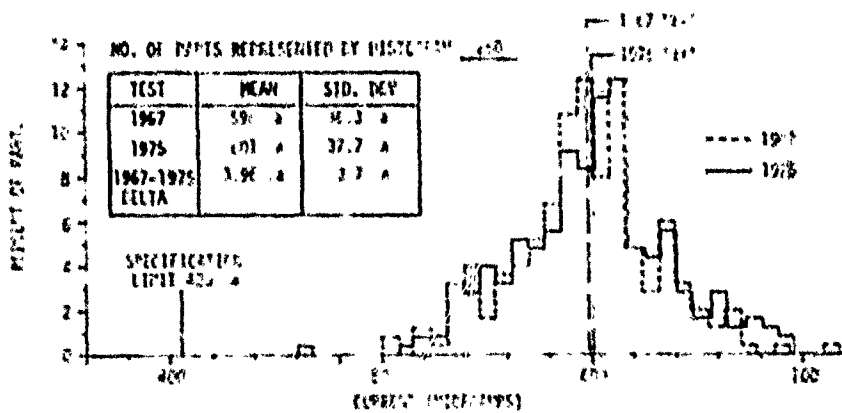
c. 1967 - 1975 CHANGE IN $I_{IN(3)}$

FIGURE 3-2. HISTOGRAM COMPARISON OF $I_{IN(3)}$

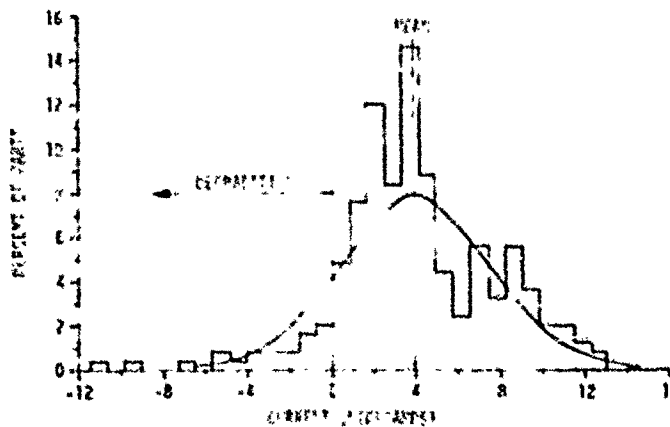
- HALF ADDER -



a. SCHEMATIC FOR IOUT(7-D) TEST (W/ RESISTANCE CHECK)



b. DISTRIBUTION OF PARTS: 1975 VS 1967 TEST

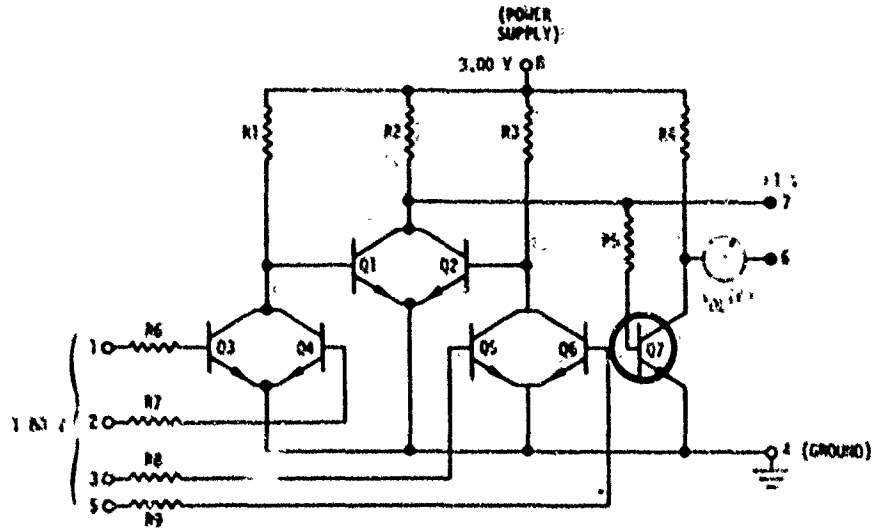


c. 1967-1975 CHANGE IN IOUT(7-D)

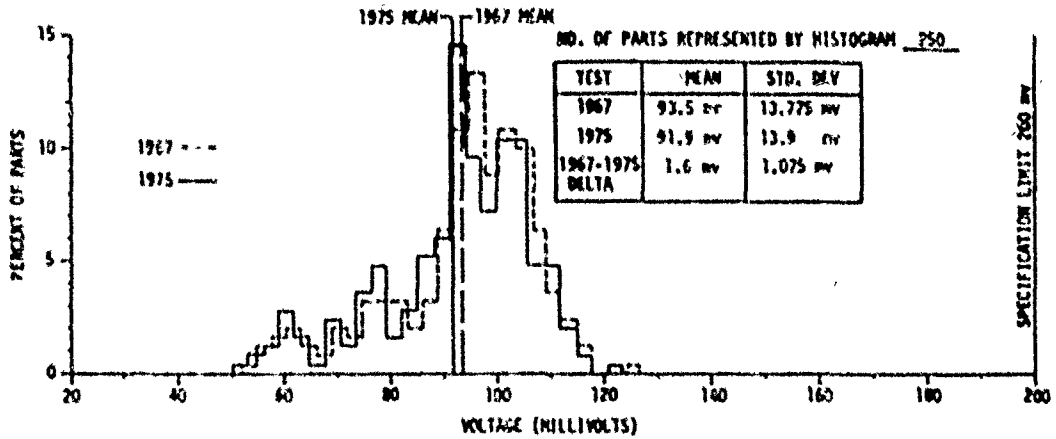
FIGURE 2-20. HISTOGRAM COMPARISON OF IOUT(7-D)

HALF ADDER

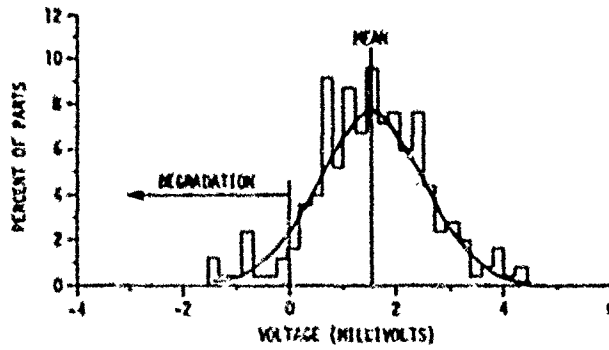
D256-10082-1



a. SCHEMATIC FOR $V_{OL(6)}$ TEST (Q7 VOLTAGE DROP AT SATURATION)



b. DISTRIBUTION OF PARTS: 1975 VS 1967 TEST



c. 1967 - 1975 CHANGE IN $V_{OL(6)}$

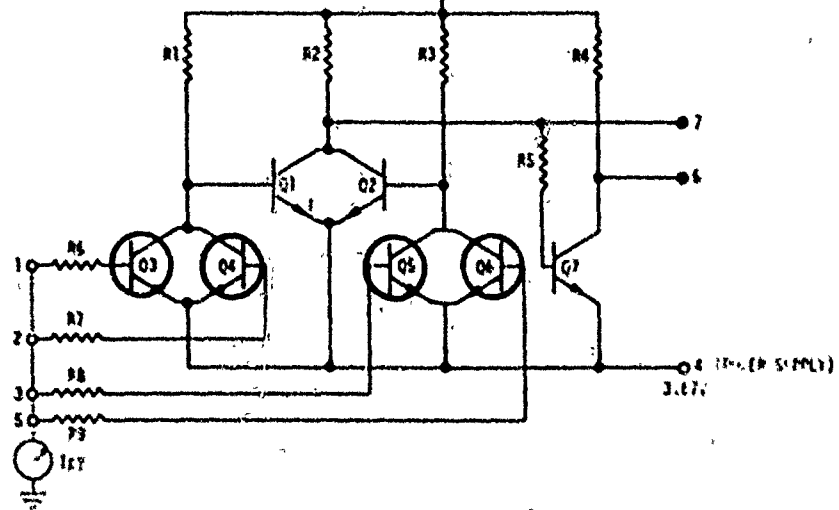
FIGURE 3-31. HISTOGRAM COMPARISON OF $V_{OL(6)}$

- HALF ADDER -

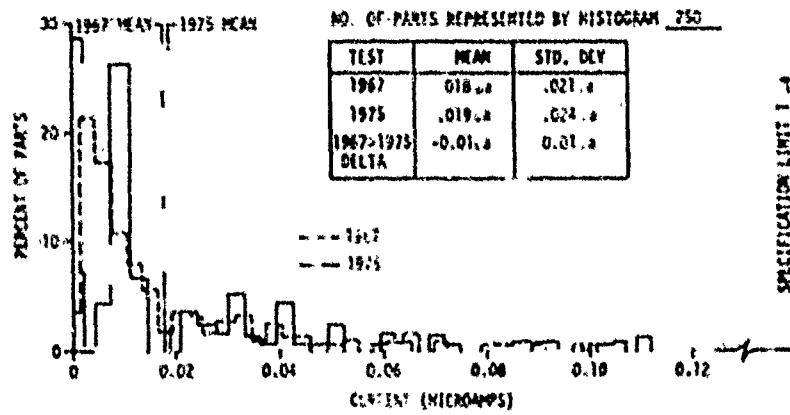
D256-10082-1

(POWER SUPPLY)

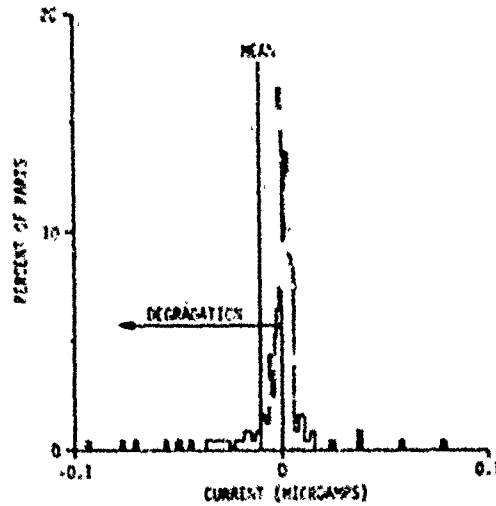
3.67V B



a. SCHEMATIC FOR IRT TEST (Q3+Q4+Q5+Q6 BASE EMITTER JUNCTION LEAKAGE CHECK)

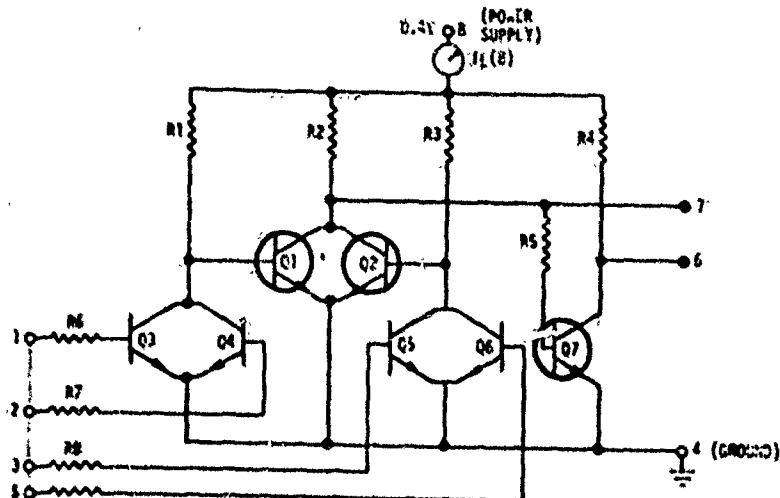


b. DISTRIBUTION OF PARTS: 1975 VS 1967 TEST

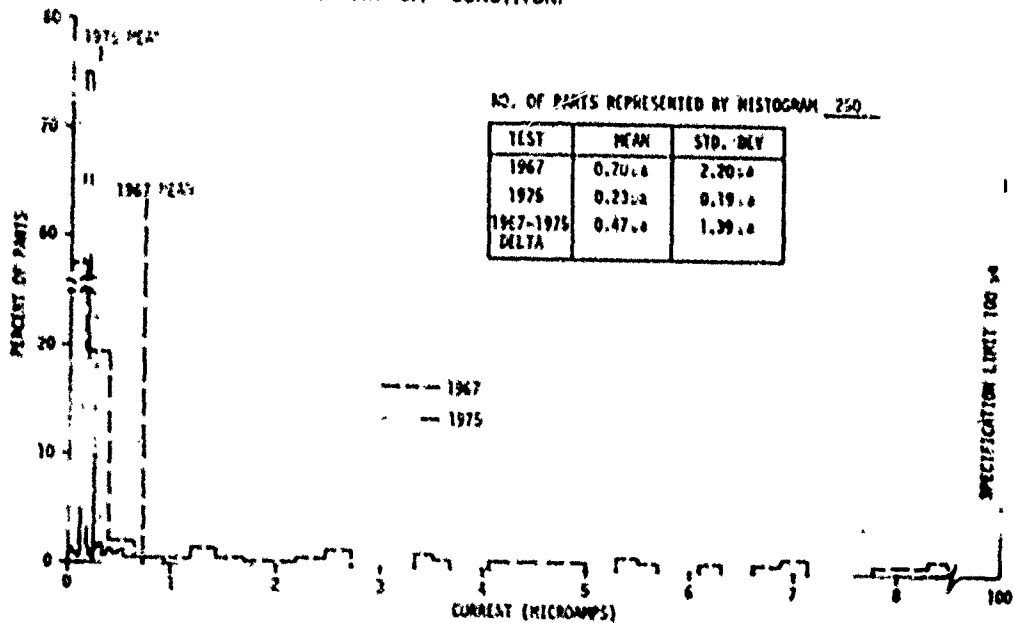


c. 1967-1975 CHANGE IN IRT
 FIGURE 3-32 HISTOGRAM COMPARISON OF IRT
 HALF ADDER

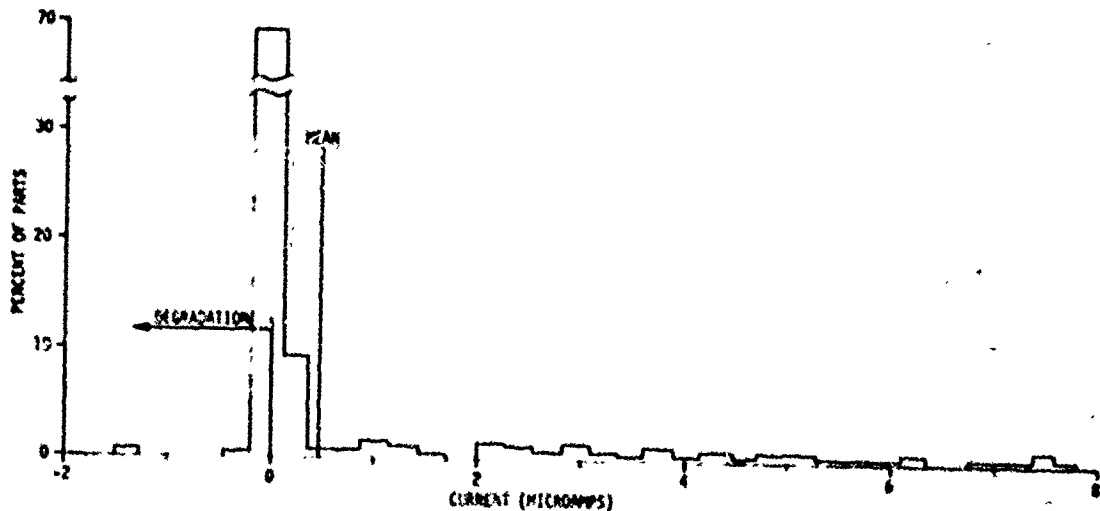
D256-10082-1



a. SCHEMATIC FOR $I_L(B)$ TEST (Q1+Q2+Q7 LEAKAGE CURRENT AT JUST BELOW MAXIMUM "OFF" CONDITION)



b. DISTRIBUTION OF PARTS: 1975 VS 1967 TEST



c. 1967-1975 CHANGE IN $I_L(B)$

FIGURE 3-33. HISTOGRAM COMPARISON OF $I_L(B)$

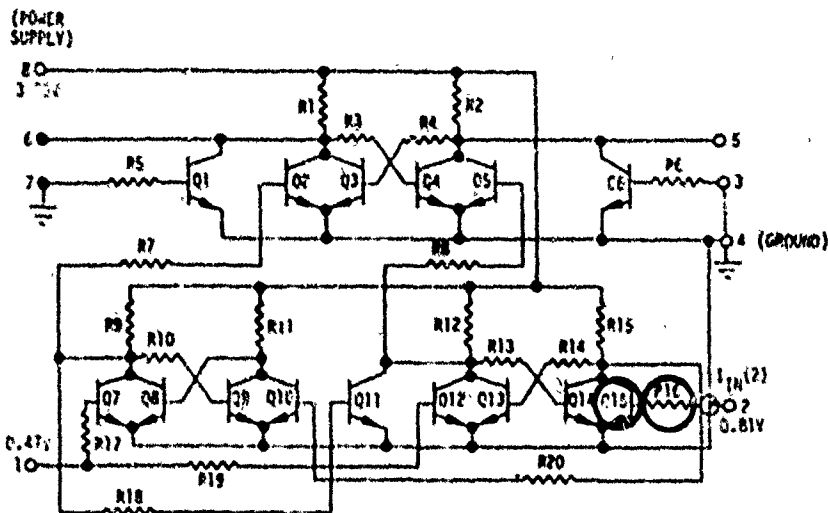
HALF ADDER

TABLE 3-XV. EVALUATION OF HISTOGRAM COMPARISONS FOR THE REGISTER

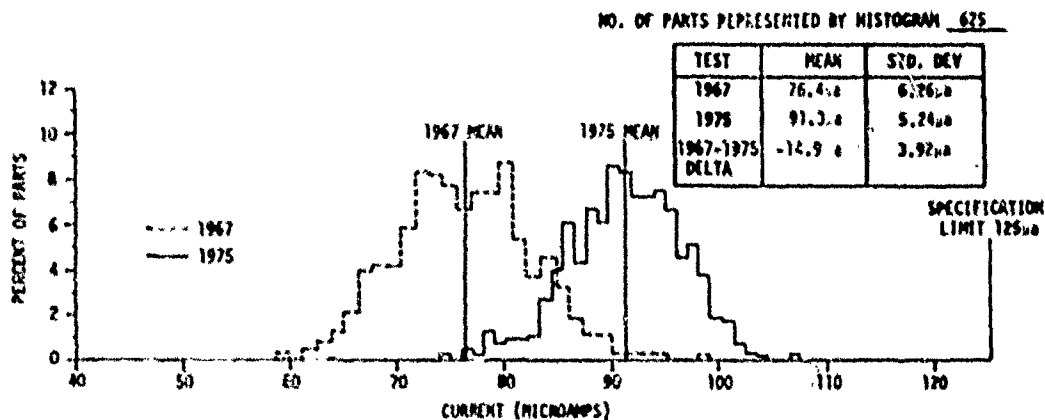
PARAMETER (FIGURE NO.)	*TRENDS OBSERVED IN HISTOGRAM COMPARISONS								TECHNICAL ASSESSMENT
	TYPICAL MEASUREMENT DIFFERENCES				TYPICAL PARAMETER DRIFT				
	HISTOGRAMS IN 1967-1975 SHOW A SHIFT	SMALL SHIFT IN MEASUREMENT NEAR ATTITUDE	MEASUREMENT DIFFERENCES	MEAN NORMAL DISTRIBUTION OF 1967-1975 CHANGES	1975 HISTOGRAMS SHIFTED AND SKEWED TOWARD SPEC LIMIT	SHIFT IN 1975 MEAN TOWARD DESIRED PERFORMANCE	DISTRIBUTION OF 1967-1975 CHANGES	DISTRIBUTION OF 1967-1975 CHANGES TOWARD DEGRADATION	
I _{IN} (2) (3-34)	///	///	///	///		///			NO MEASURABLE DRIFT
I _{OUT} (6-1) (3-35)	///	///	///	///		///	✓	✓	NO MEASURABLE DRIFT
V _{OUT} (5-1) (3-36)					///	///	///	///	MODERATE DRIFT
V _{OL} (6-1) (3-37)	✓	✓	✓	✓	✓	✓	✓	✓	NO MEASURABLE DRIFT IN +σ PARTS; SLIGHT DRIFT IN -σ PARTS
I _{RT} (3-38)	✓	✓	✓	✓					NO SIGNIFICANT DRIFT
I _L (8) (3-39)	✓	✓	✓	✓					NO SIGNIFICANT DRIFT

*NOTE: CHECKS APPEARING IN FIRST THREE COLUMNS SUPPORT CONCLUSION THAT DIFFERENCES ARE DUE TO NORMAL MEASUREMENT ERRORS; CHECKS IN LAST THREE COLUMNS SUPPORT CONCLUSION THAT DIFFERENCES ARE DUE TO PARAMETER DRIFT

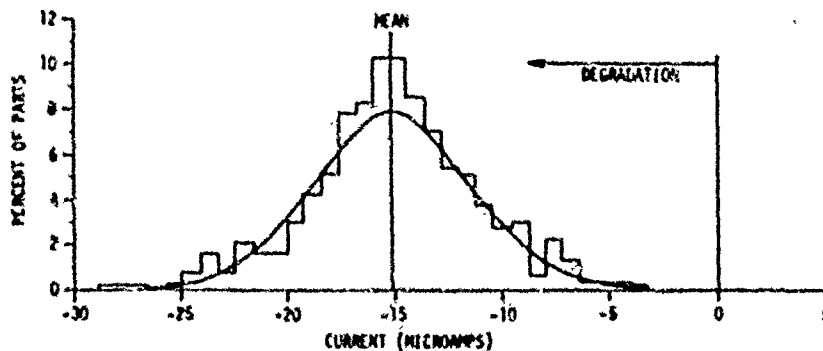
D256-10082-1



a. SCHEMATIC FOR $I_{IN(2)}$ TEST (R_{16} RESISTANCE + Q15 BASE-EMITTER CHECK AT SATURATION VOLTAGE)



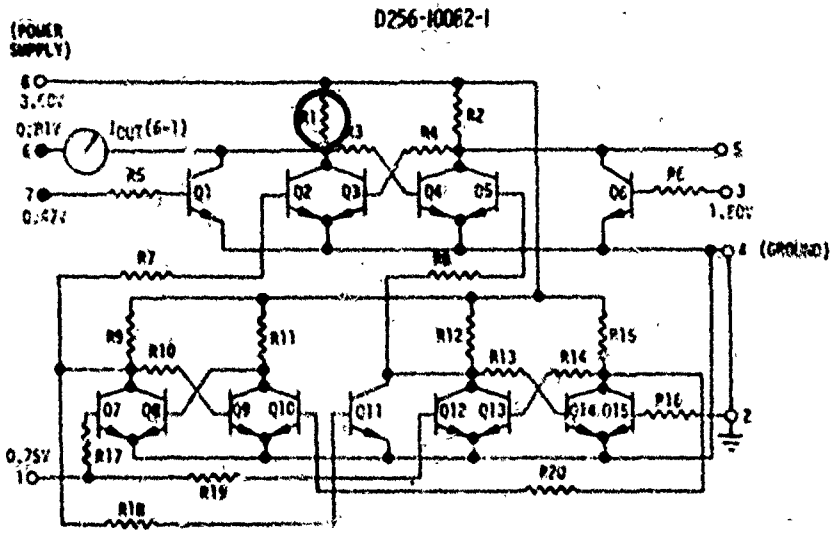
b. DISTRIBUTION OF PARTS: 1975 VS 1967 TEST



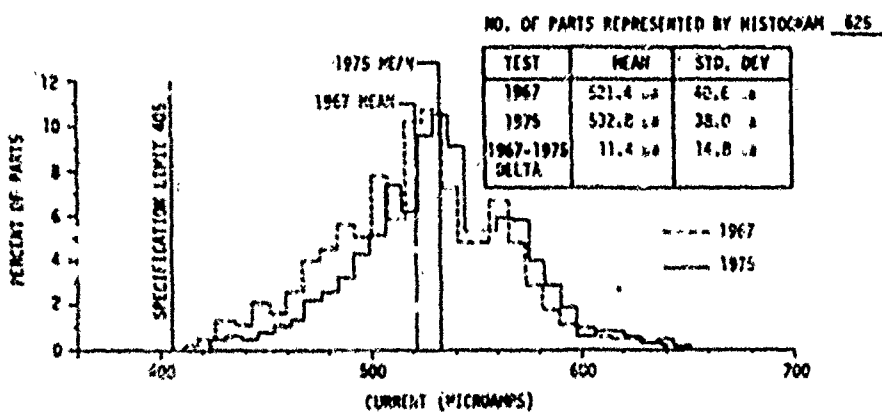
c. 1967 - 1975 CHANGE IN $I_{IN(2)}$

FIGURE 3-34. HISTOGRAM COMPARISON OF $I_{IN(2)}$

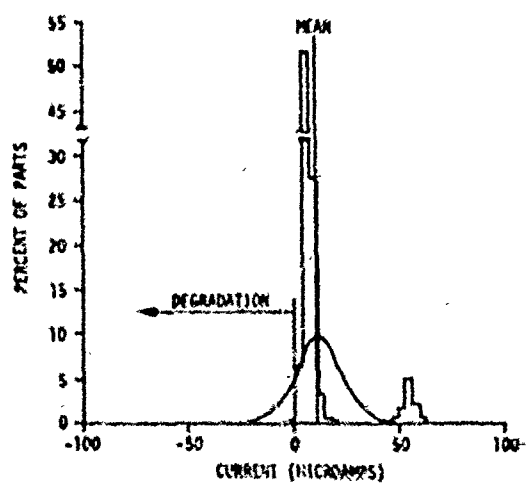
- REGISTER -



a. SCHEMATIC FOR I_{OUT}(6-1) TEST (R₁ RESISTANCE CHECK)



b. DISTRIBUTION OF PARTS: 1975 VS 1967 TEST

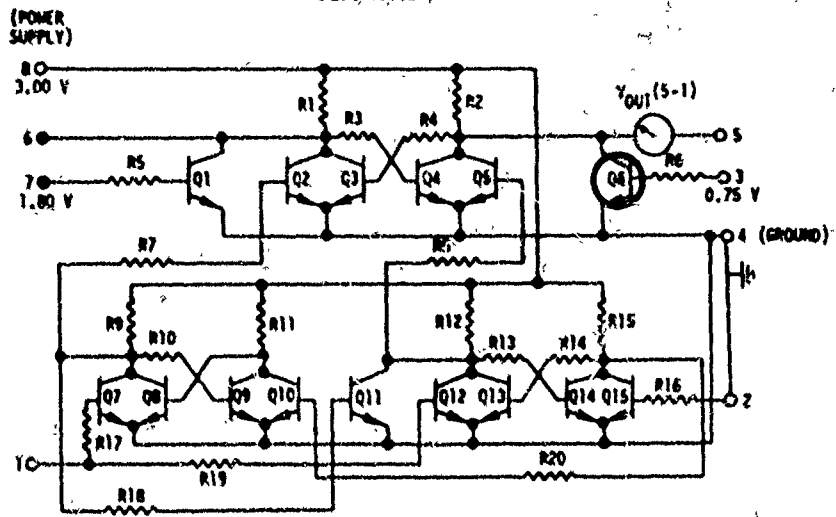


c. 1967-1975 CHANGE IN I_{OUT}(6-1)

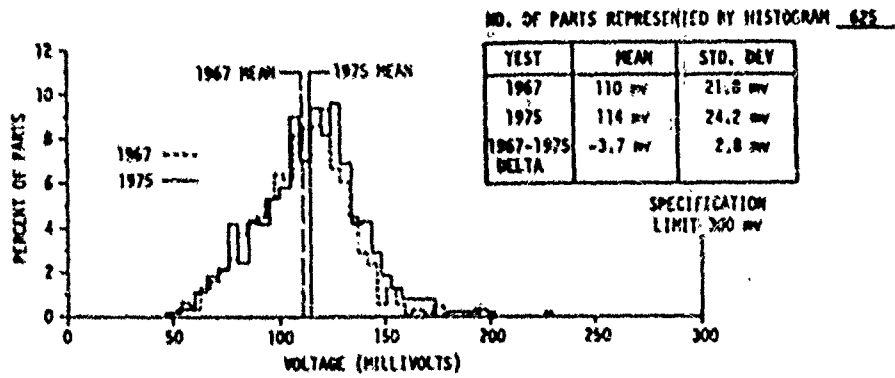
FIGURE 3-35. HISTOGRAM COMPARISON OF I_{OUT}(6-1)

REGISTER

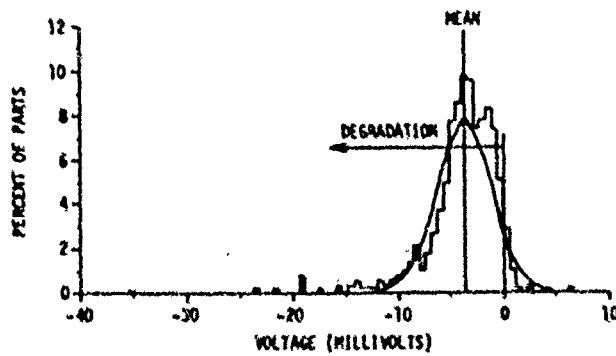
D256-10082-1



a. SCHEMATIC FOR $V_{OUT(5-1)}$ TEST (0.6 VOLTAGE DROP AT MINIMUM "ON" CONDITION)



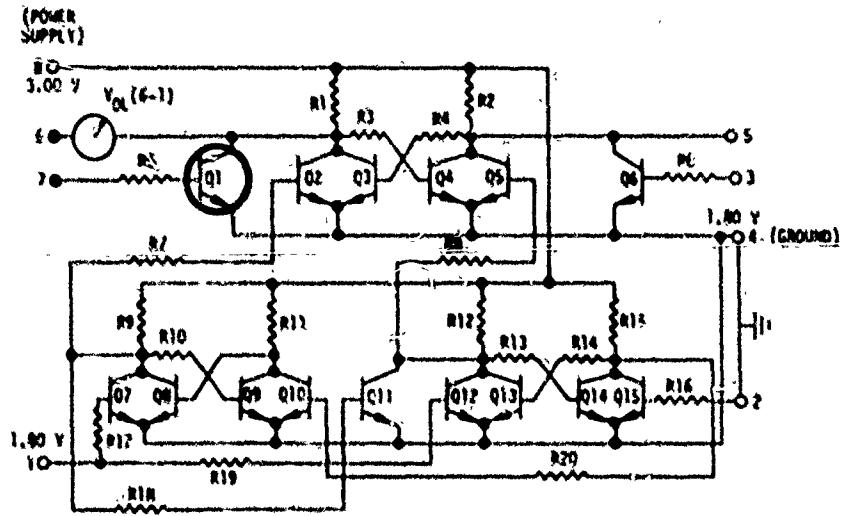
b. DISTRIBUTION OF PARTS: 1975 VS 1967 TEST



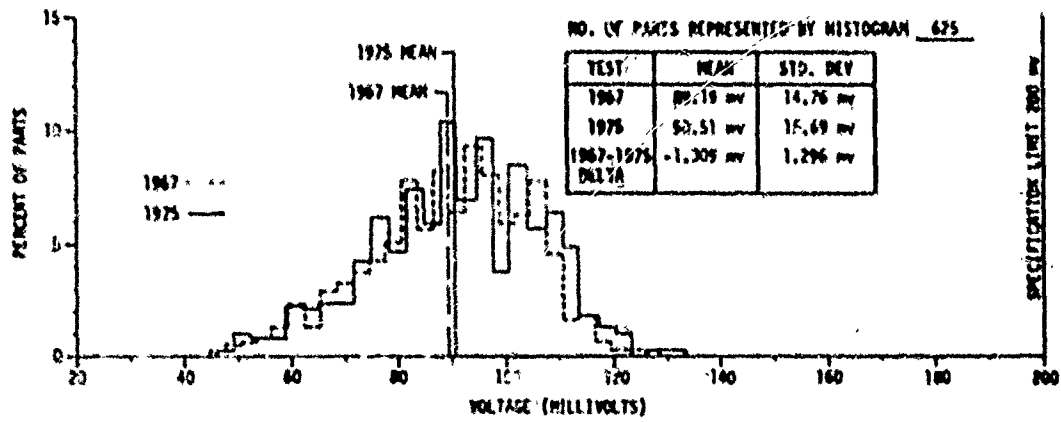
c. 1967 - 1975 CHANGE IN $V_{OUT(5-1)}$

FIGURE 3-36. HISTOGRAM COMPARISON OF $V_{OUT(5-1)}$

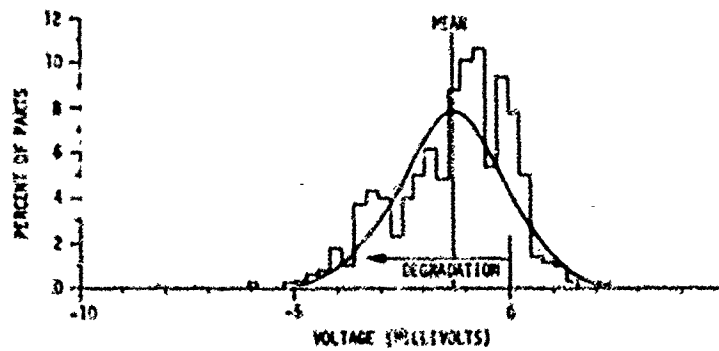
D256-10062-1



a. SCHEMATIC FOR $V_{OL} (6-1)$ TEST (Q1 VOLTAGE DROP AT SATURATION)

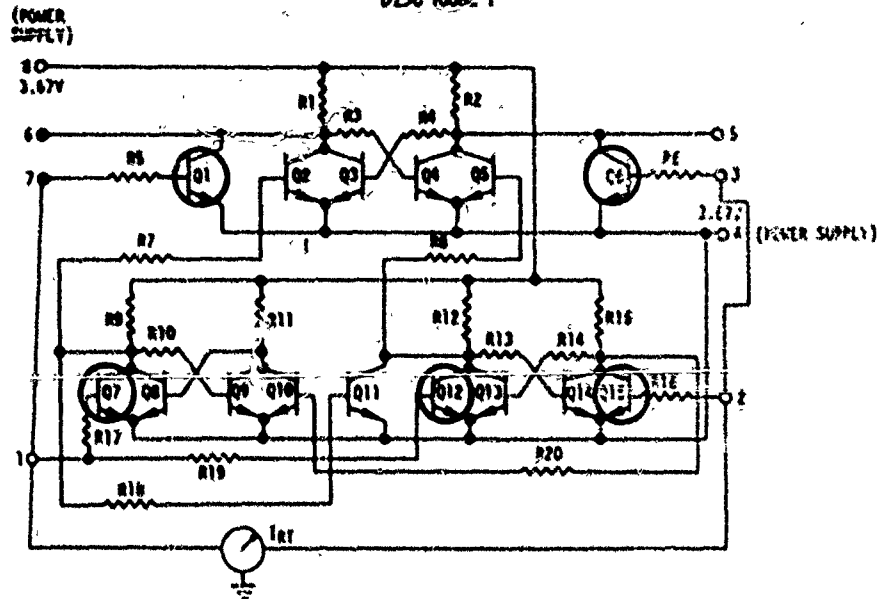


b. DISTRIBUTION OF PARTS: 1975 VS 1967 TEST

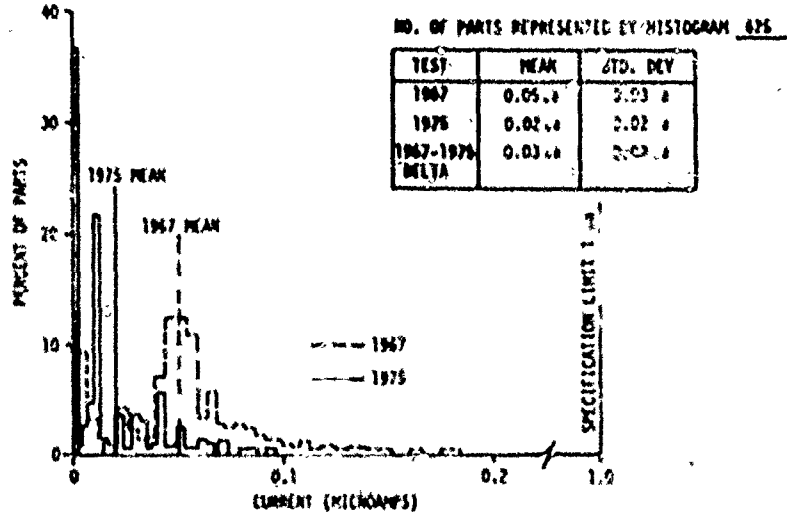


c. 1967 - 1975 CHANGE IN $V_{OL} (6-1)$

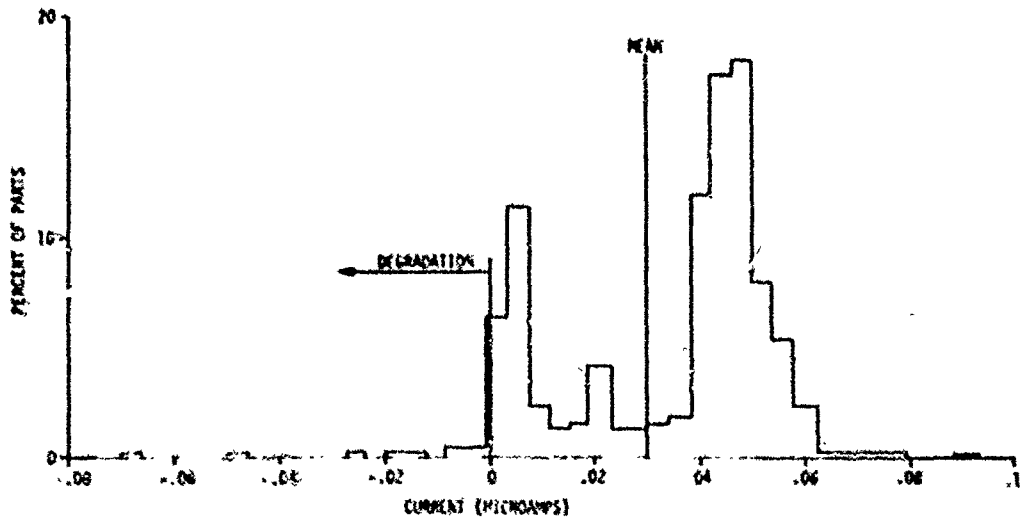
FIGURE 3-37. HISTOGRAM COMPARISON OF $V_{OL} (6-1)$



a. SCHEMATIC FOR IRT TEST (Q1+Q6+Q7+Q12+Q15 BASE-EMITTER JUNCTION LEAKAGE CHECK)

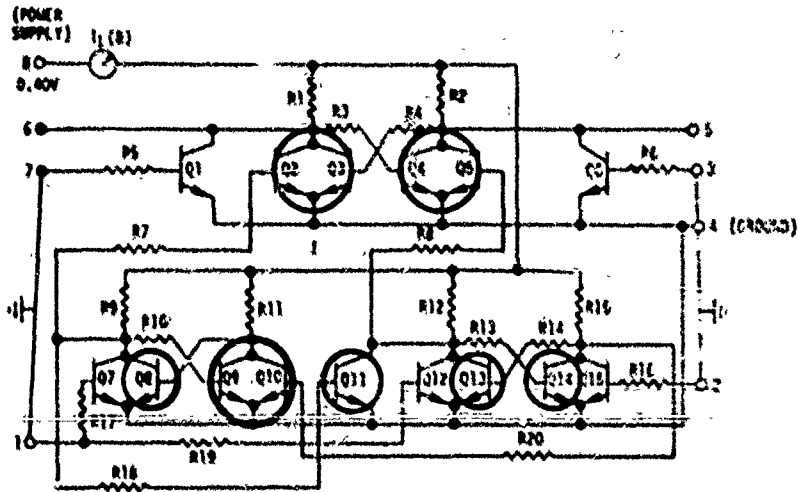


b. DISTRIBUTION OF PARTS; 1975 VS 1967 TEST

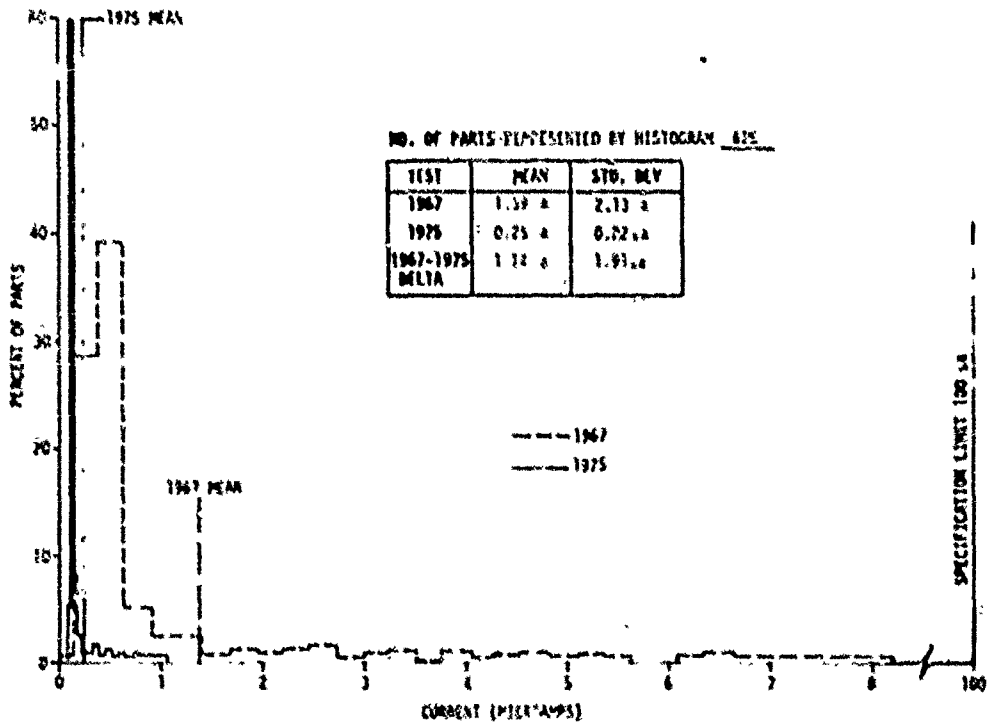


c. 1967-1975 CHANGE IN IRT

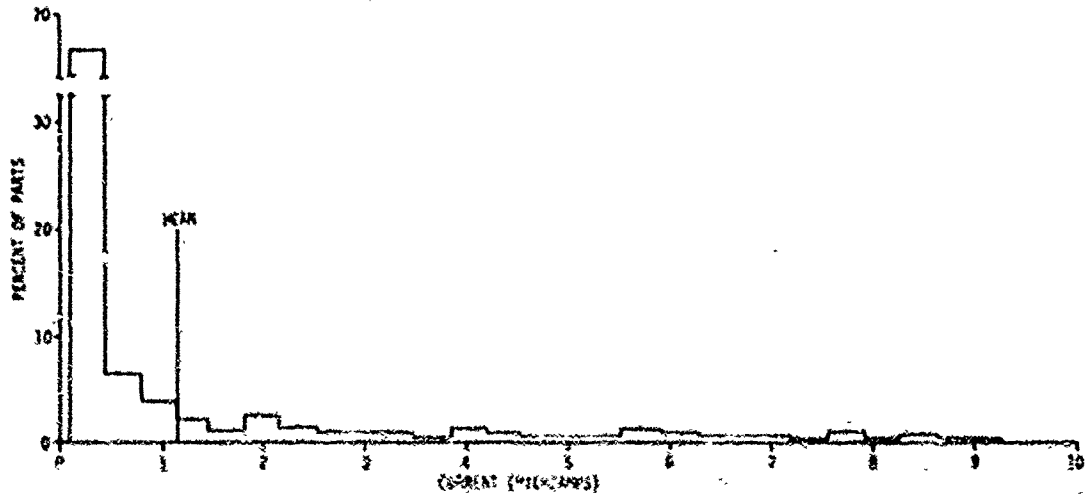
FIGURE 3-38. HISTOGRAM COMPARISON OF IRT



a. SCHEMATIC FOR I(LB) TEST (Q2+Q3+Q4+Q5+Q8+Q9+Q10+Q11+Q13+Q14 LEAKAGE CURRENT AT JUST BELOW MAXIMUM "OFF" CONDITION)



b. DISTRIBUTION OF PARTS: 1975 VS. 1967 TEST

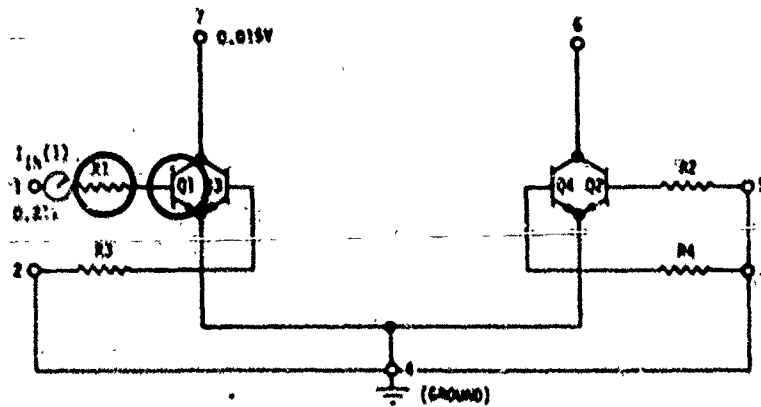


c. 1967-1975 CHANGE IN I(LB)
FIGURE 3-59. HISTOGRAM COMPARISON OF I(LB)

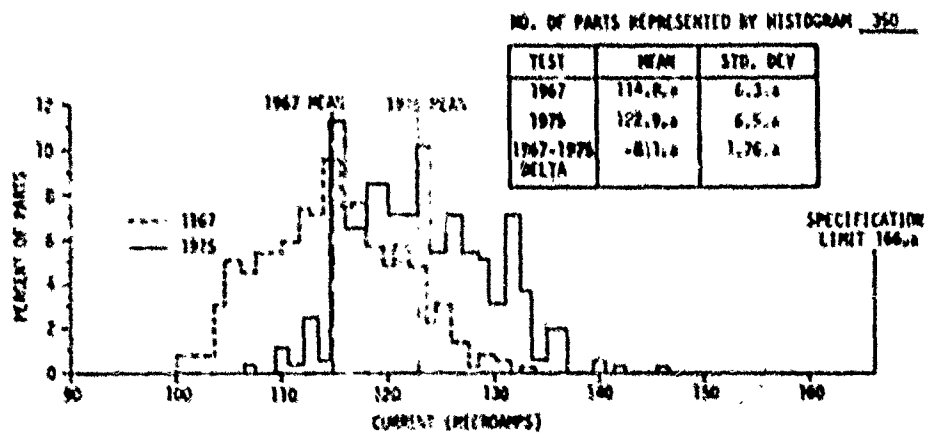
TABLE 3-XVI. EVALUATION OF HISTOGRAM COMPARISONS FOR THE EXPANDER

LEGEND	*TRENDS OBSERVED IN HISTOGRAM COMPARISONS						TECHNICAL ASSESSMENT
	TYPICAL MEASUREMENT DIFFERENCES			TYPICAL PARAMETER DRIFT			
✓ SLIGHT TREND // MODERATE TREND /// PRONOUNCED TREND	1967 - 1975 HISTOGRAMS SIMILAR TO SHIFT	1967 - 1975 HISTOGRAMS SPLIT IN MEASUREMENT ATTRIBUTES	1967 - 1975 HISTOGRAMS SPLIT IN MEASUREMENT SPEC LIMIT	1967 - 1975 HISTOGRAMS SPLIT IN MEASUREMENT SPEC LIMIT	1967 - 1975 HISTOGRAMS SPLIT IN MEASUREMENT SPEC LIMIT	1967 - 1975 HISTOGRAMS SPLIT IN MEASUREMENT SPEC LIMIT	
PARAMETER (FIGURE NO.)	✓	✓	✓	///	///	///	
I _{IN} (1) (3-40)	✓	✓	✓	///	///	///	NO MEASURABLE DRIFT
V _{OUT} (E-1) (3-41)	✓	✓	✓	///	///	///	PRONOUNCED DRIFT, VERY PRONOUNCED IN -σ PARTS
V _{OL} (E-1) (3-42)	✓	///	✓	✓	✓	✓	NO MEASURABLE DRIFT IN +σ PARTS; SLIGHT DRIFT IN -σ PARTS
*V _{OL} (7-1) (3-43)	✓	///	✓	✓	✓	✓	NO MEASURABLE DRIFT IN +σ PARTS; SLIGHT DRIFT IN -σ PARTS
I _{RT} (3-44)	✓	✓	✓				NO SIGNIFICANT DRIFT
I _L (8) (3-45)	✓	✓	✓				NO SIGNIFICANT DRIFT
I _{CEX} (3-46)	✓	✓	✓				NO SIGNIFICANT DRIFT

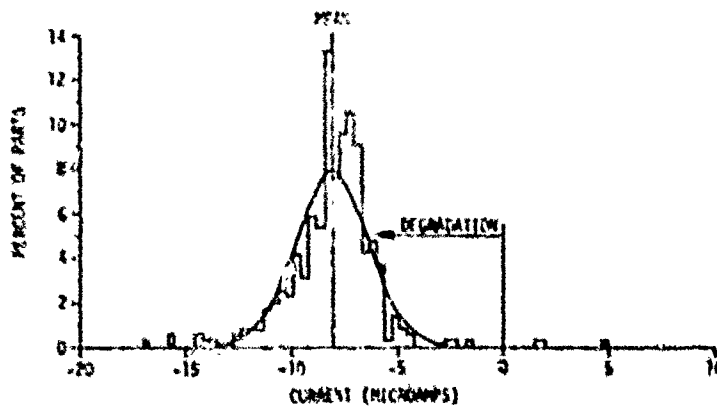
*NOTE: CHECKS APPEARING IN FIRST THREE COLUMNS SUPPORT CONCLUSION THAT DIFFERENCES ARE DUE TO NORMAL MEASUREMENT ERRORS; CHECKS IN LAST THREE COLUMNS SUPPORT CONCLUSION THAT DIFFERENCES ARE DUE TO PARAMETER DRIFT



a. SCHEMATIC FOR $I_{IN(II)}$ TEST (R₁ RESISTANCE + C1 CASE EVALUATION CHECK AT SATURATION VOLTAGE)



b. DISTRIBUTION OF PARTS: 1975 VS 1967 TEST

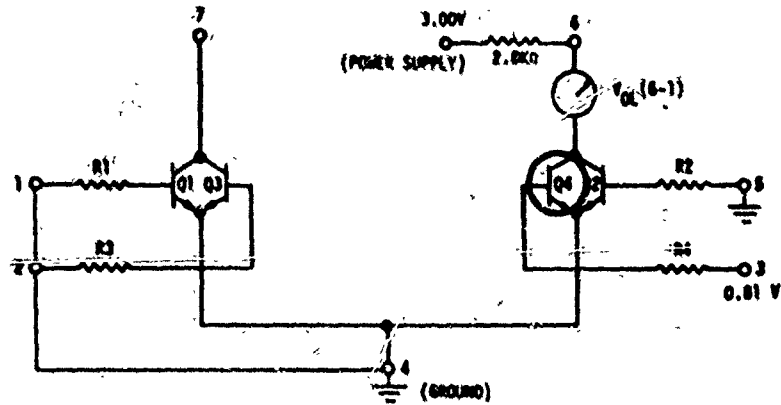


c. 1967 - 1975 CHANGE IN $I_{IN(II)}$

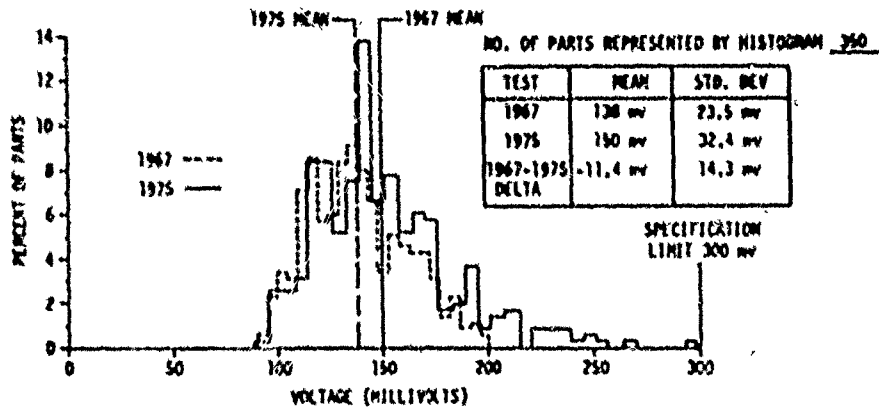
FIGURE 3-40. HISTOGRAM COMPARISON OF $I_{IN(II)}$

- EXPANDER -

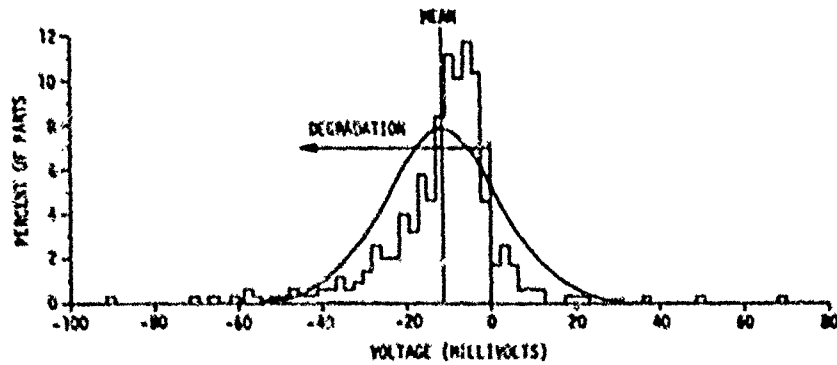
D256-10082-1



a. SCHEMATIC FOR $V_{OUT(6-1)}$ TEST (Q4 VOLTAGE DROP AT MINIMUM "ON" CONDITION)



b. DISTRIBUTION OF PARTS: 1975 VS 1967 TEST

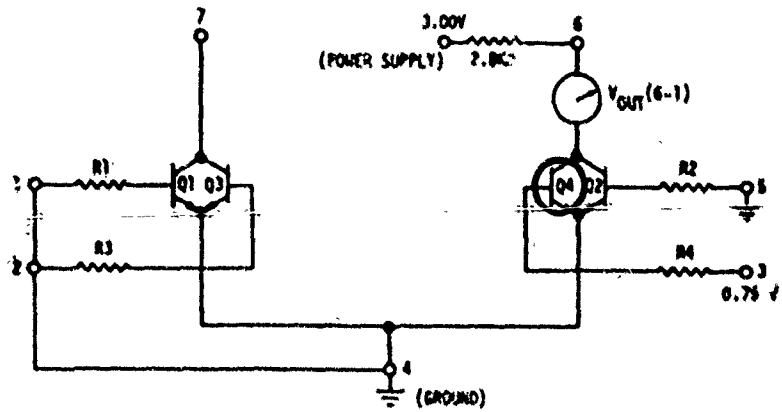


c. 1967 - 1975 CHANGE IN $V_{OUT(6-1)}$

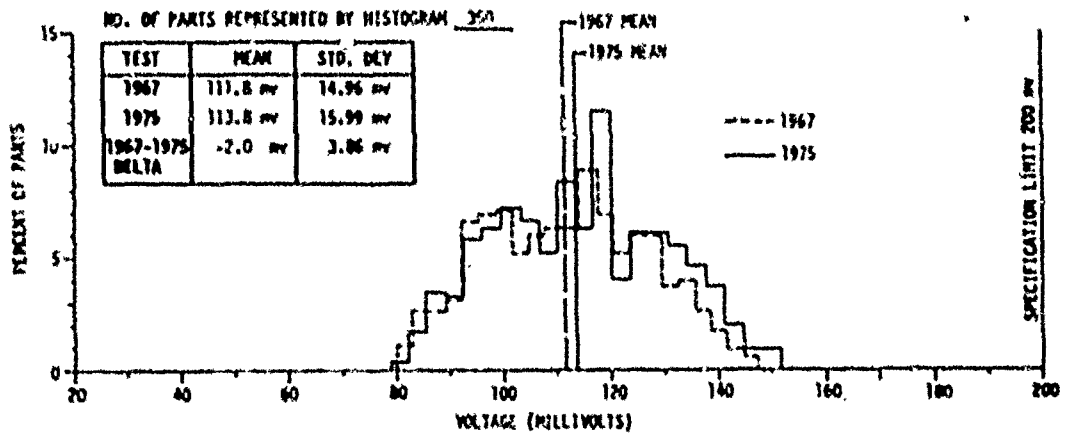
FIGURE 3-41. HISTOGRAM COMPARISON OF $V_{OUT(6-1)}$

- EXPANDER -

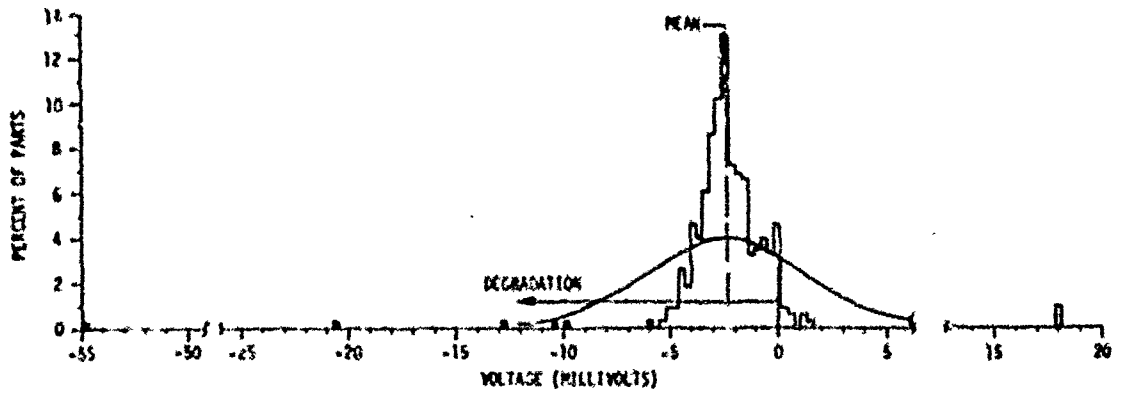
D256-100E2-1



a. SCHEMATIC FOR V_{OL} (6-1) TEST (04 VOLTAGE DROP AT SATURATION)



b. DISTRIBUTION OF PARTS: 1975 VS 1967 TEST

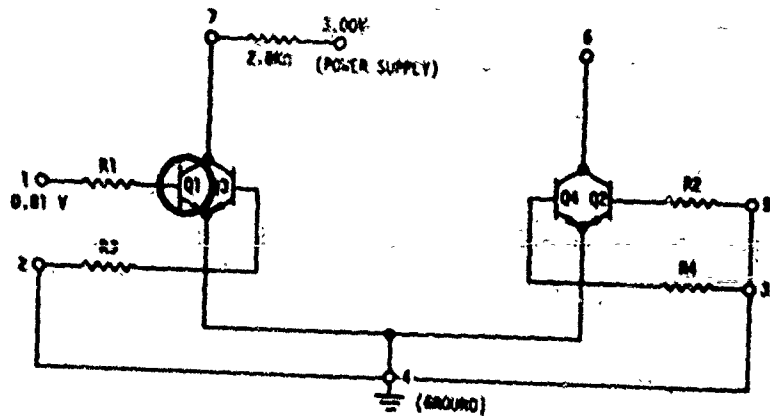


c. 1967 - 1975 CHANGE IN V_{OL} (6-1)

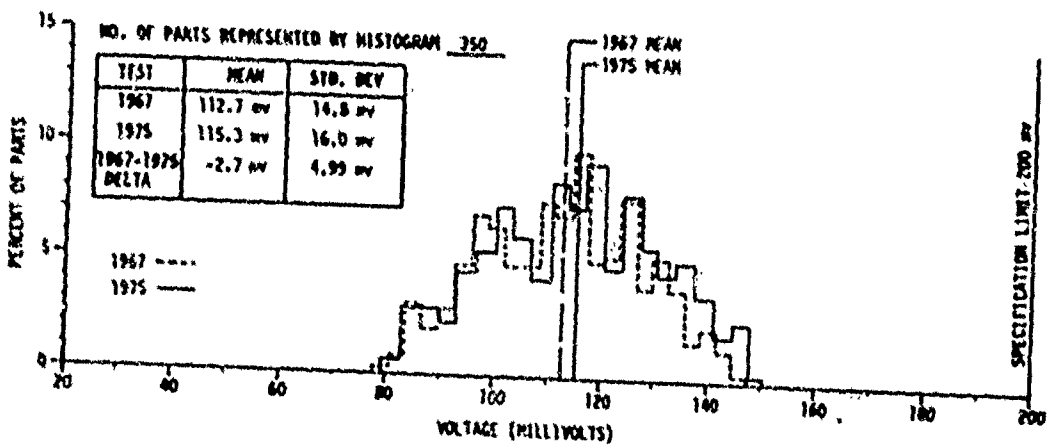
FIGURE 3-42. HISTOGRAM COMPARISON OF V_{OL} (6-1)

- EXPANDER -

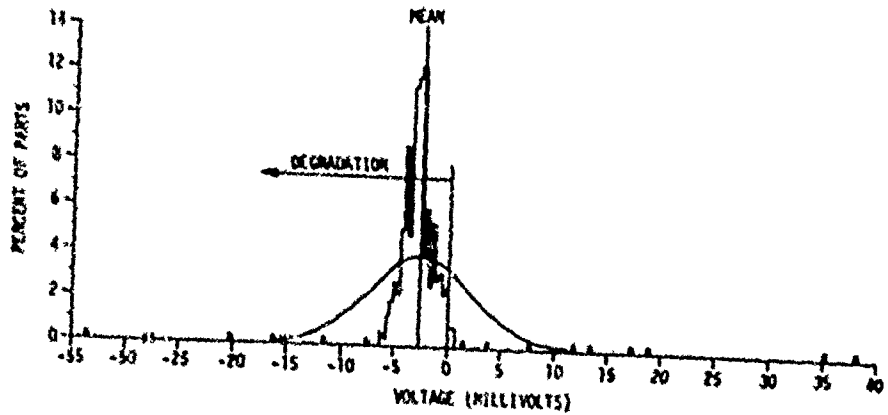
D256-L082-1



a. SCHEMATIC FOR V_{OL} (7-1) TEST (Q1 VOLTAGE DROP AT SATURATION)

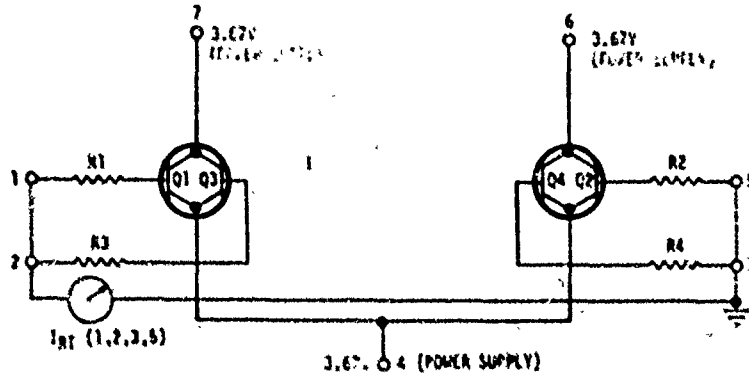


b. DISTRIBUTION OF PARTS: 1975 VS 1967 TEST

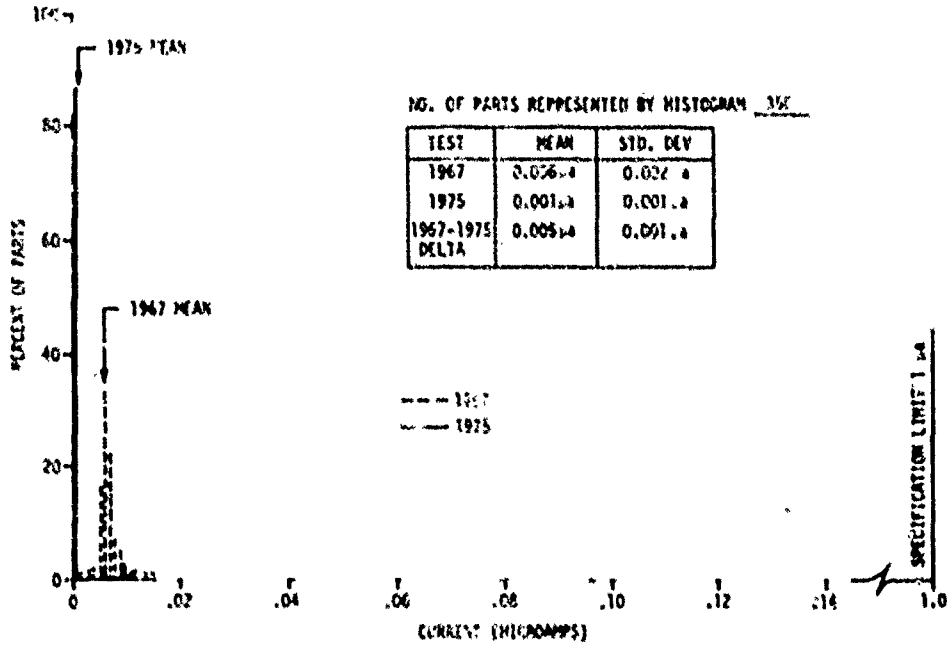


c. 1967 - 1975 CHANGE IN V_{OL} (7-1)

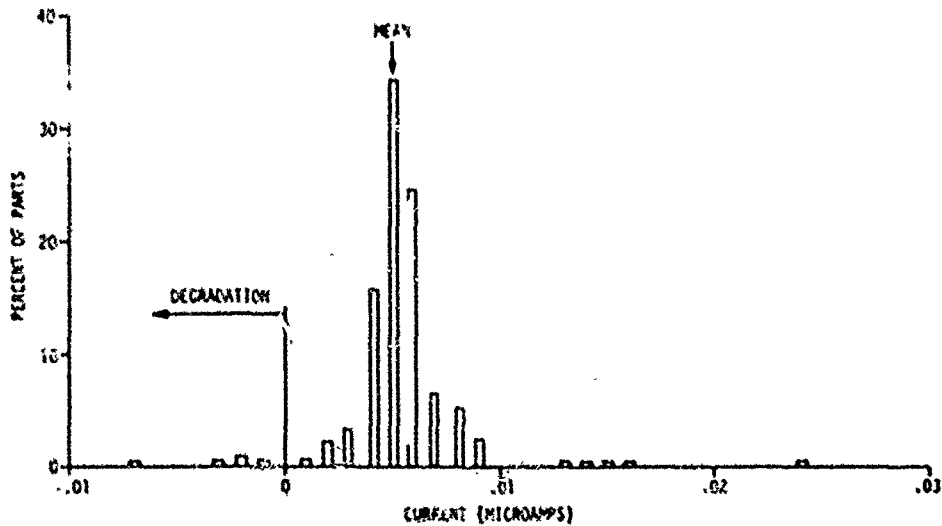
FIGURE 3-43. HISTOGRAM COMPARISON OF V_{OL} (7-1)



a. SCHEMATIC FOR $I_{RT}(1,2,3,5)$ TEST ($Q1+Q2+Q3+Q4$ BASE EMITTER JUNCTION LEAKAGE CURRENT)



b. DISTRIBUTION OF PARTS: 1975 VS 1967 TEST

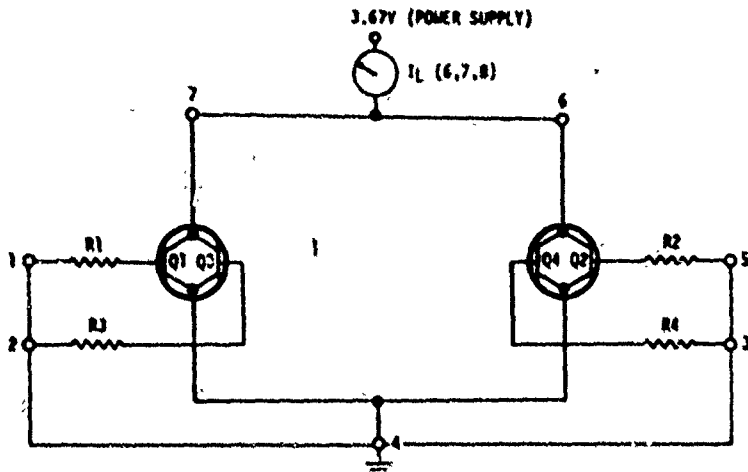


c. 1967-1975 CHANGE IN $I_{RT}(1,2,3,5)$

FIGURE 3-4A. HISTOGRAM COMPARISON OF $I_{RT}(1,2,3,5)$

EXPANDER

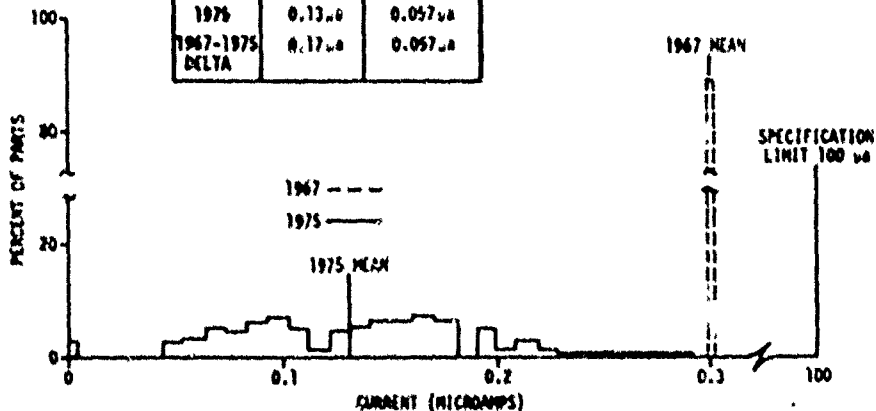
2.6A



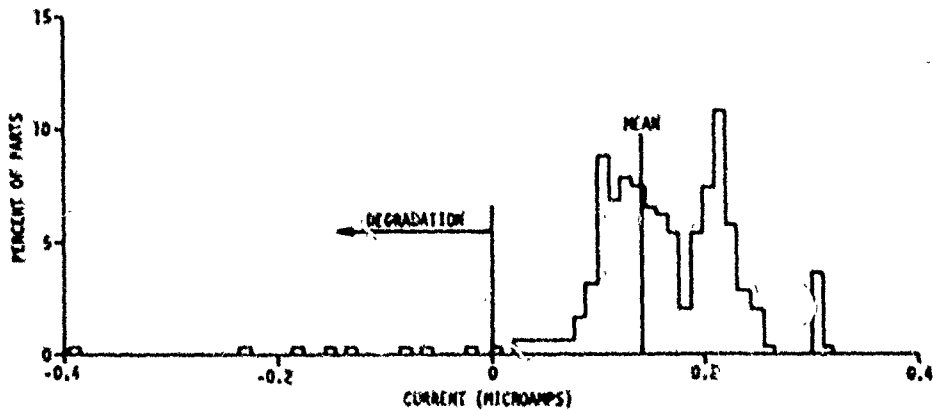
a. SCHEMATIC FOR $I_L(6,7,8)$ TEST ($Q1+Q2+Q3+Q4$ LEAKAGE CURRENT AT MAXIMUM POWER SUPPLY VOLTAGE)

NO. OF PARTS REPRESENTED BY HISTOGRAM 350

TEST	MEAN	STD. DEV
1967	0.30 μ a	0.002 μ a
1975	0.13 μ a	0.057 μ a
1967-1975 DELTA	0.17 μ a	0.057 μ a



b. DISTRIBUTION OF PARTS: 1975 VS 1967 TEST

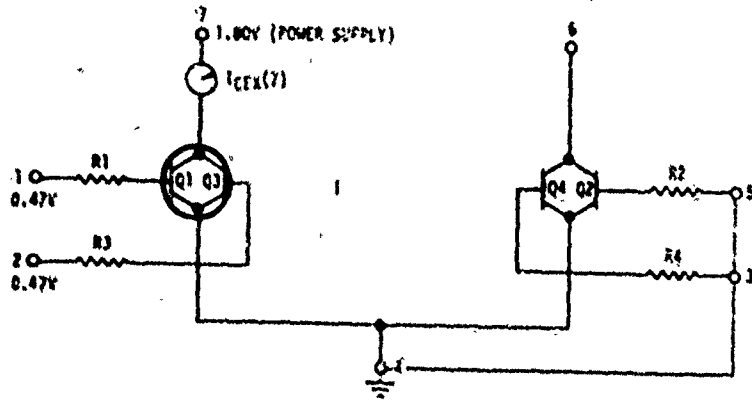


c. 1967-1975 CHANGE IN I_L

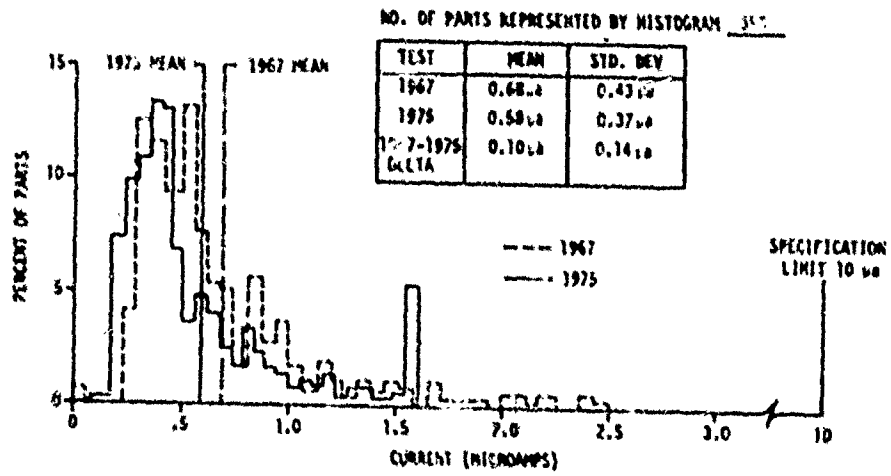
FIGURE 3-45. HISTOGRAM COMPARISON OF I_L

EXPANDER

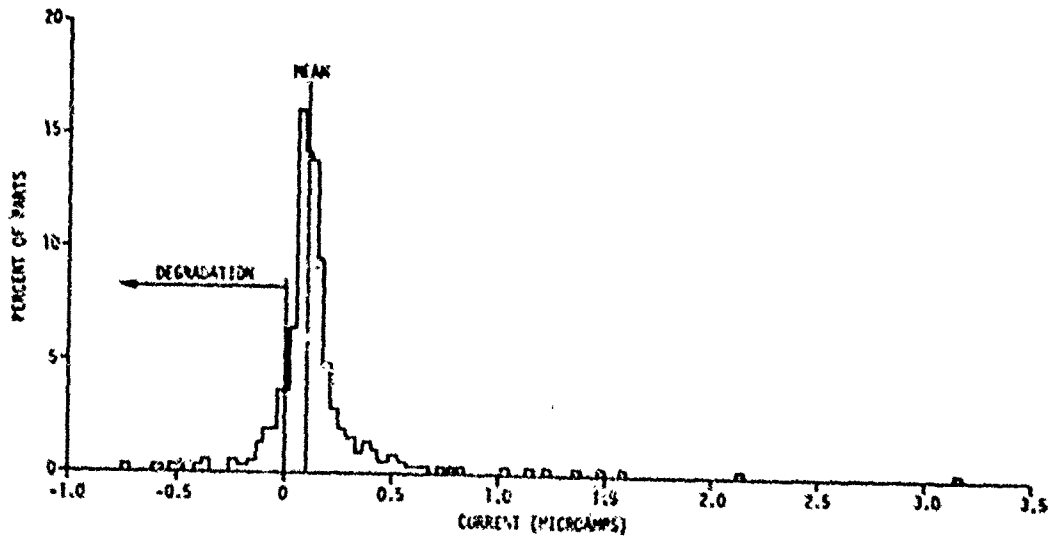
DZ56-10082-1



a. SCHEMATIC FOR ICEX(7) TEST (Q1+Q3 LEAKAGE CURRENT AT MAXIMUM "OFF" VOLTAGE)



b. DISTRIBUTION OF PARTS: 1975 VS 1967 TEST



c. 1967-1975 CHANGE IN ICEX
FIGURE 3-46. HISTOGRAM COMPARISON OF ICEX
EXPANDER

SECTION 4

PRODUCT IMPROVEMENT GUIDELINES

4.0 PRODUCT IMPROVEMENT GUIDELINES

The results of this test program have been assessed to establish guidelines for increasing storage life. Recommendations are summarized in Table 4-I.

TABLE 4-I. PRODUCT IMPROVEMENT RECOMMENDATIONS

POTENTIAL FAILURES	TEST RESULTS	RECOMMENDATIONS
<u>CATASTROPHIC</u> BOND WIRE FAILURES PACKAGE PROBLEMS LEAD CORROSION/BREAKAGE OXIDE DEFECTS	NO FAILURES NO FAILURES NO FAILURES 3 FAILURES; FAILURE RATE = 0.0005×10^{-6} FAILURES/PART HR (90% CONFIDENCE LEVEL)	STORAGE INTEGRITY OF BOND WIRES, PACKAGES AND LEADS CAN BE ADEQUATELY ASSURED VIA THE FOLLOWING MILITARY SPECIFICATIONS AND STANDARDS FOR MO-REL PARTS: <ul style="list-style-type: none"> • MIL-STD-203, "TEST METHODS FOR ELECTRONIC AND ELECTRICAL COMPONENT PARTS" • MIL-S-10400, "MILITARY SPECIFICATIONS, BOND CONDUCTOR DEVICES GENERAL SPECIFICATIONS FOR" • MIL-S-45204, "SOLDER PLATING, ELECTRO-DEPOSITED" • QQ-S-571, "SOLDER; TIN ALLOY, LEAD-TIN ALLOY, LEAD ALLOY" STORAGE INDUCED OXIDE DEFECT FAILURES CAN BE ADEQUATELY CONTROLLED VIA THE ABOVE SPECIFICATIONS/STANDARDS PLUS THE REQUIREMENTS TEST THOROUGH FUNCTIONAL TESTS BE PERFORMED AT THE CIRCUIT CARD LEVEL.
<u>PARAMETER DRIFT</u> RESISTANCE TRANSISTOR LEAKAGE TRANSISTOR GAIN	NO SIGNIFICANT DRIFT NO SIGNIFICANT DRIFT SIGNIFICANT DRIFT	ASSURE COMPLIANCE WITH THE SPECIFICATIONS AND STANDARDS CITED ABOVE PERFORM "WORST CASE" CIRCUIT ANALYSIS TO DEFINE OPERATING RANGE OF EACH GAIN-DEPENDENT PARAMETER. ESTABLISH DESIGN SPECIFICATIONS AND/OR SCREENING TEST CRITERIA TO MAINTAIN ALL PARAMETERS WITHIN RELATIVELY LINEAR OPERATING RANGE ASSUMING A 30% LOSS IN GAIN (I.E., AVOID DRIFTING INTO REGIONS CHARACTERIZED BY THE STEEP PART OF FIGURE 4-1, WHERE A SMALL LOSS IN GAIN CAN CAUSE A LARGE CHANGE IN A CRITICAL PARAMETER).

The parts were packaged, assembled, inspected and tested to Boeing specifications that closely followed the Military Standards and Specifications cited in Table 4-I. There were no bond wire failures, no package problems, and no lead corrosion/breakage after eight years of storage; the cited specifications provide adequate storage reliability for these potential

4.0 (Continued)

failures modes. The only source of storage-induced catastrophic failures in these parts - oxide defects - can be controlled in a hardware system. Minuteman experience has shown that most of the latent oxide defects that survive part level burn-in can be detected and eliminated by assuring that adequate functional tests are performed at the circuit card level.

Parameter drift proved negligible in the resistance and transistor leakage characteristics. Transistor gain was the only parameter that exhibited a significant loss of performance during the eight years of storage. This is the one parameter that may have to be controlled to obtain a 10-20 year shelf life on these RTL devices. Transistor gain was not measured directly. However, the transfer function relating V_{OUT} to transistor gain was obtained from a special test of the Double Gate devices. The result is shown in Figure 4-1. Using this transfer function, and measured changes of V_{OUT} , hand calculations were made of the gain changes in 20 of the parts. These parts included all of the Double Gate incipient failures plus other parts selected randomly from the -1 σ tail of the 1967 distribution. These parts showed reduction in gain ranging from 7 to 26%, with an average change of 13%.

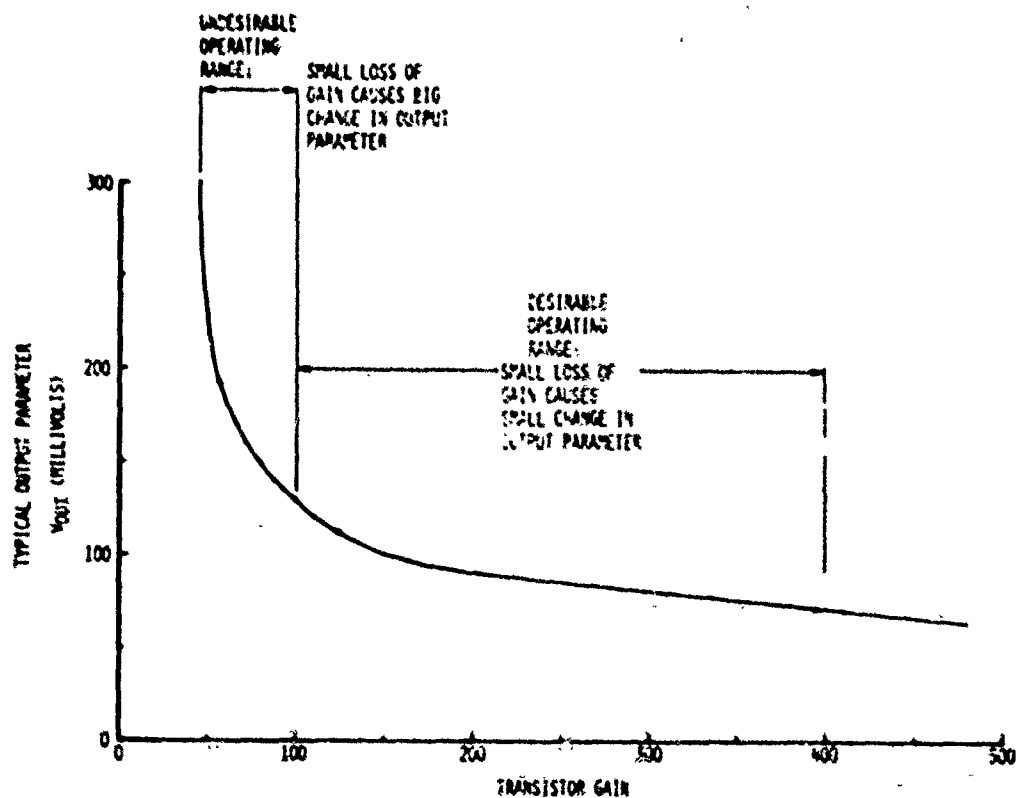


FIGURE 4-1. TYPICAL OUTPUT PARAMETER VS TRANSISTOR GAIN

4.0 (Continued)

To achieve long shelf life, the design specifications for new parts, or the screening test specifications for existing parts, should prevent operating the part in a highly non-linear region such as shown in Figure 4-1.

If a new part is being developed, the diffusion profiles can be adjusted to obtain higher gain parts in which a small loss of gain does not cause a large degradation in one of the output parameters. Screening tests can also be used to reject the lower gain parts which could lead to the output parameter(s) drifting into the non-linear region. The circuit card designer can also limit fanout (the number of inputs driven by a single output) to less than the Manufacturer's rating to prevent operating on the steep part of the output-gain curve. The following approach is recommended to achieve adequate control of transistor gain drift during storage:

- 1) Perform analysis of design to determine worst case operating regions.
- 2) Determine the part gain and/or circuit card fanout limits required to keep the output parameters from drifting into the highly non-linear operating region assuming a 30% loss of gain (10 yr shelf life).
- 3) Establish design and/or screening test criteria to accomplish (2) above.

The screening tests could be imposed at the wafer level. Wafers that would yield high gain parts would be selected for long storage life applications, with the remainder going to commercial use.

As previously stated, rejecting the 16% (-1 σ) of the parts with the highest V_{OUT} measurements (lowest gain measurements) would have eliminated all but one of the incipient parameter drift failures. A worst case analysis of the Minuteman logic circuits was performed to evaluate the effect of V_{OUT} drifting above the 300 mv specification. The analysis showed that these parts would still reliably perform their logic functions even when degraded well beyond the 300 mv limit. Consequently, these particular parts are deemed to have adequate storage life reliability without imposing more severe test criteria. However, other devices may be more dependent on the gain of their transistors and should be evaluated on a case-by-case basis.

4.1 TRANSISTOR GAIN DRIFT MECHANISMS

The shelf-life drift observed in transistor gain is attributed to one or a combination of the following mechanisms:

- 1) Changes in the gold doping process, which is used to control the "parasitic transistor" condition*, as well as to increase part switching speed.

*Refer to pp 222-226, Fundamentals of Silicon Integrated Device Technology, Vol. II, Edited by R. M. Burger and R. P. Donovan, Prentice-Hall, 1968, for an explanation of the "parasitic transistor" condition.

4.1 (Continued)

- 2) Growth of a "parasitic transistor" condition due to migration of contaminants, or to changes in the gold doping process.

In devices of this type, a parasitic base-to-substrate transistor can form due to migration of contaminants or gold. This parasitic transistor shunts part of the base current around the base emitter junction, effectively reducing transistor gain. The gold may also migrate within the silicon lattice structure, thereby reducing the gain directly. Since all of the incipient failure parts were operating in the non-linear region characterized by Figure 4-1, small gain changes were able to produce large increases in the V_{OUT} parameter. Selected incipient failures are being provided to Georgia Institute of Technology, who will attempt to determine the physical changes that are causing the observed drift.